

FIG. 1

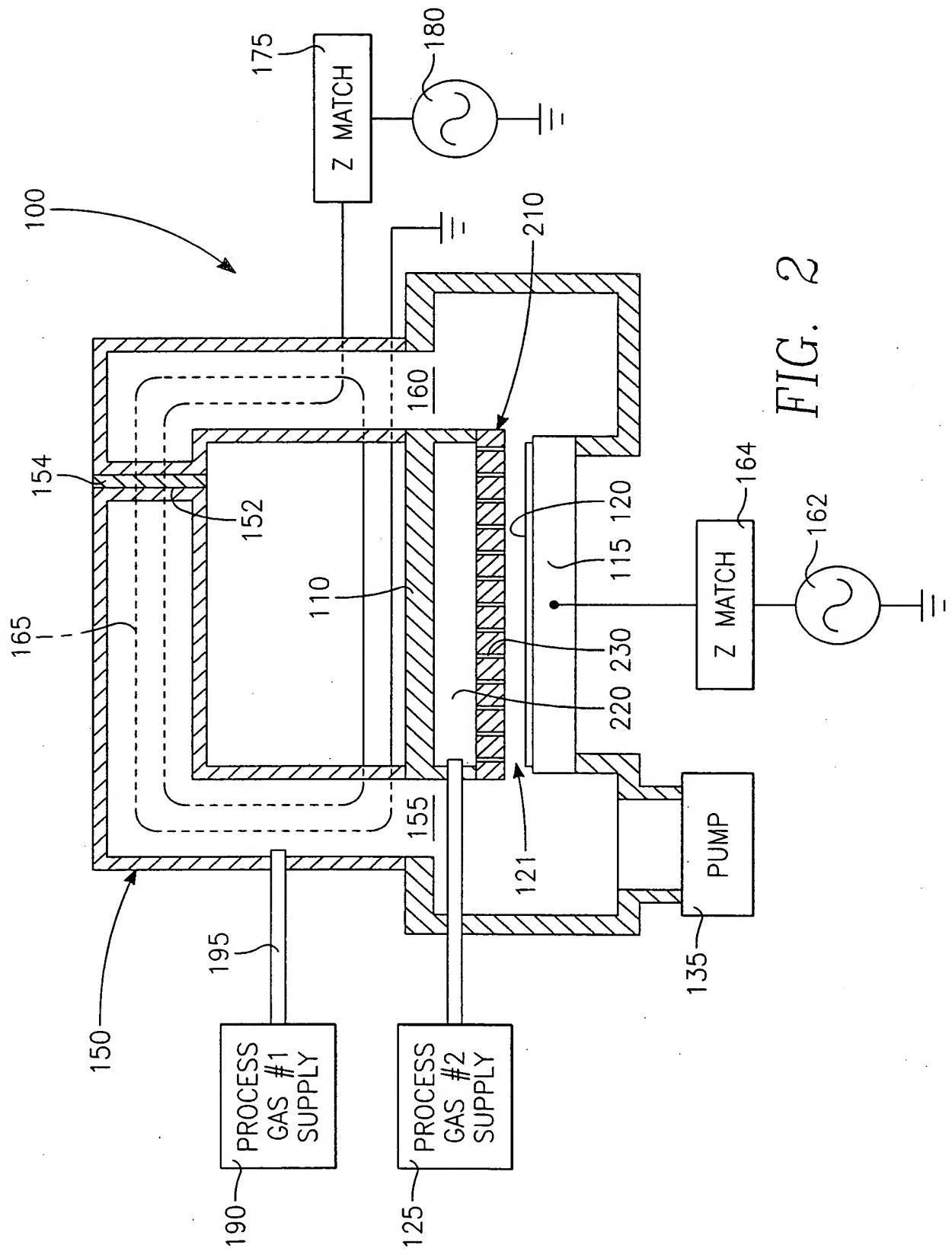


FIG. 2

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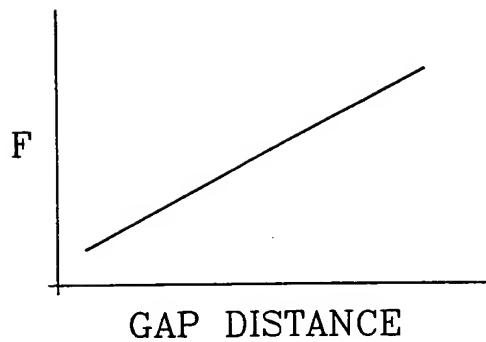


FIG. 3

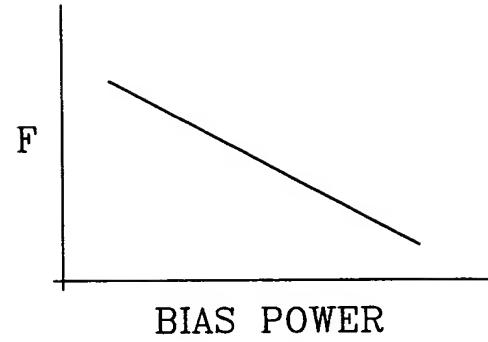


FIG. 4

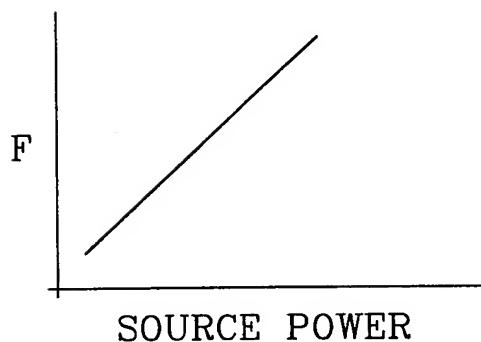


FIG. 5

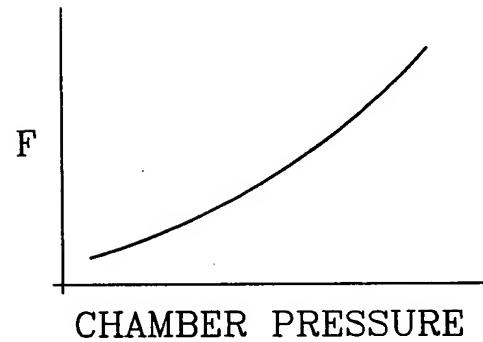


FIG. 6

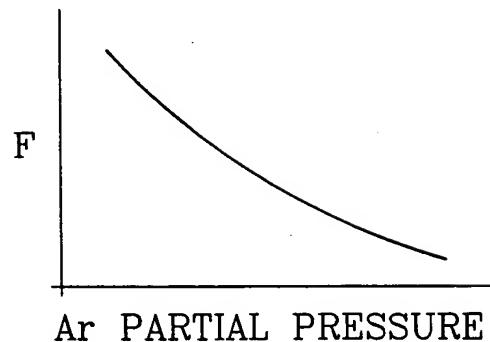


FIG. 7

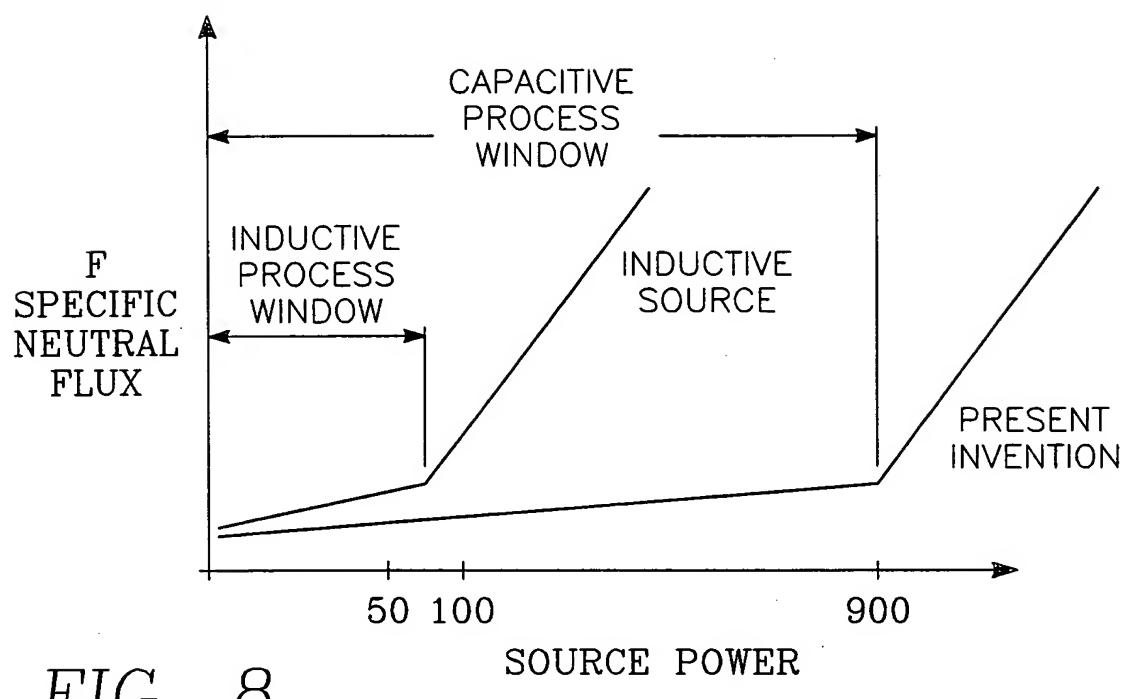


FIG. 8

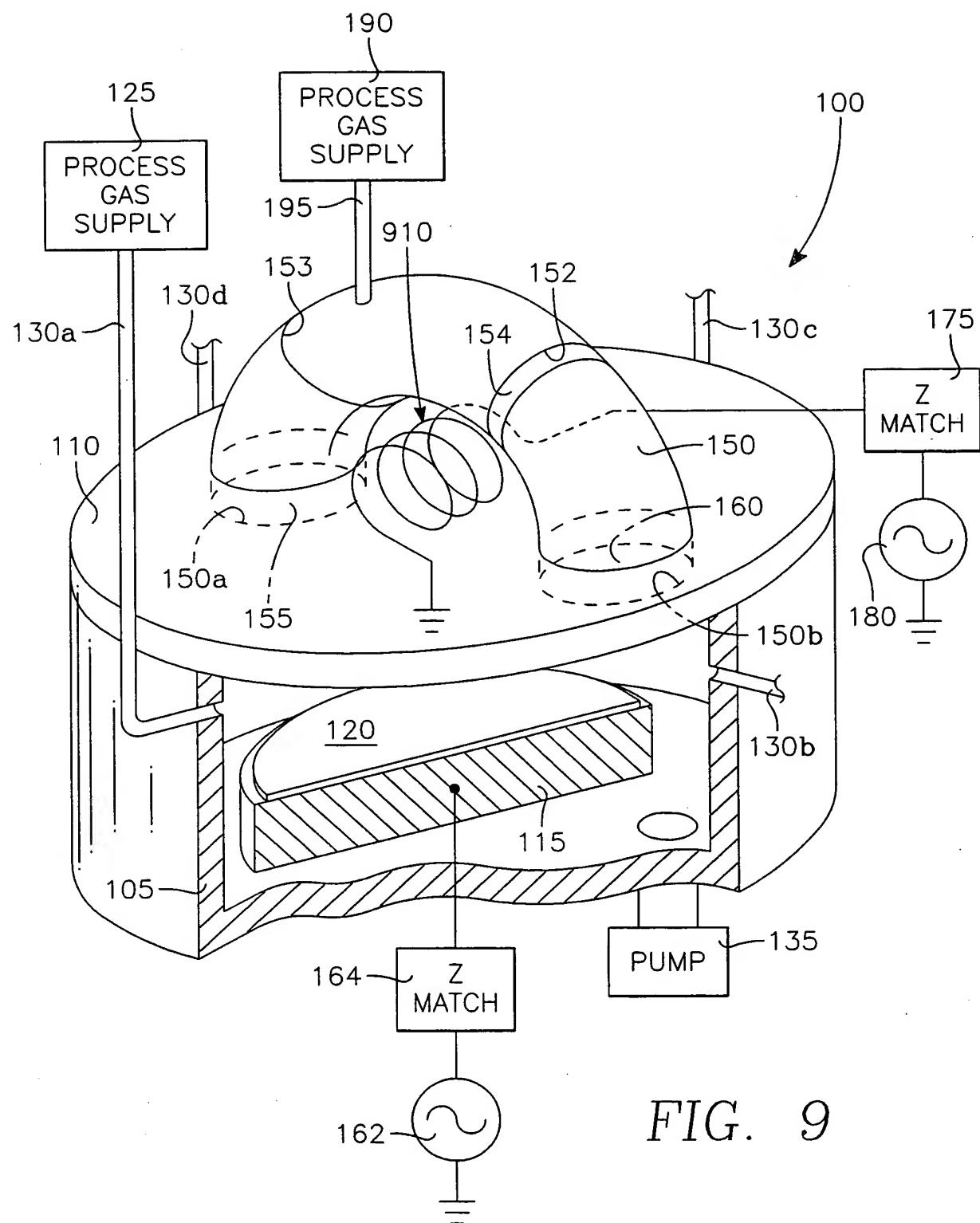


FIG. 9

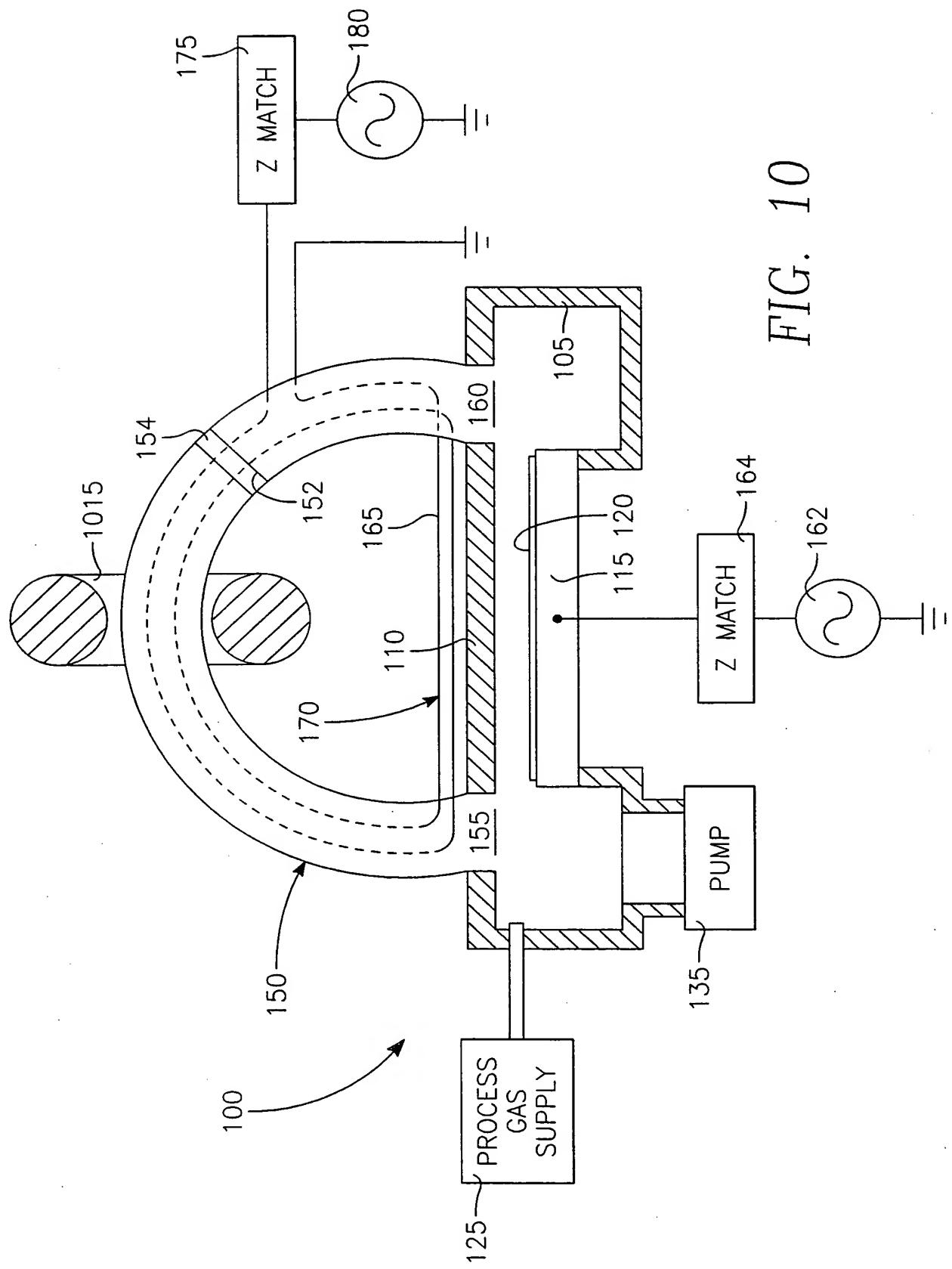


FIG. 10

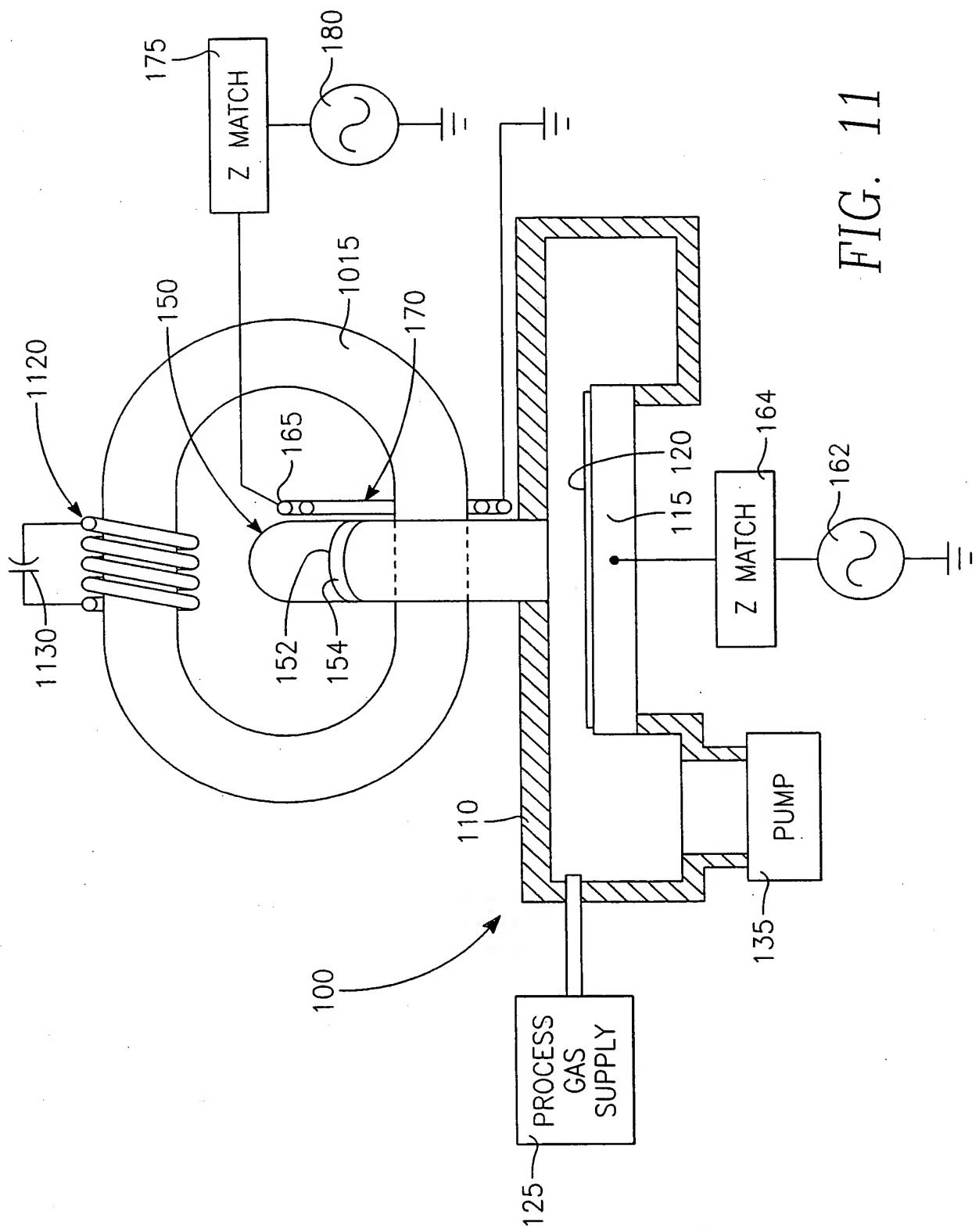


FIG. 11

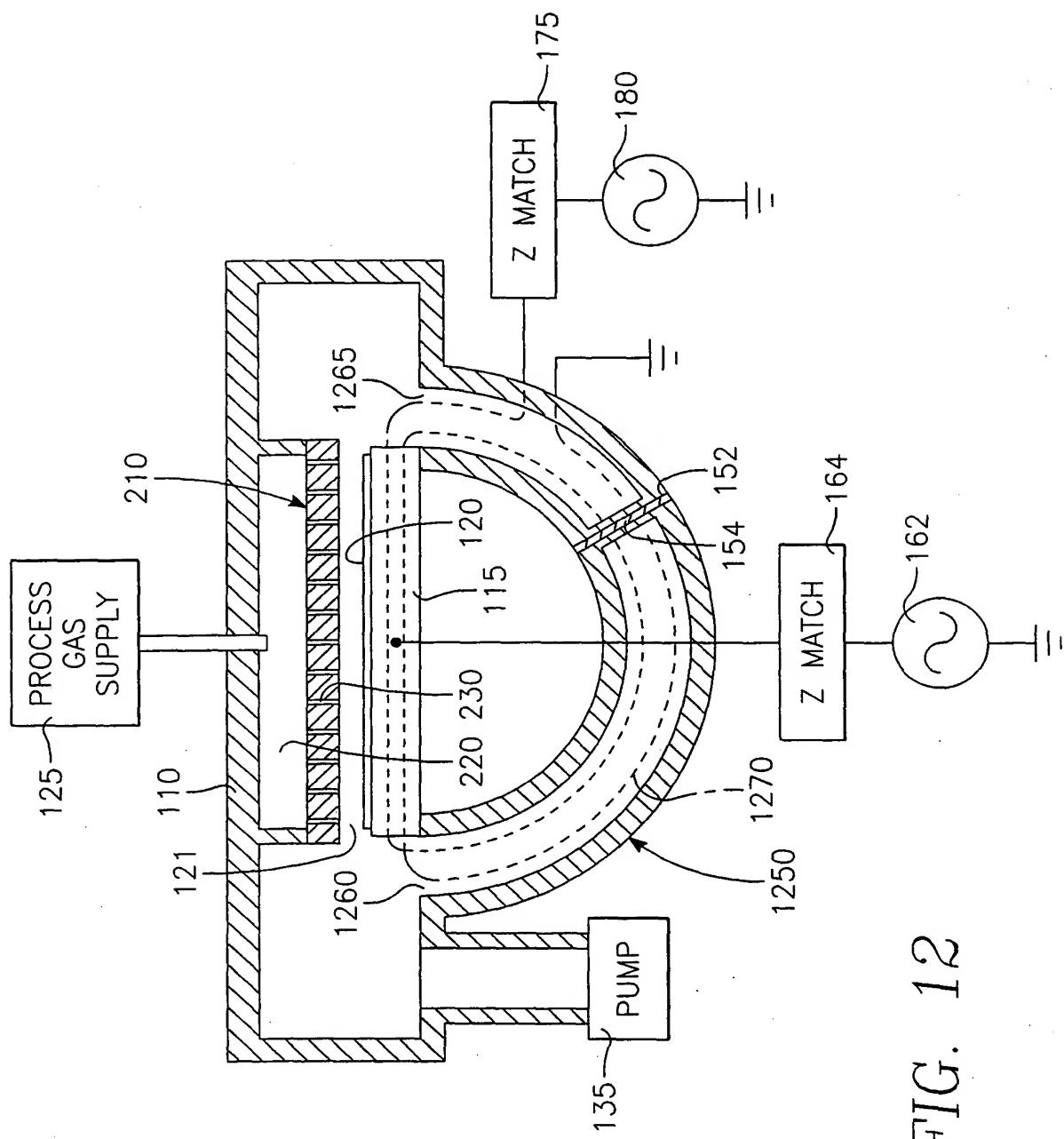


FIG. 12

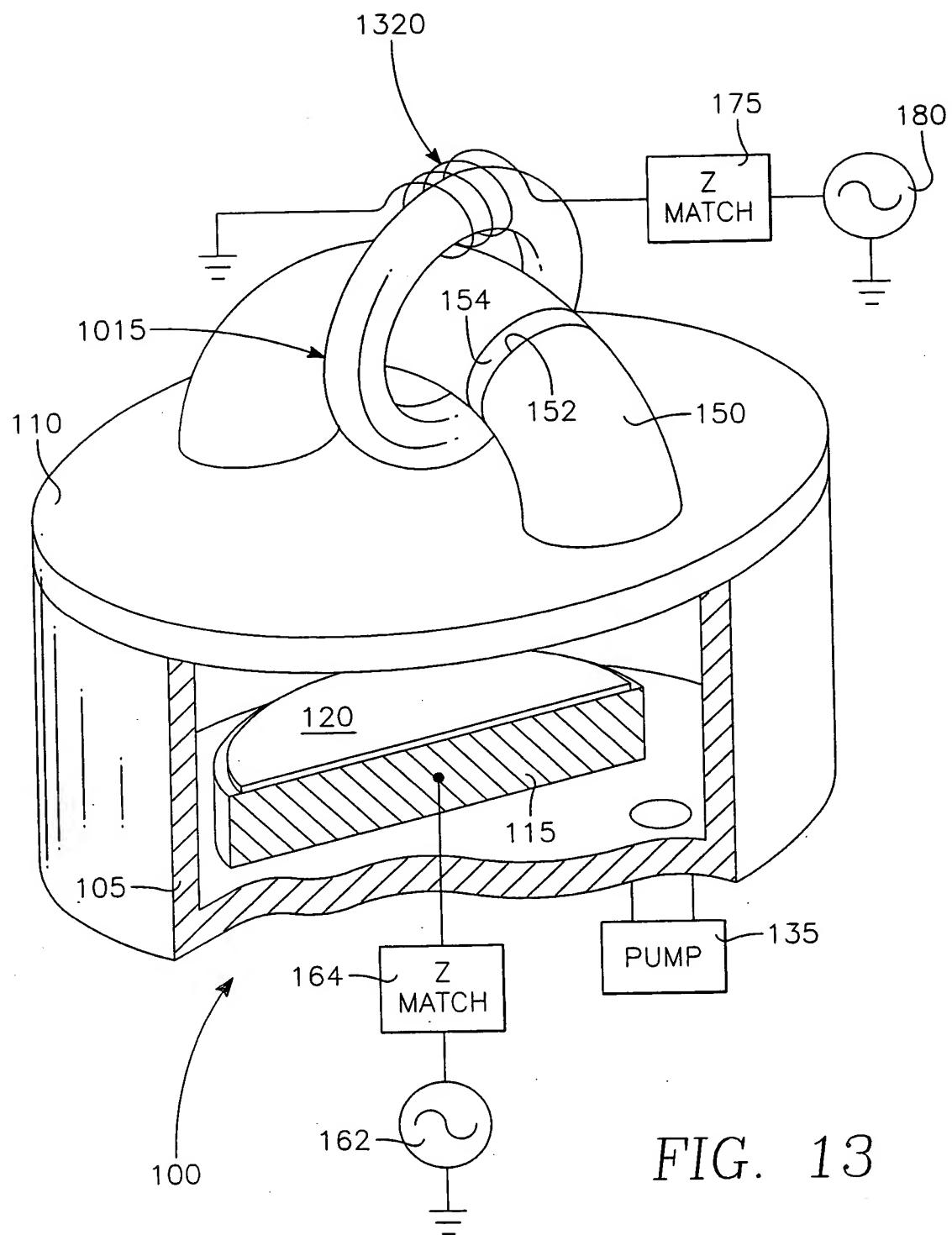


FIG. 13

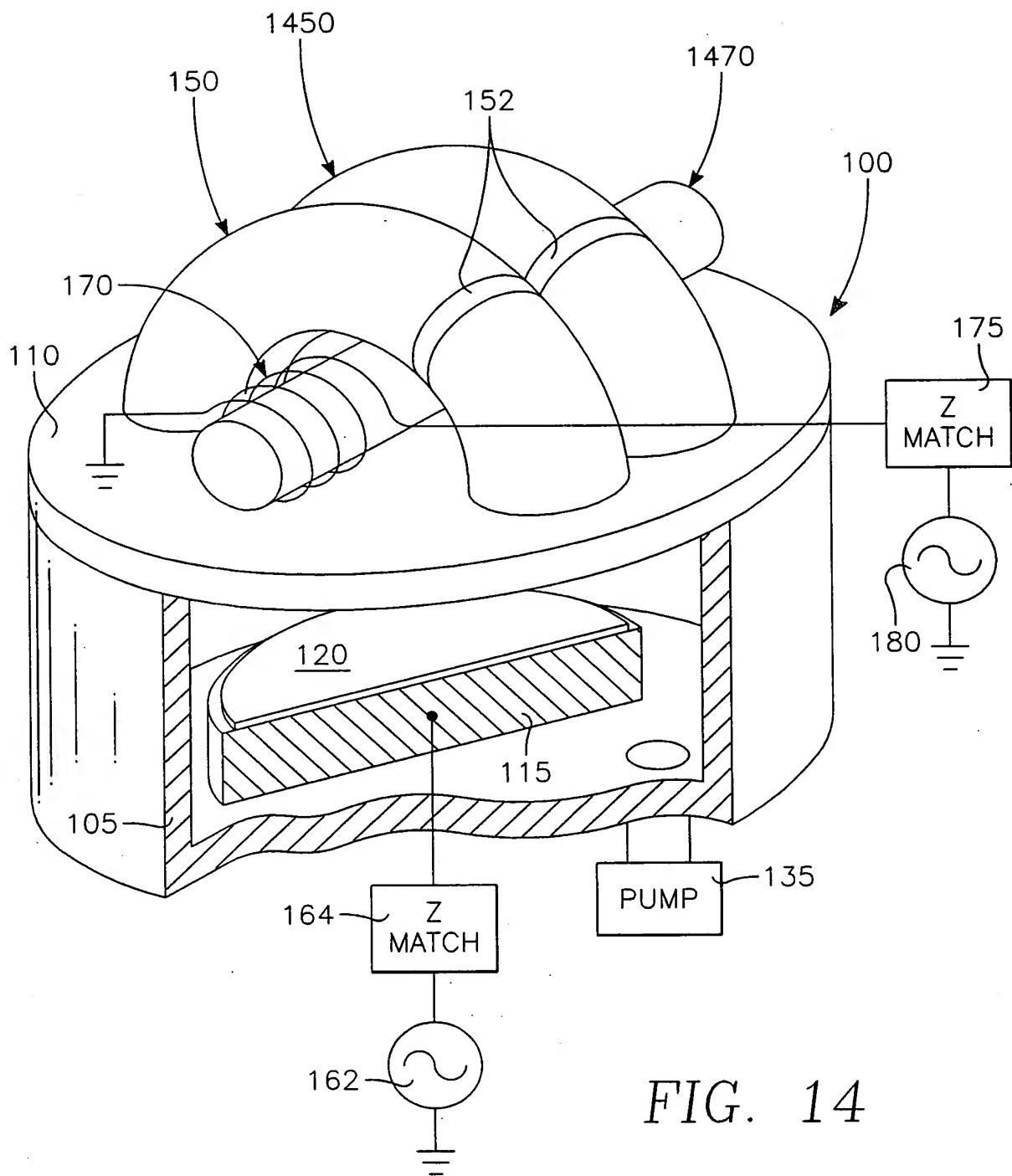
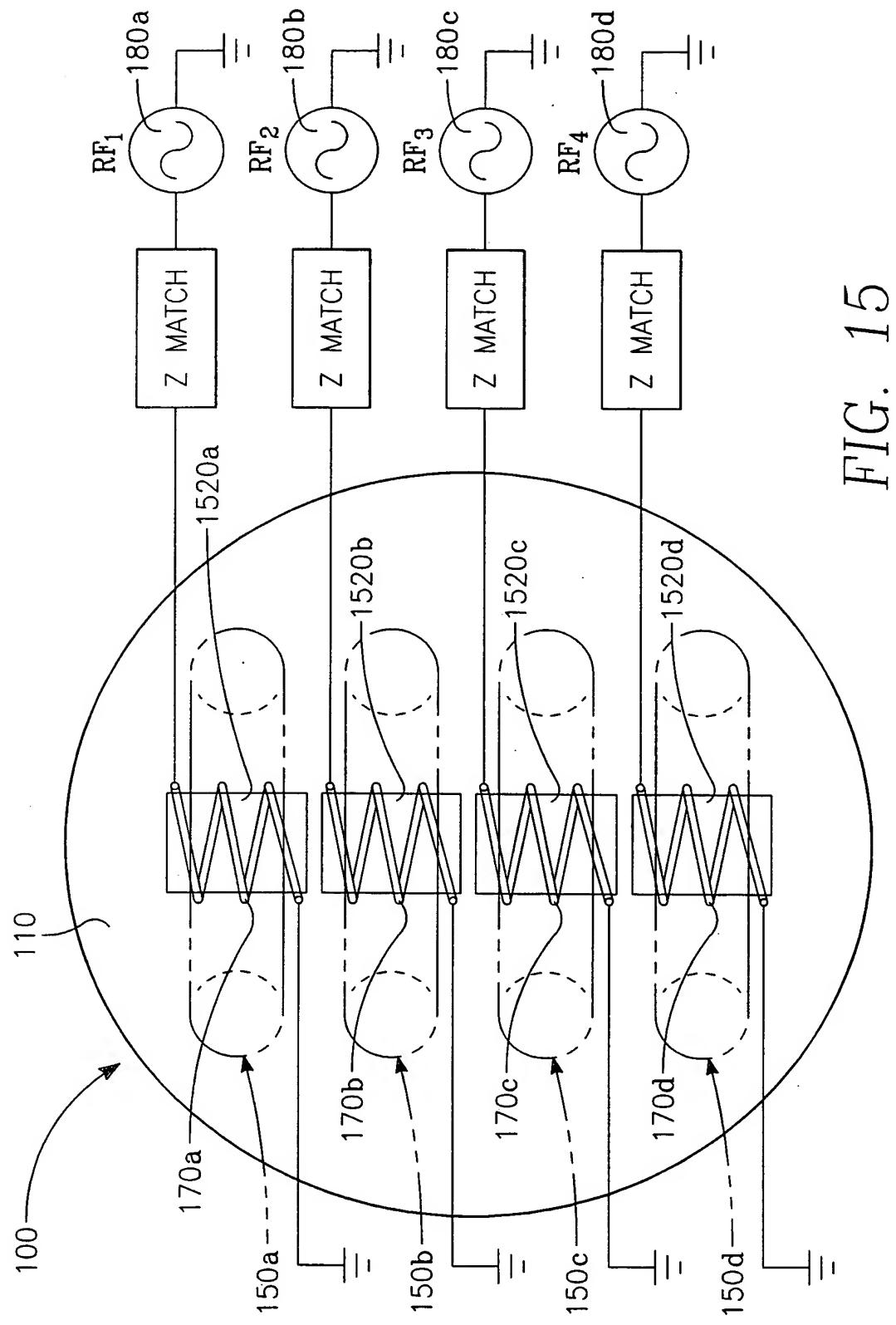


FIG. 14



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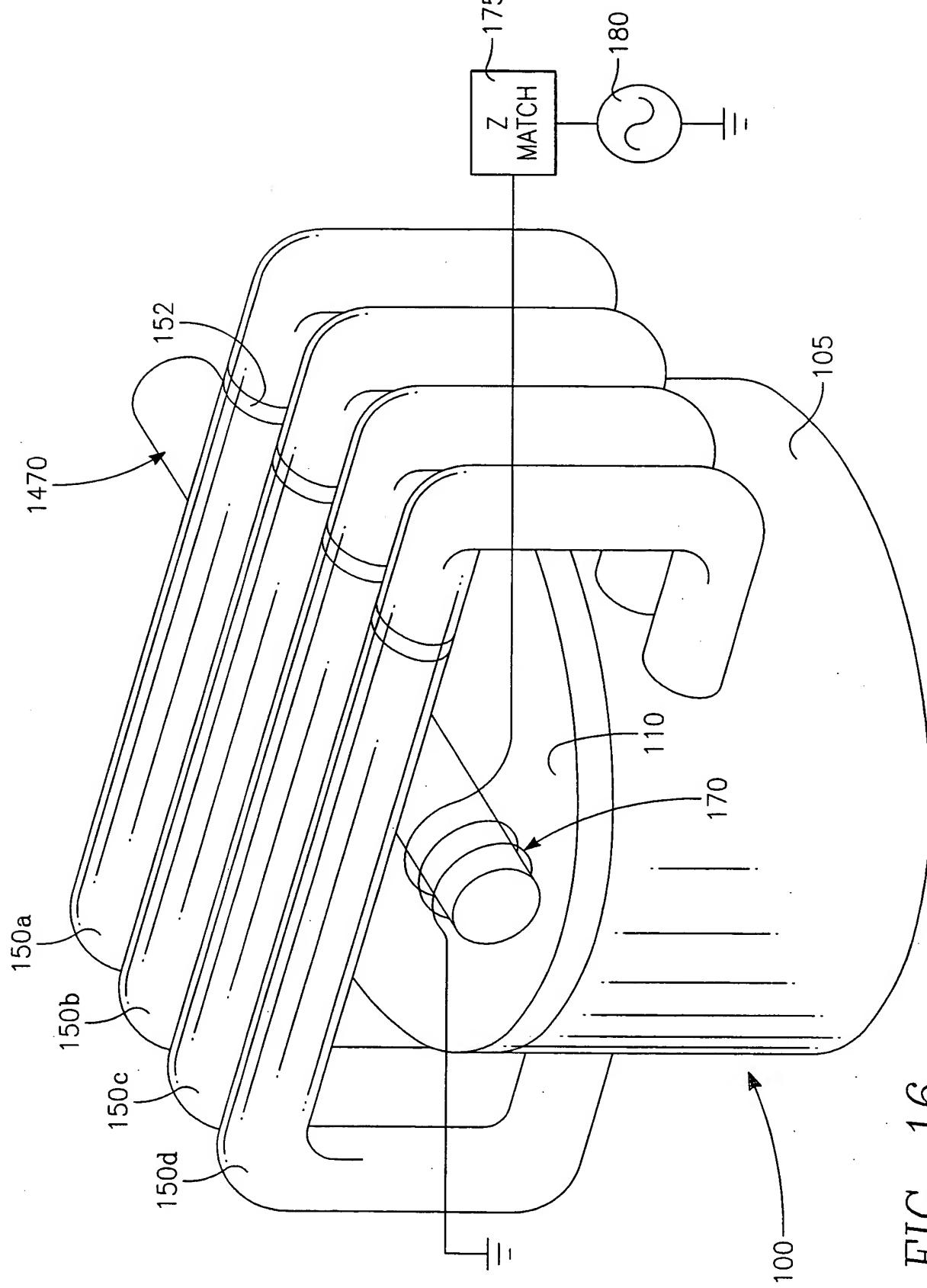


FIG. 16

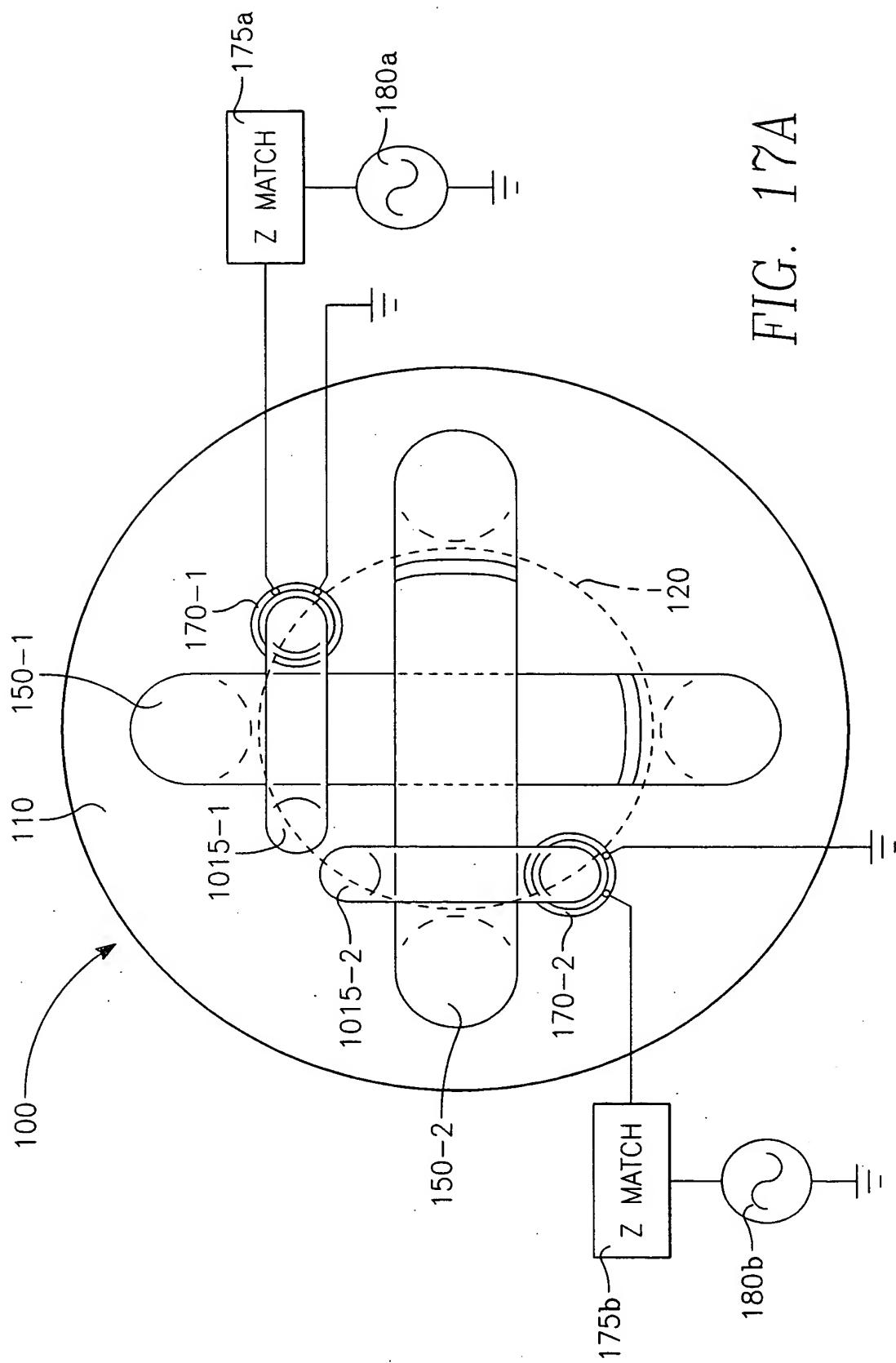


FIG. 17A

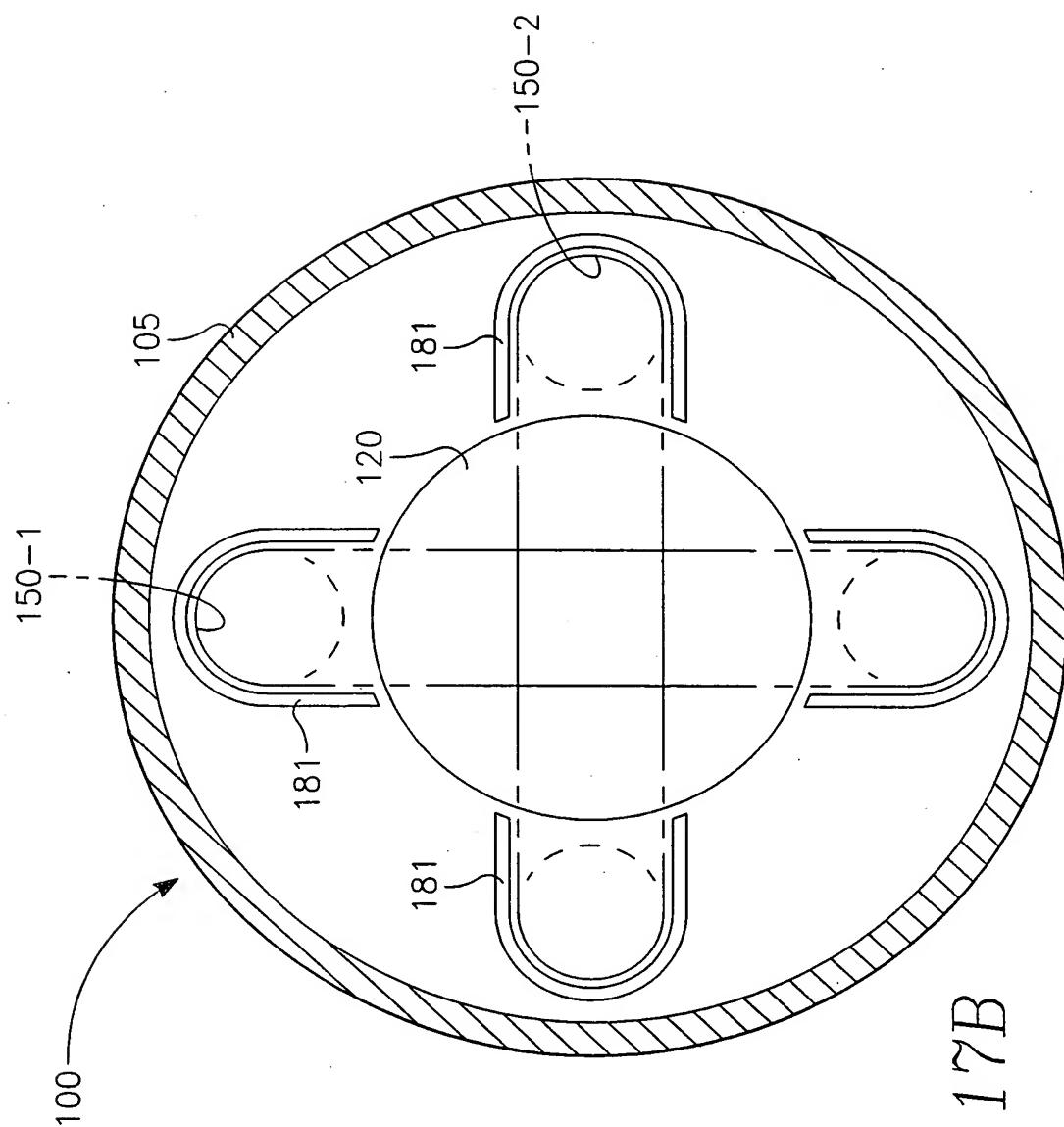


FIG. 17B

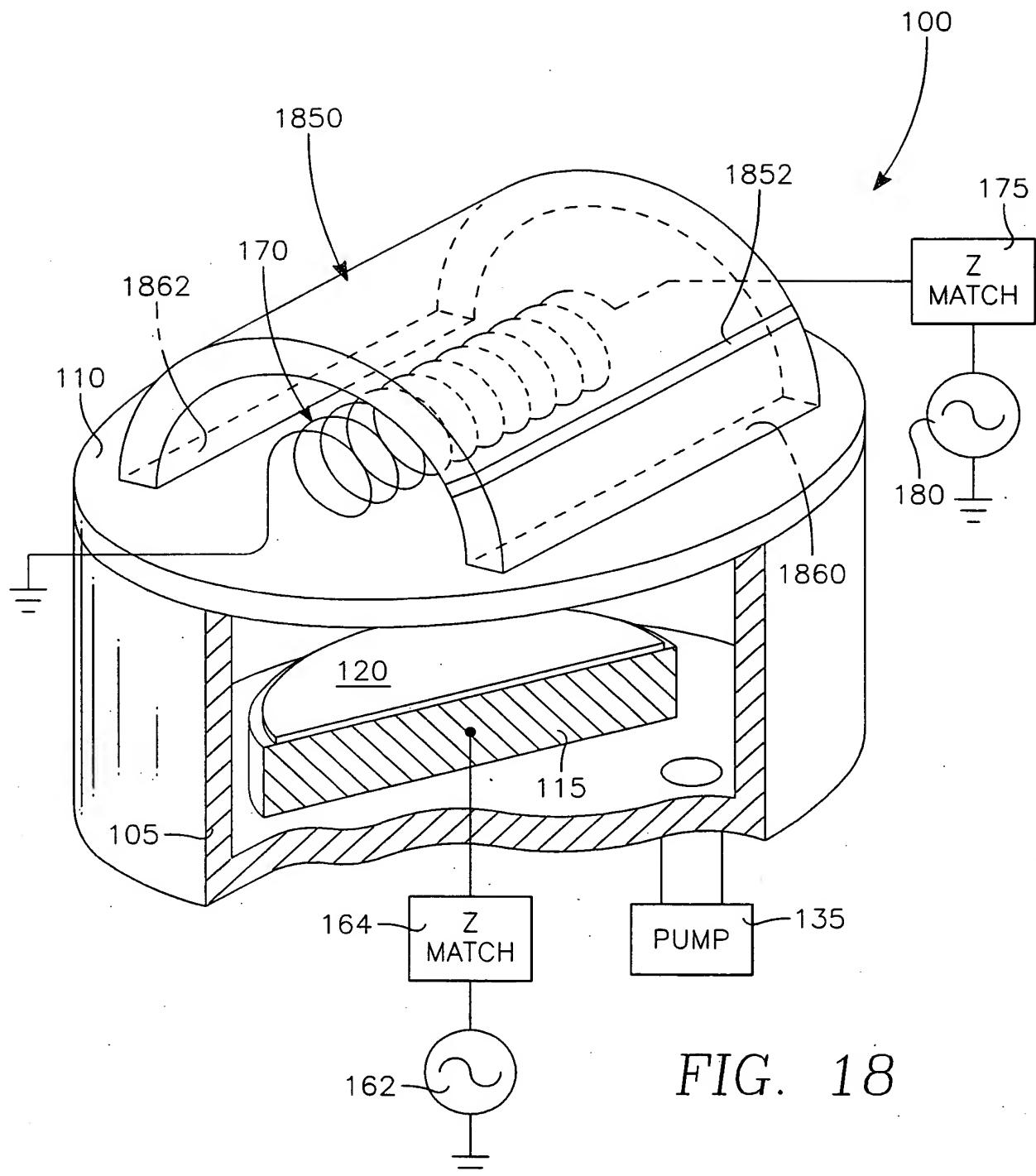


FIG. 18

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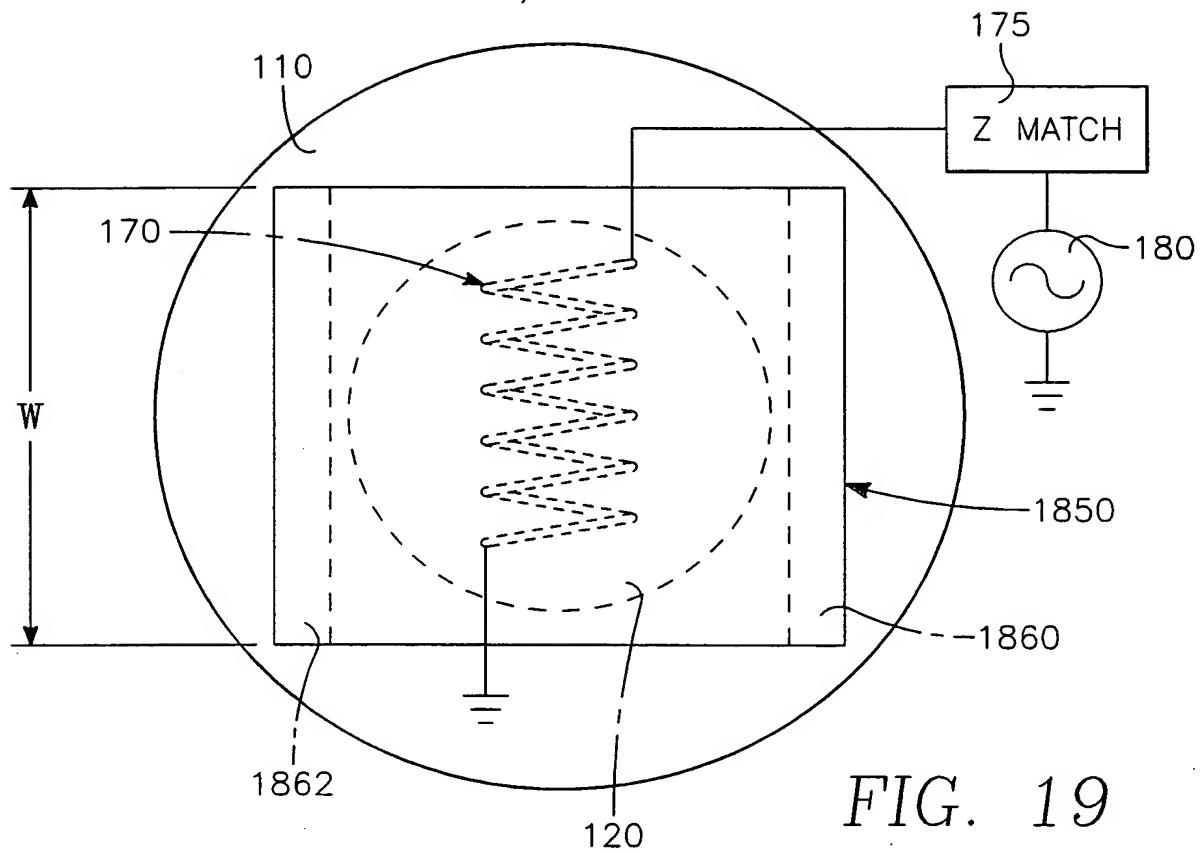


FIG. 19

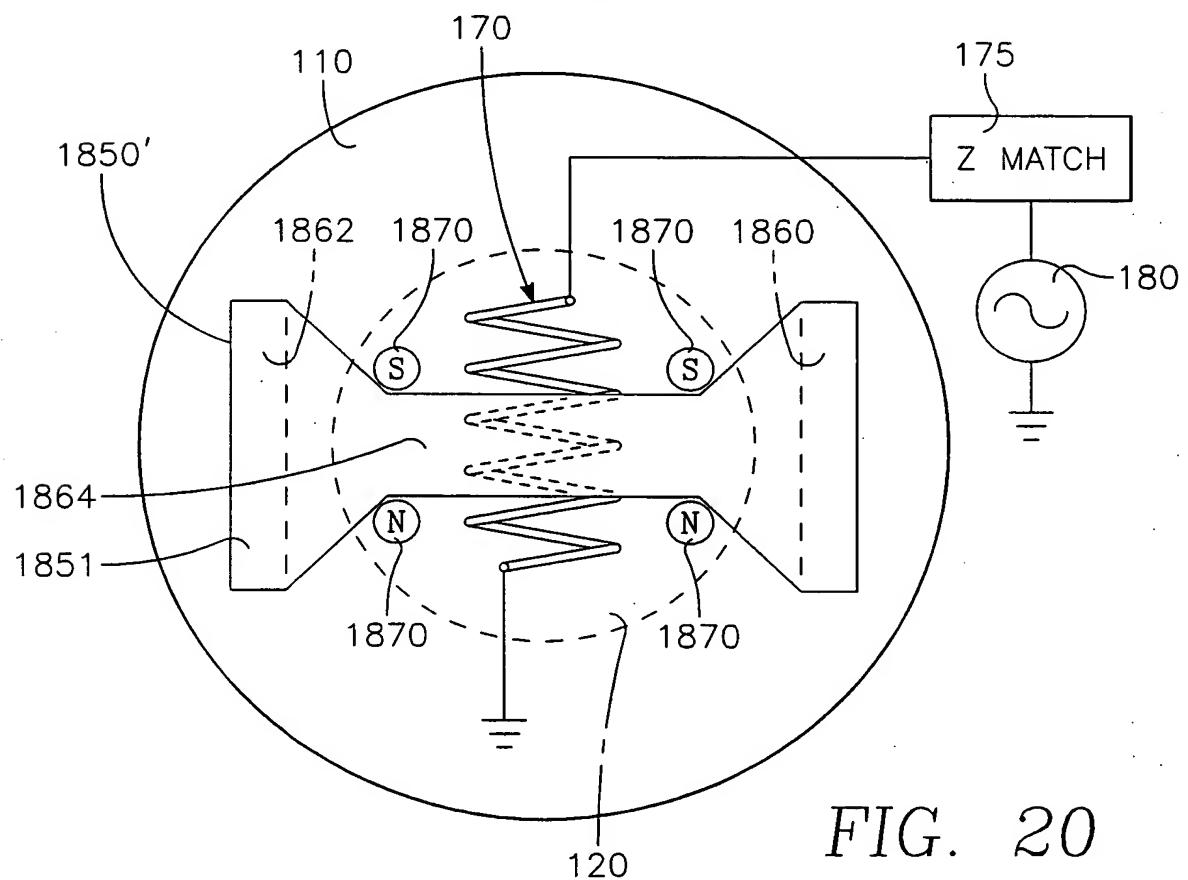


FIG. 20

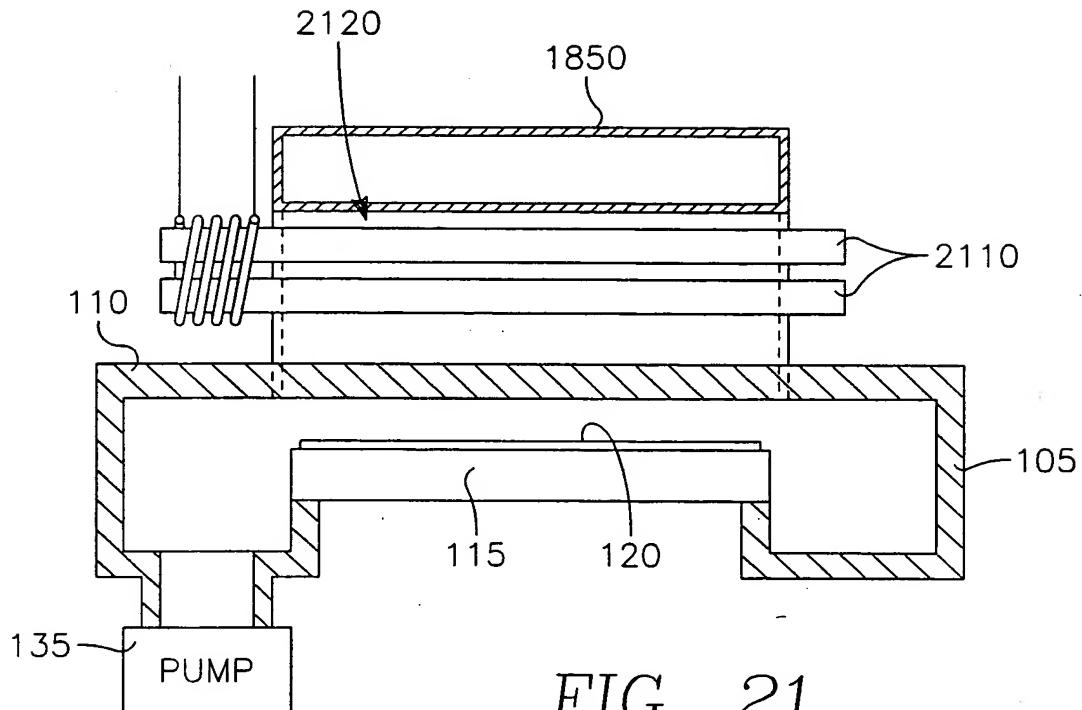


FIG. 21

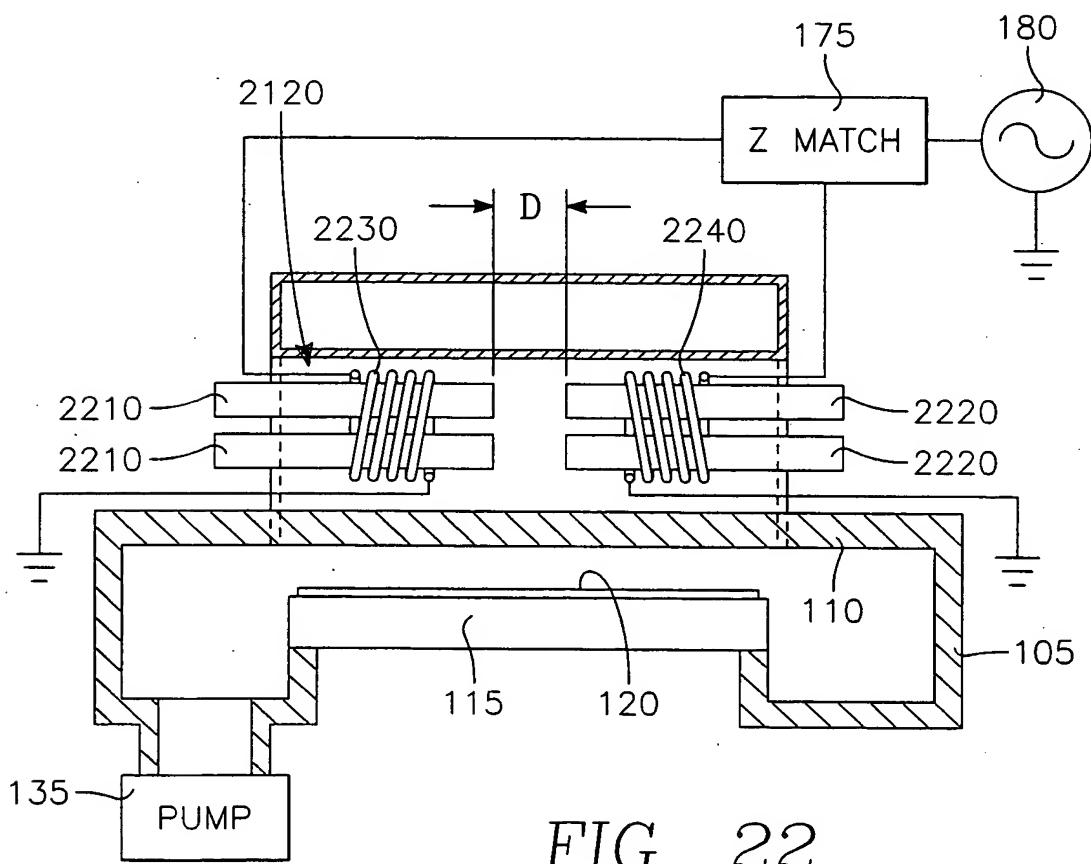


FIG. 22

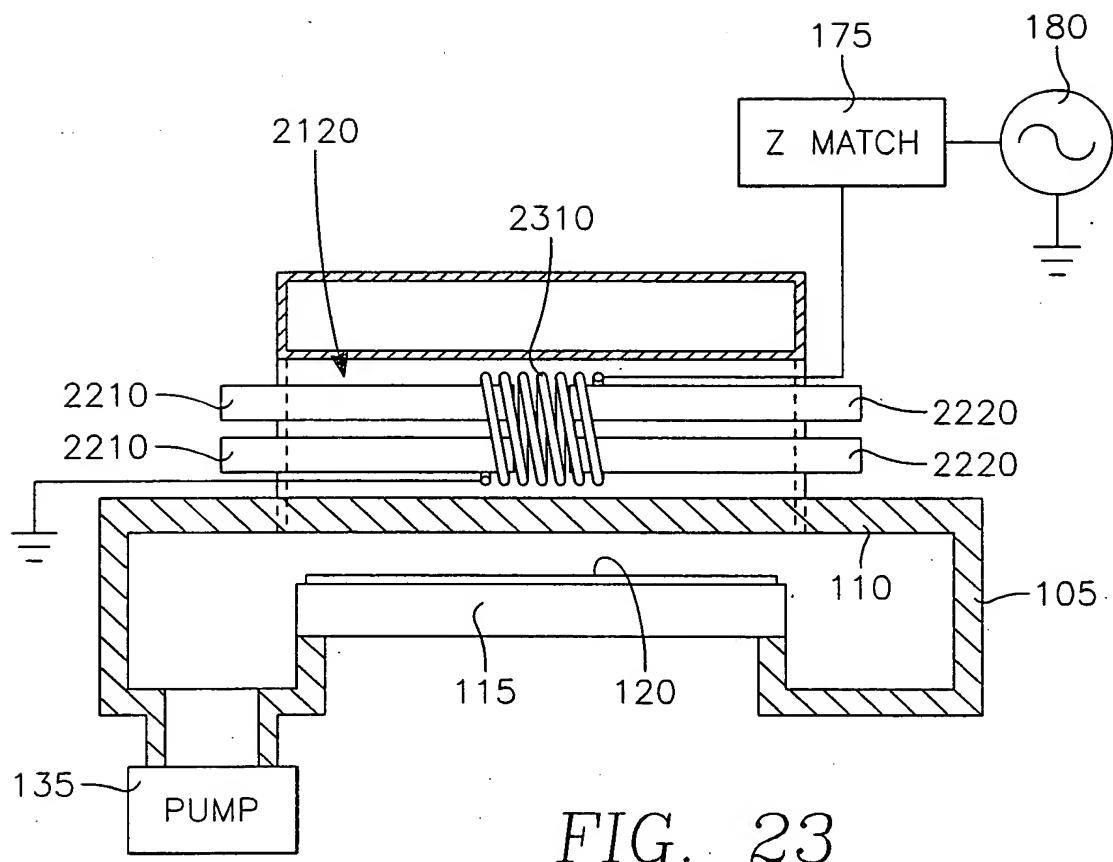


FIG. 23

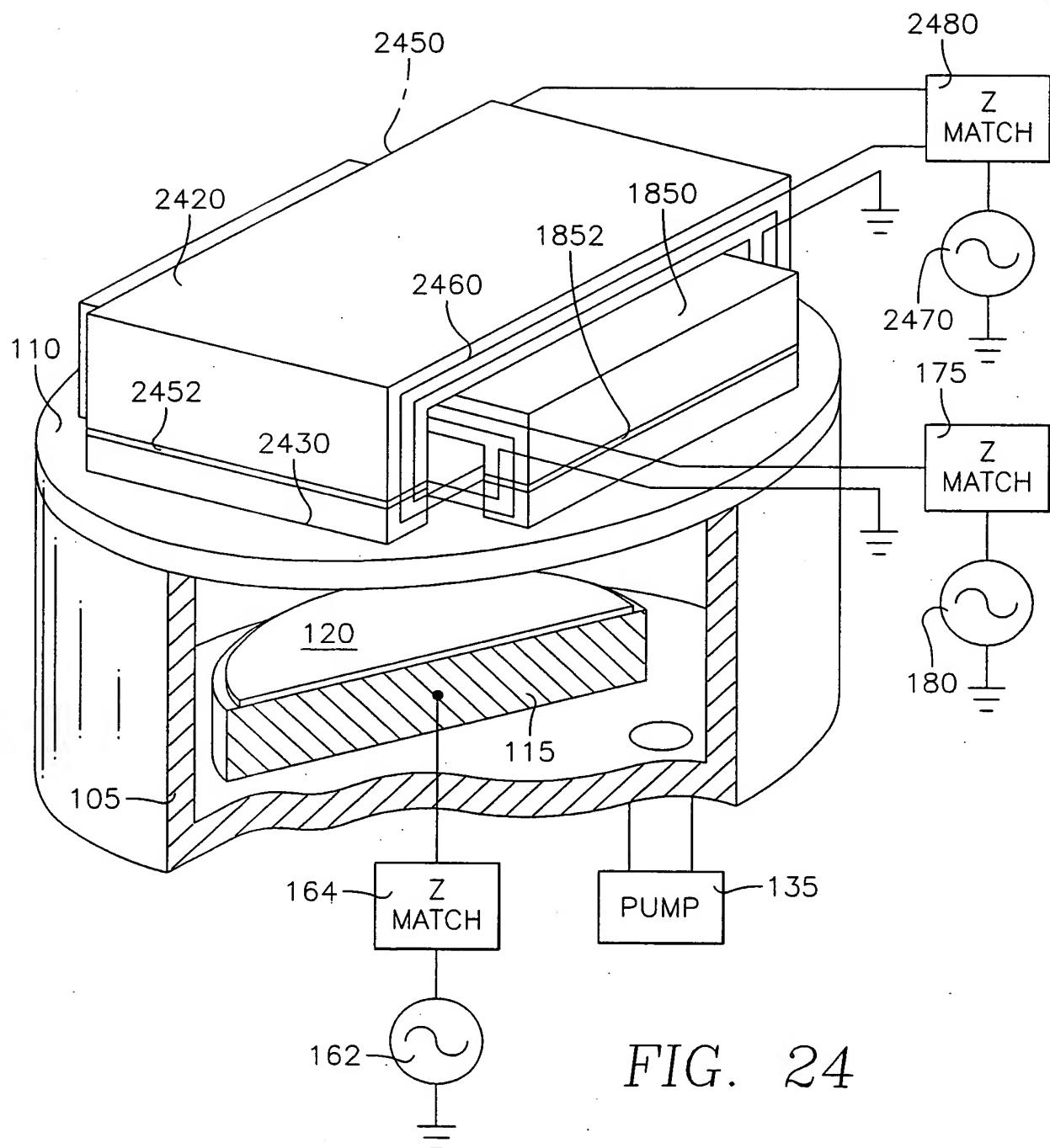
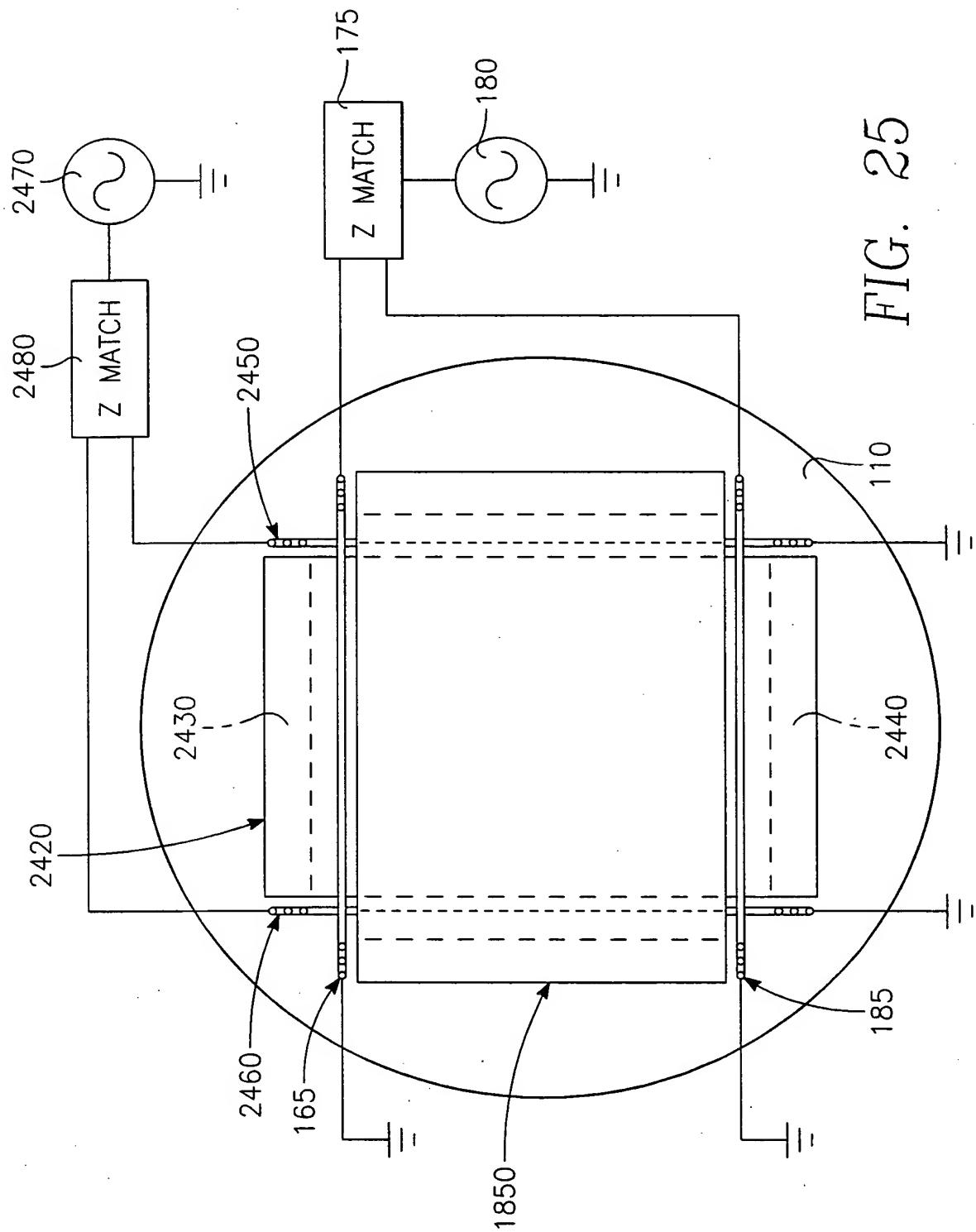
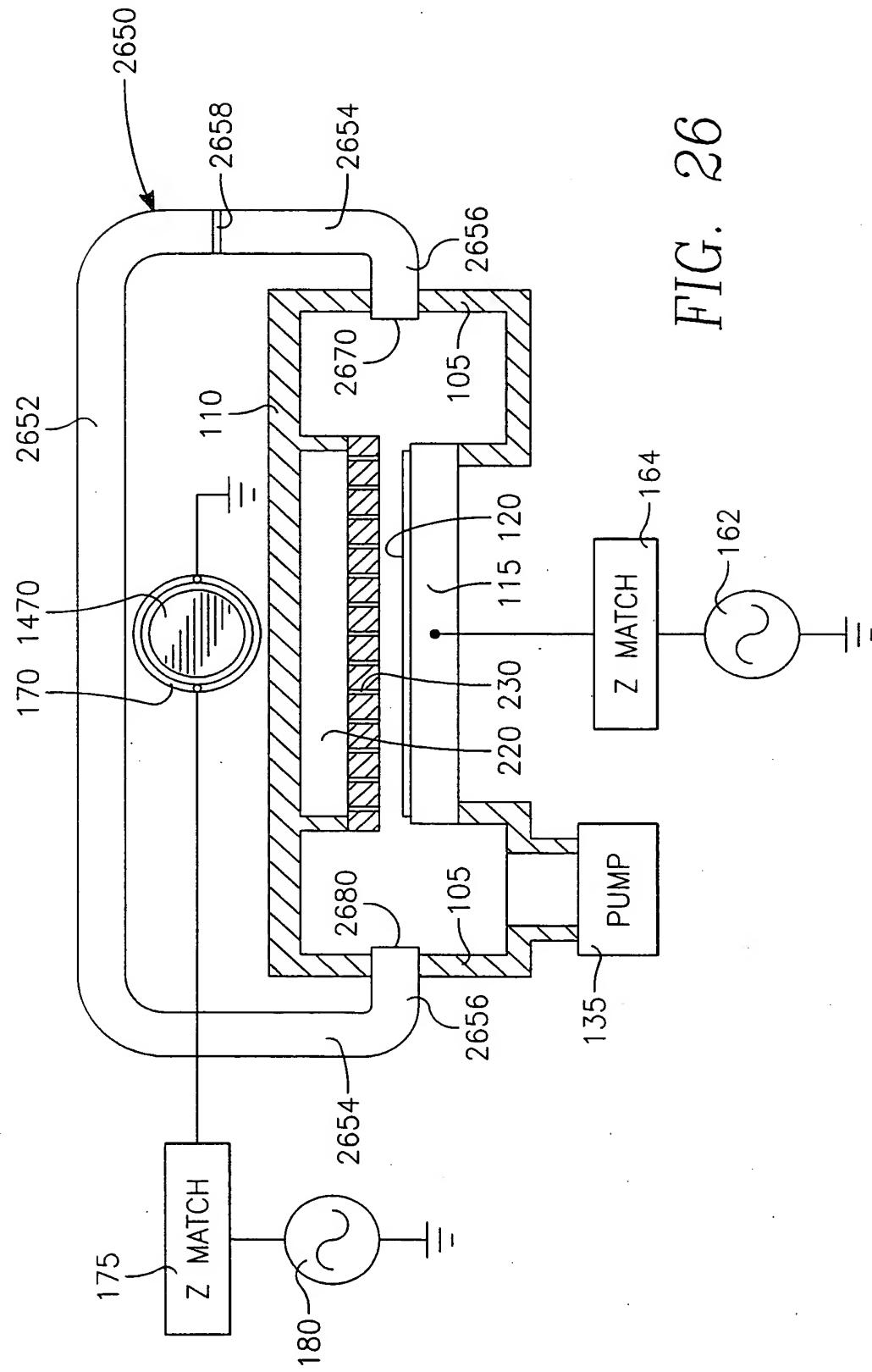


FIG. 24





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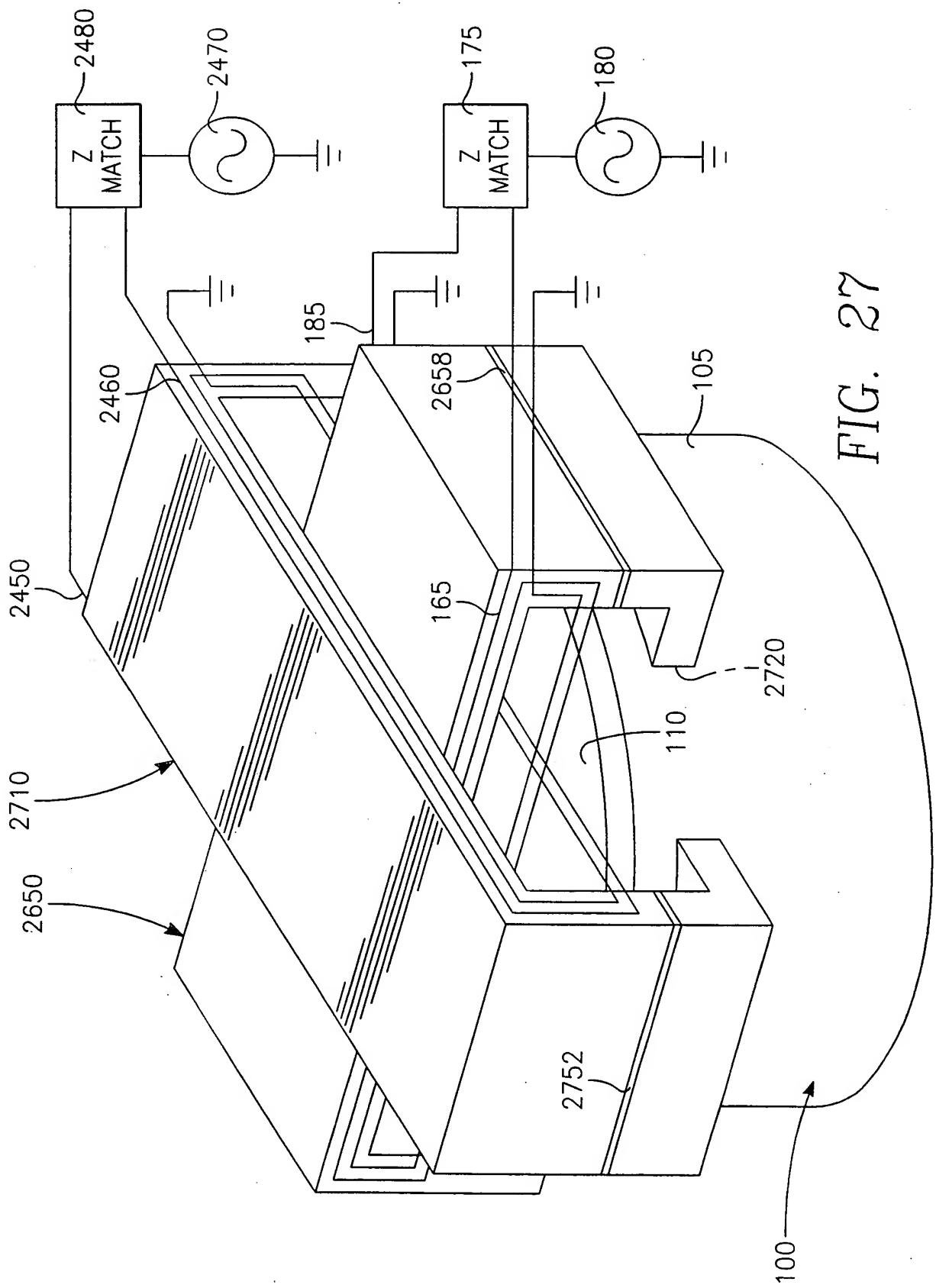
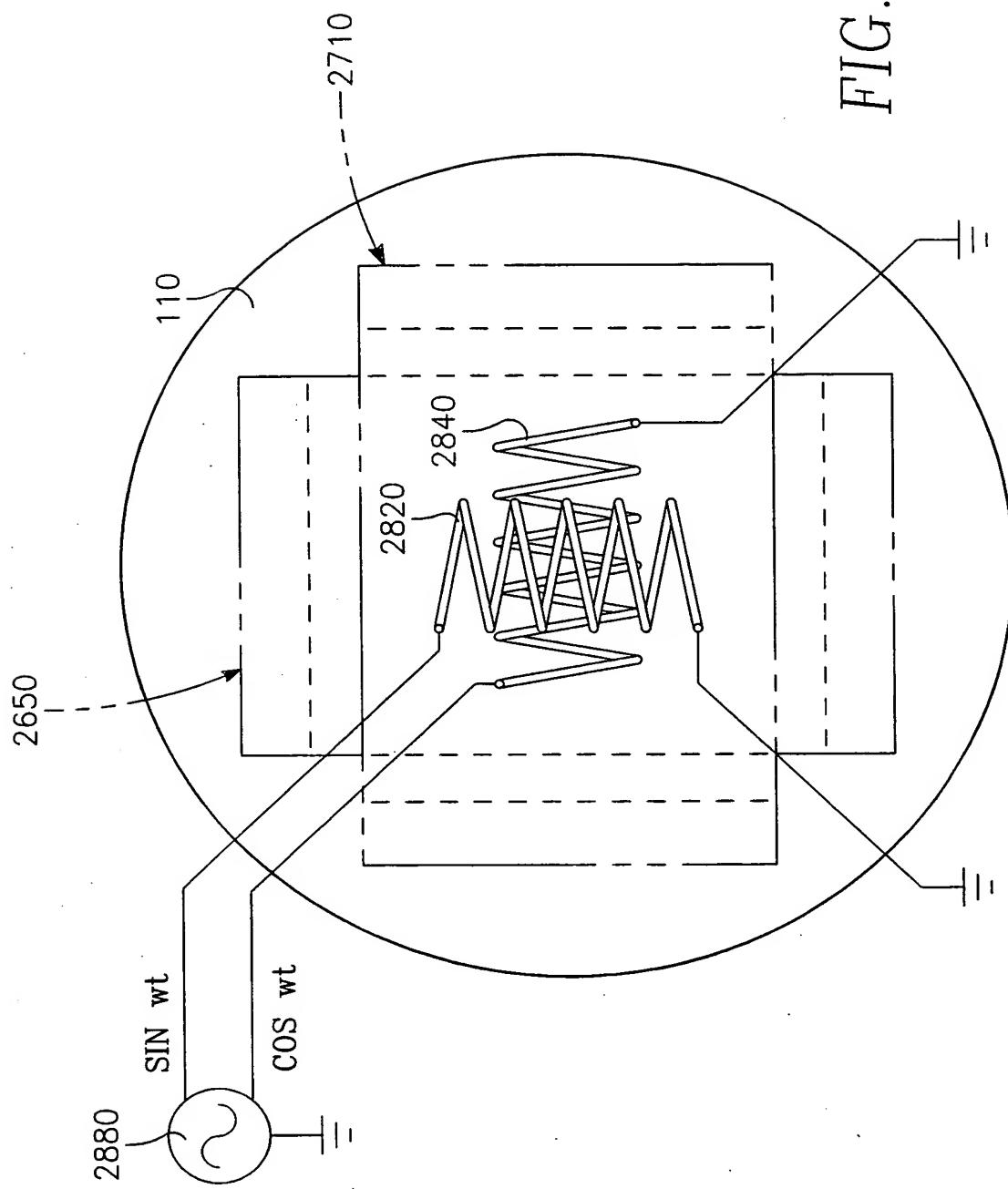


FIG. 28A



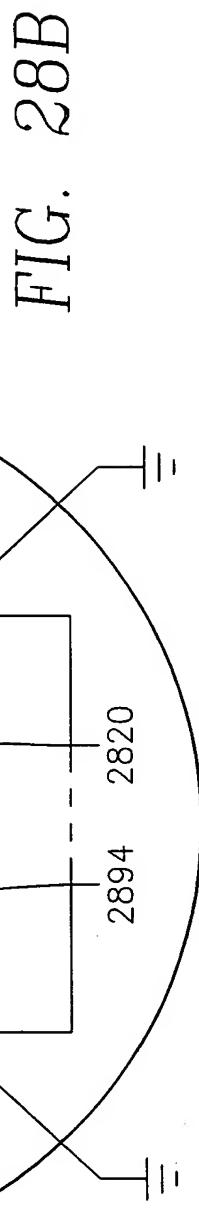
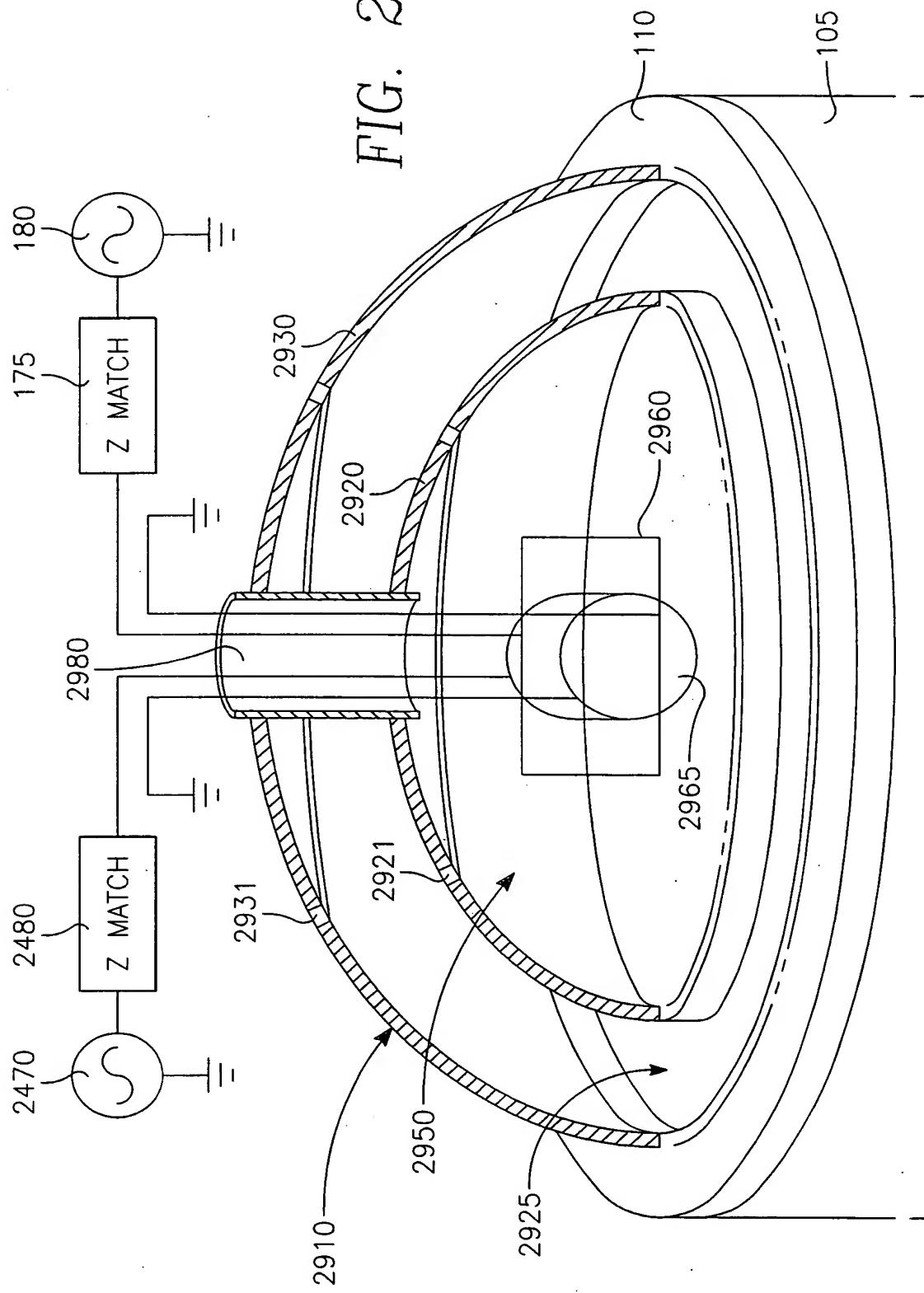


FIG. 29



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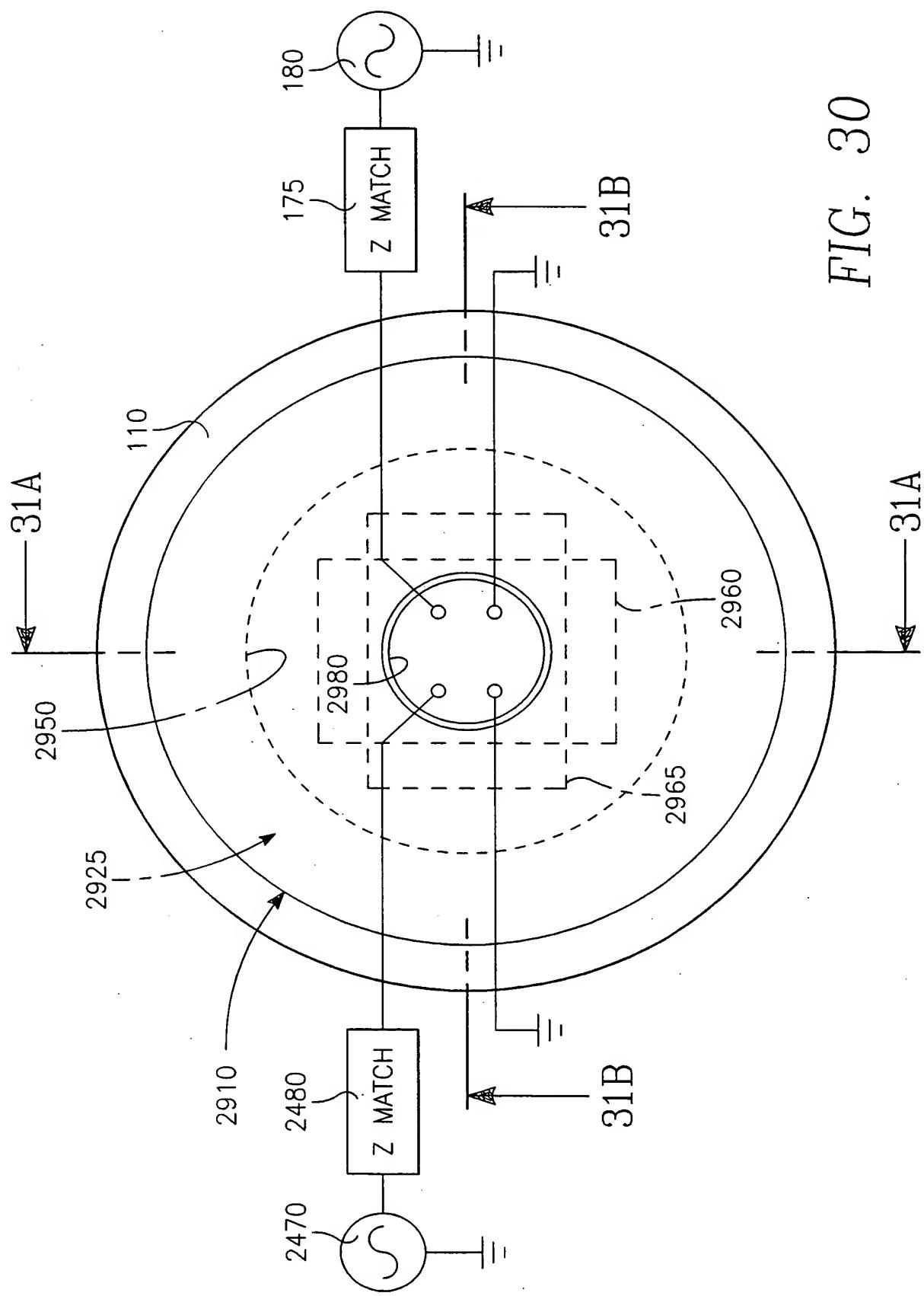


FIG. 30

31A

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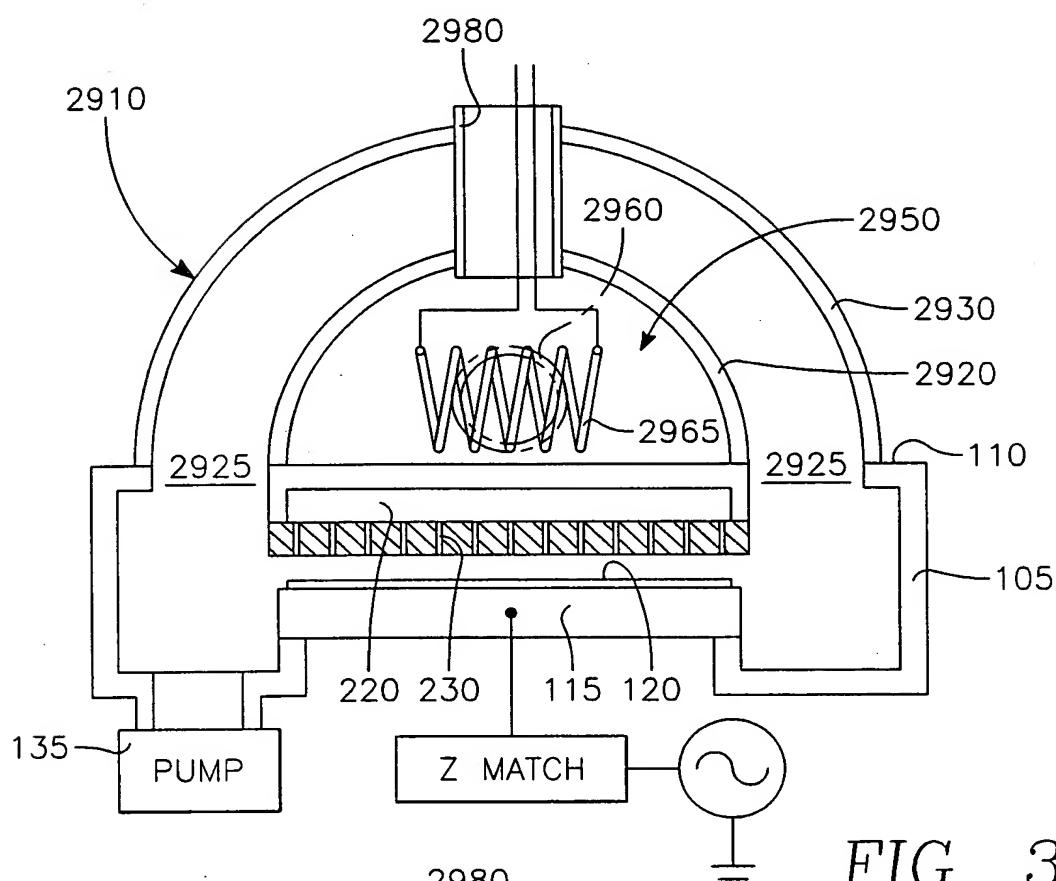


FIG. 31A

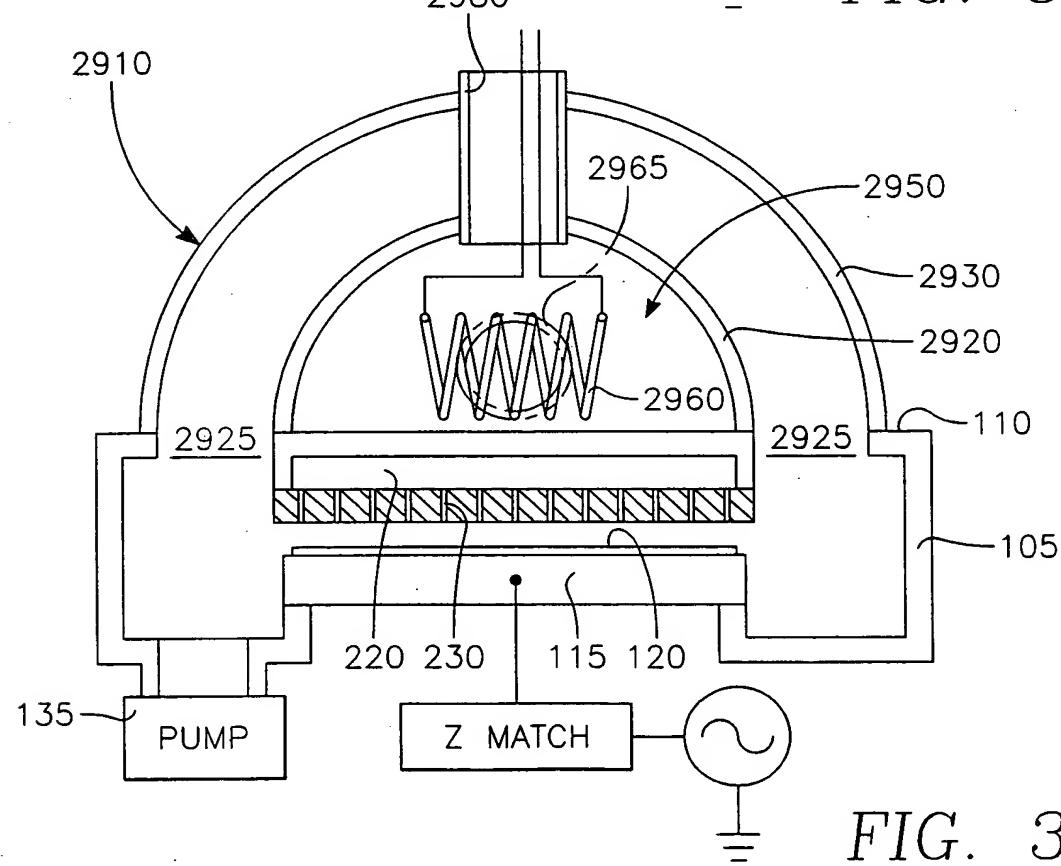


FIG. 31B

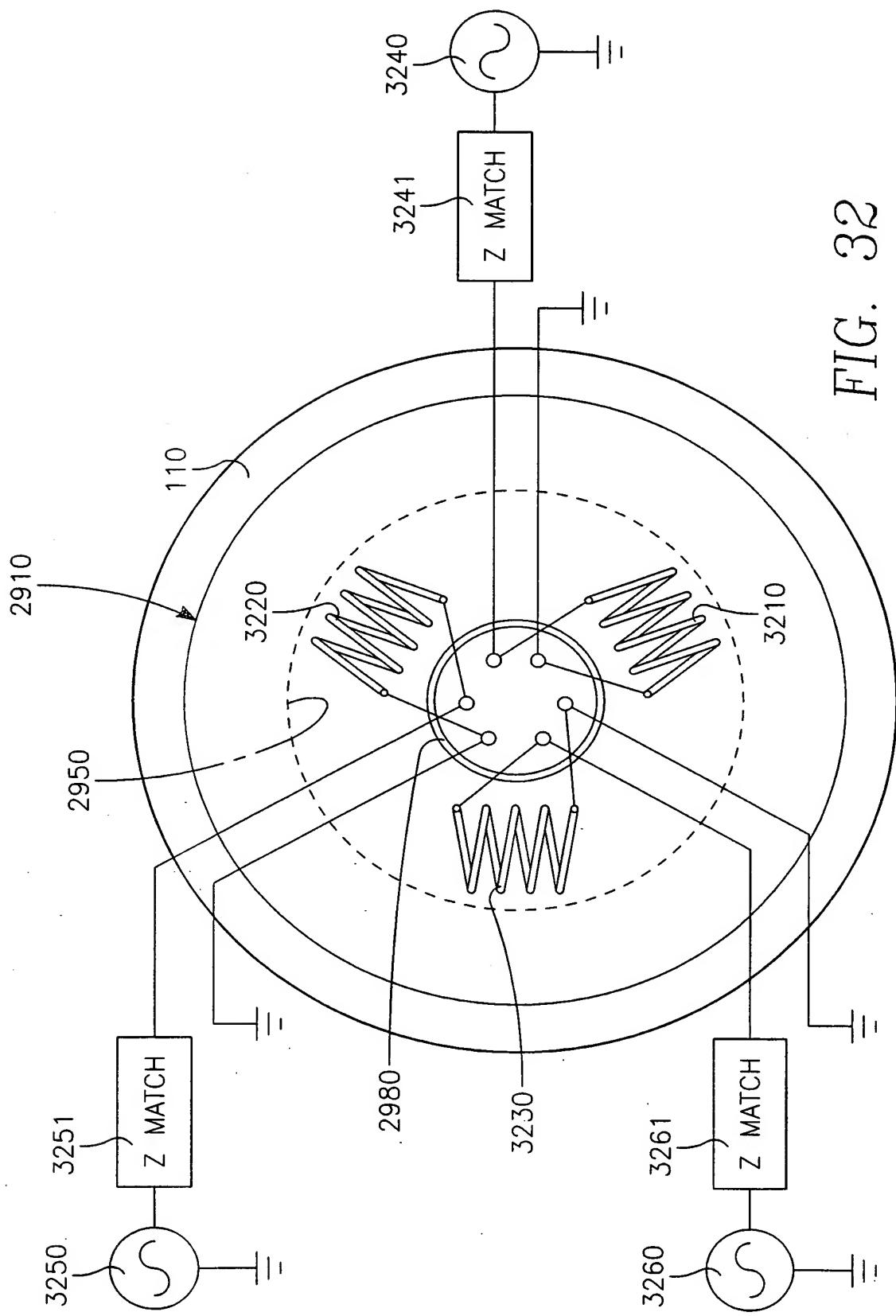


FIG. 32

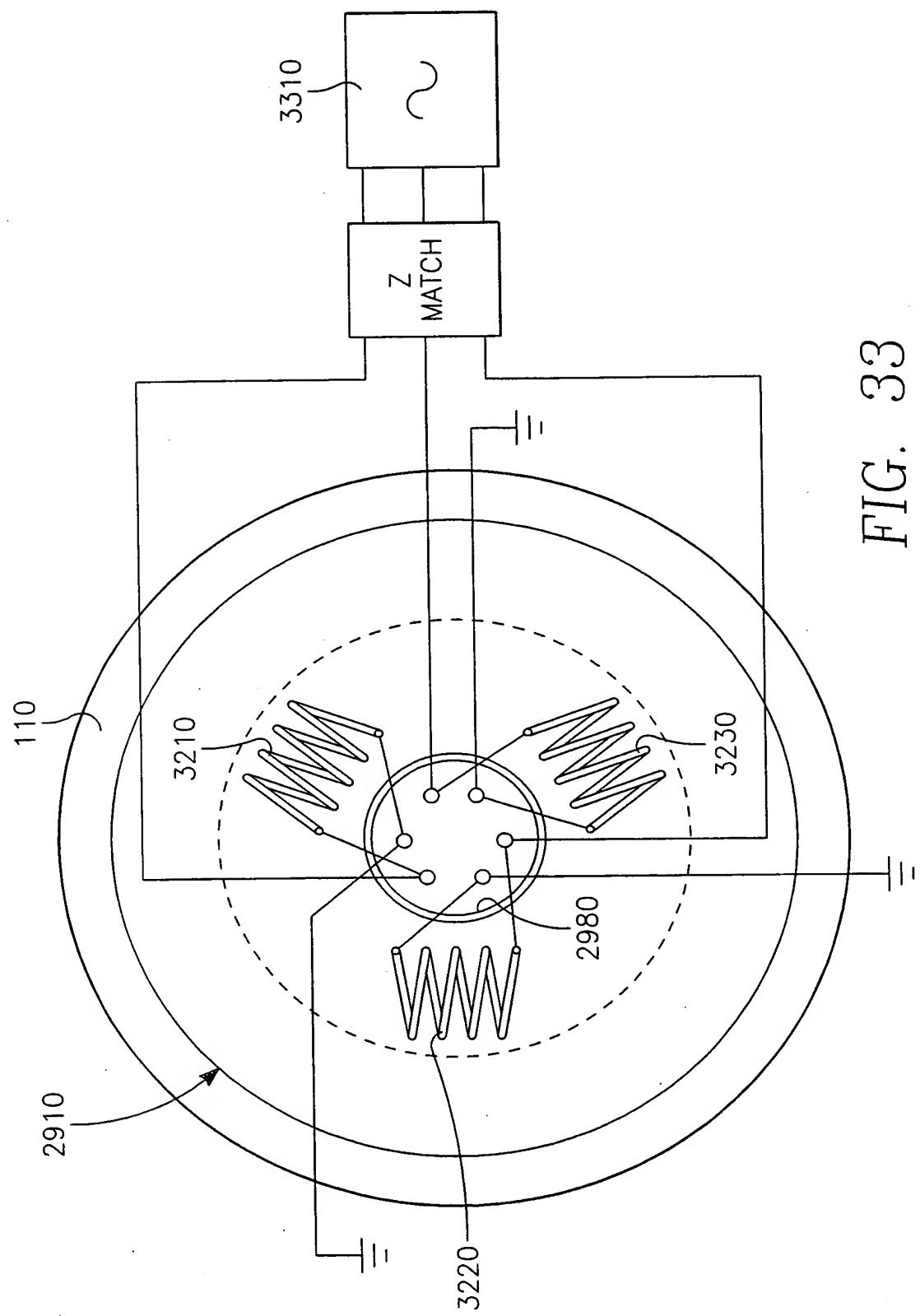
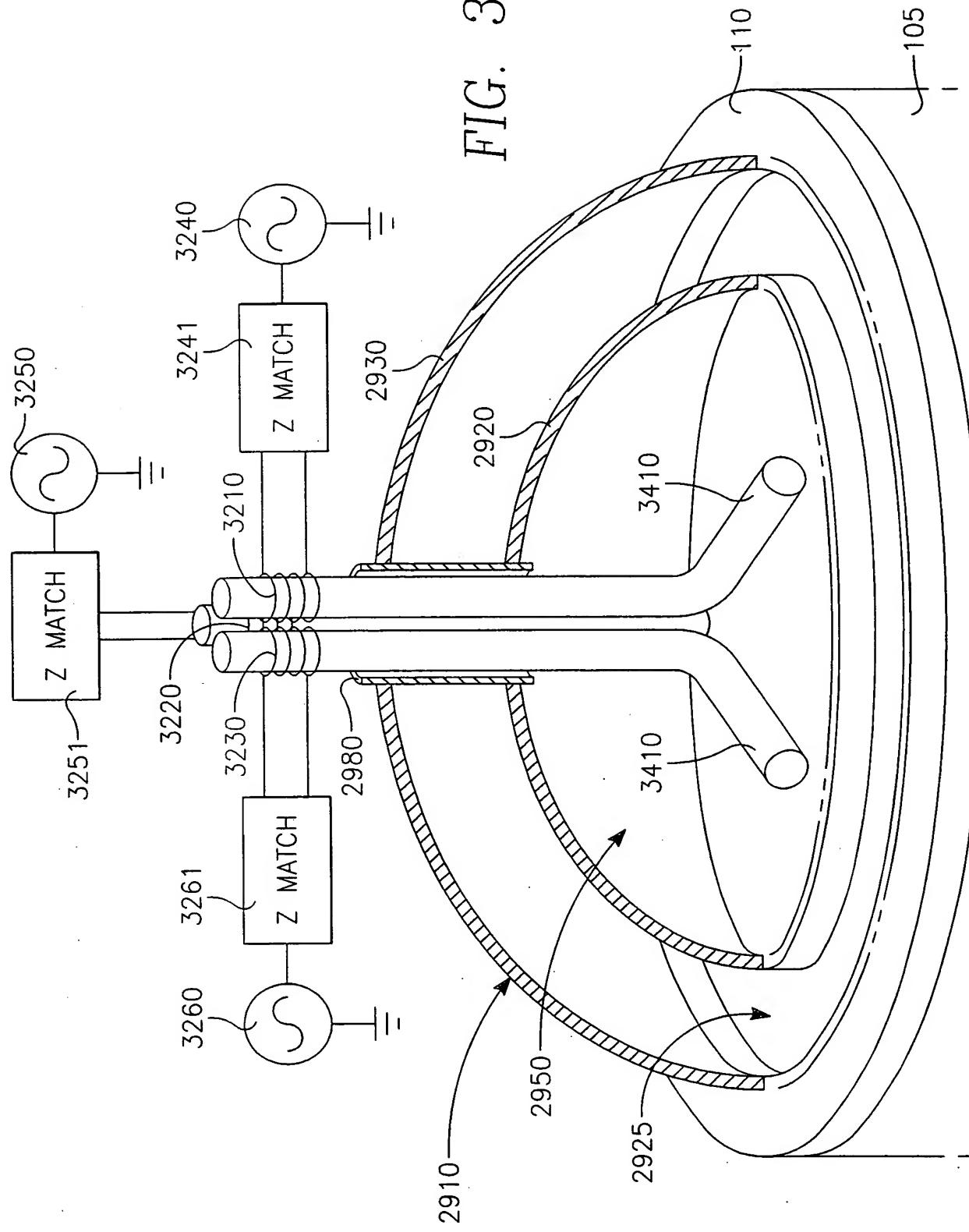
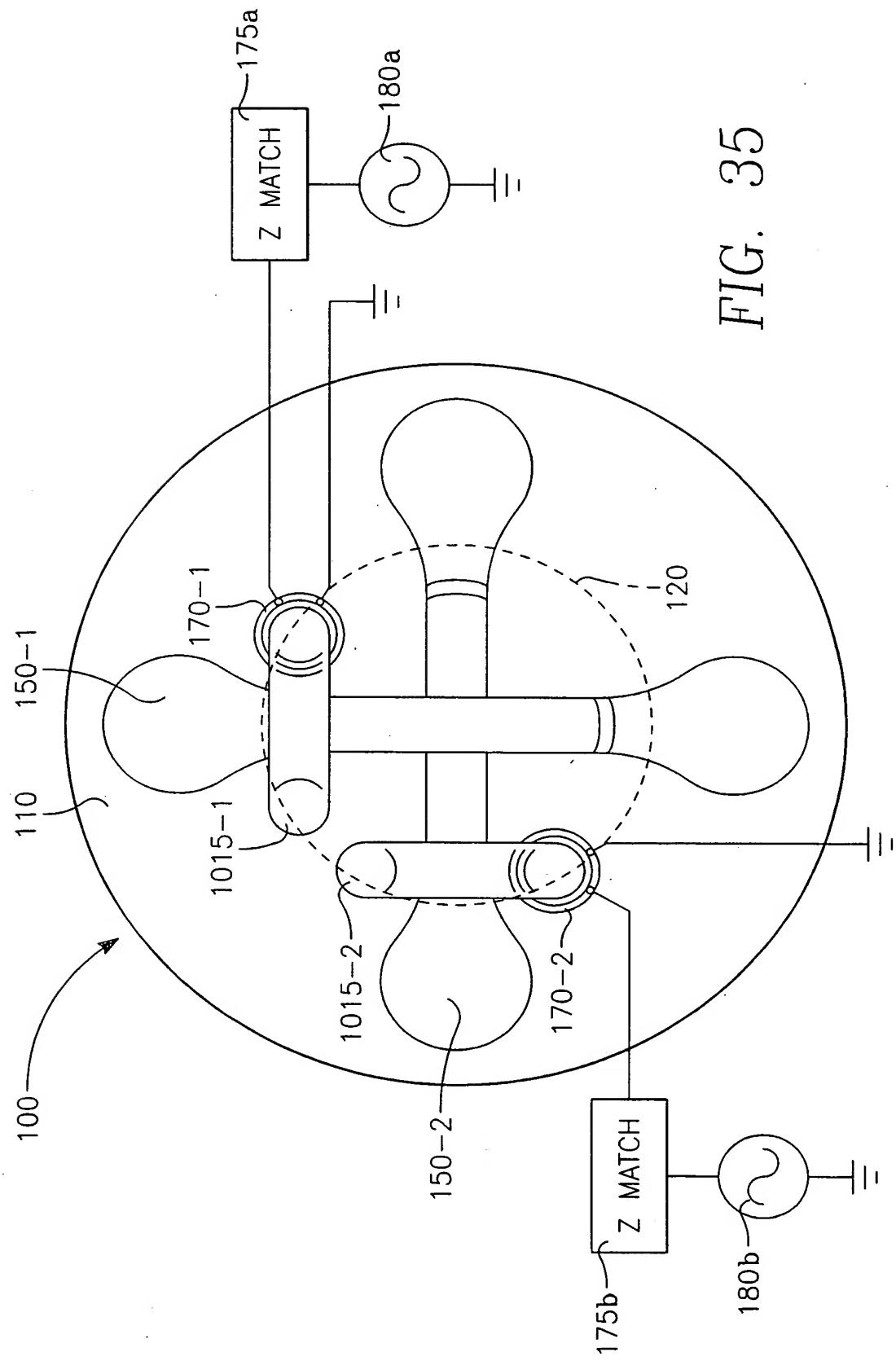


FIG. 34





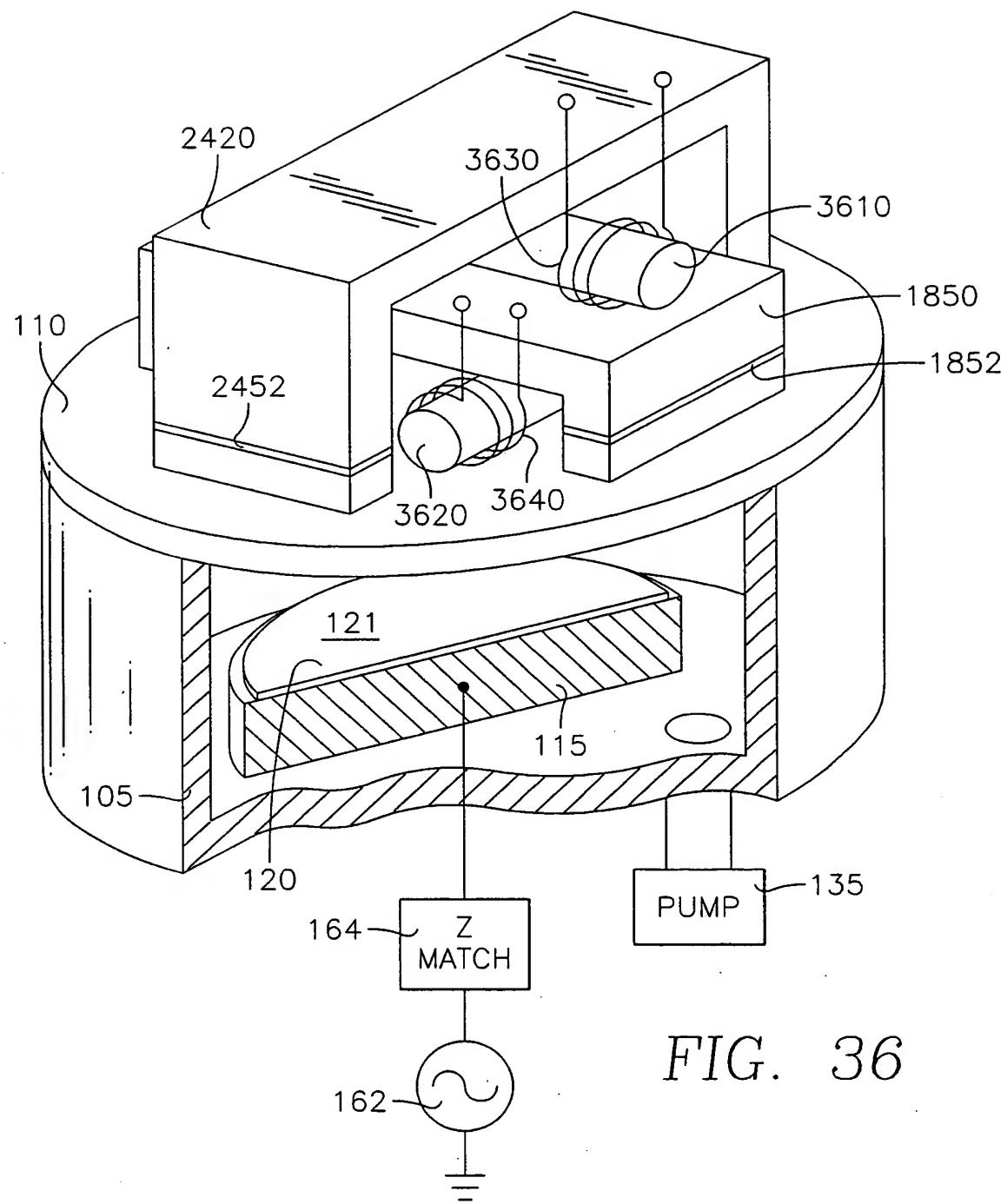


FIG. 36

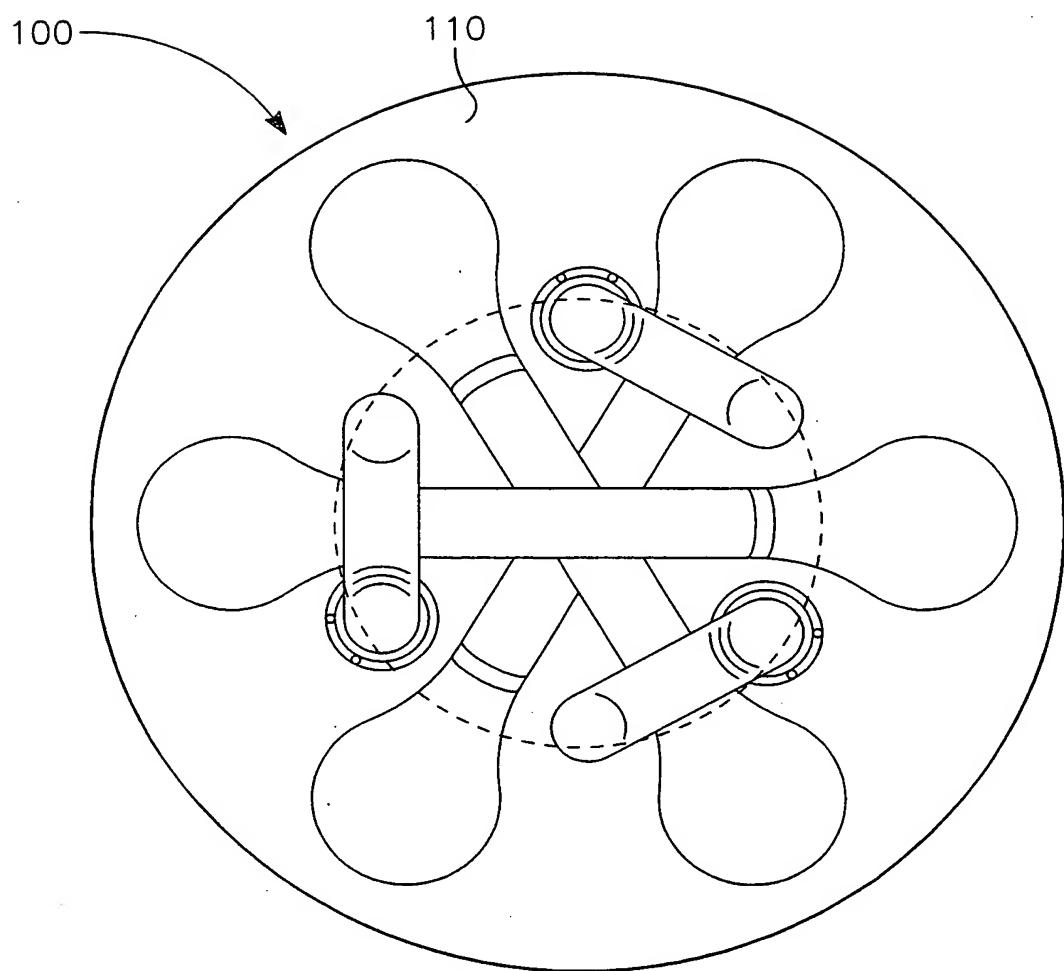


FIG. 37

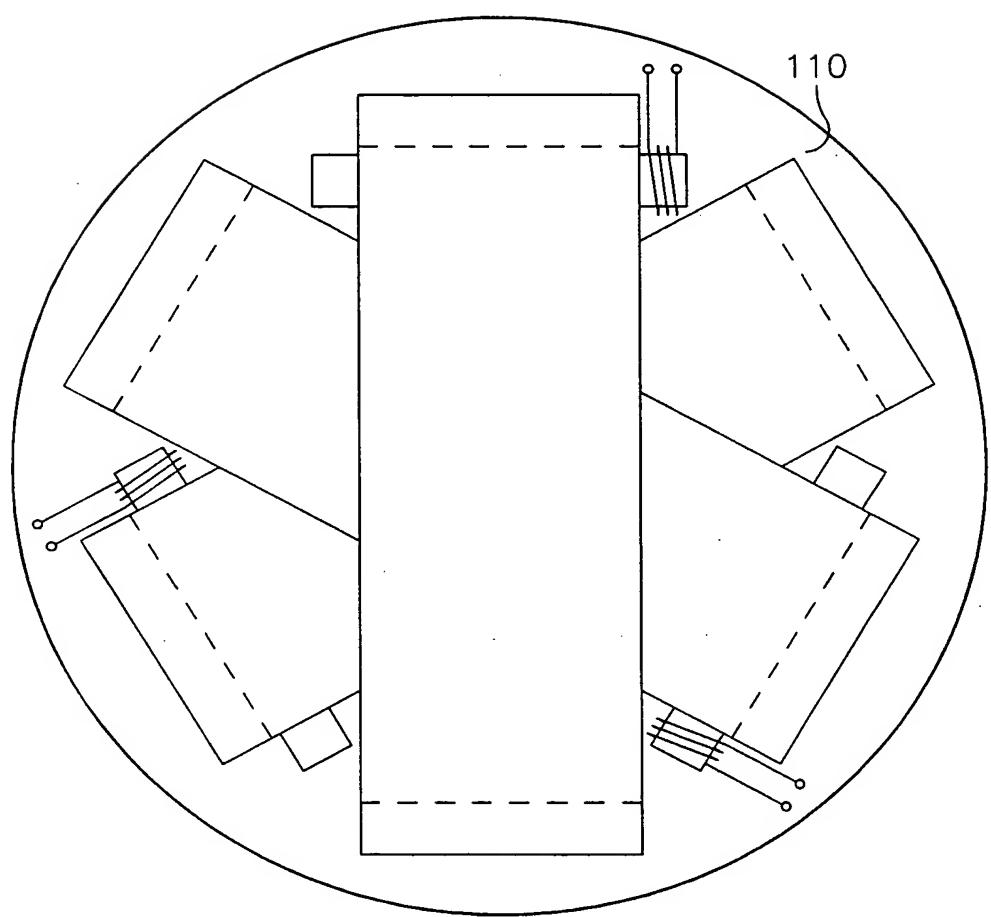


FIG. 38

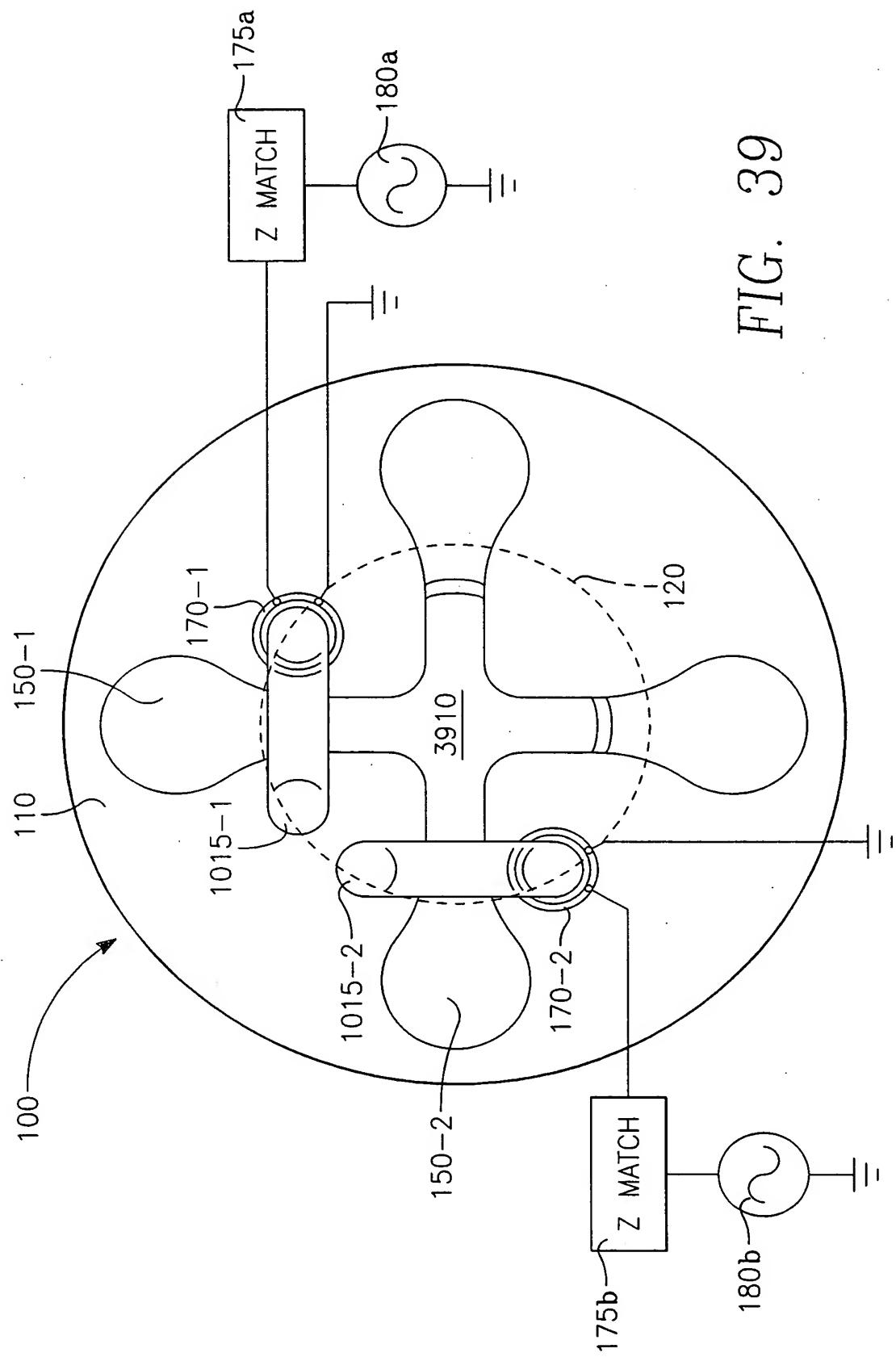


FIG. 39

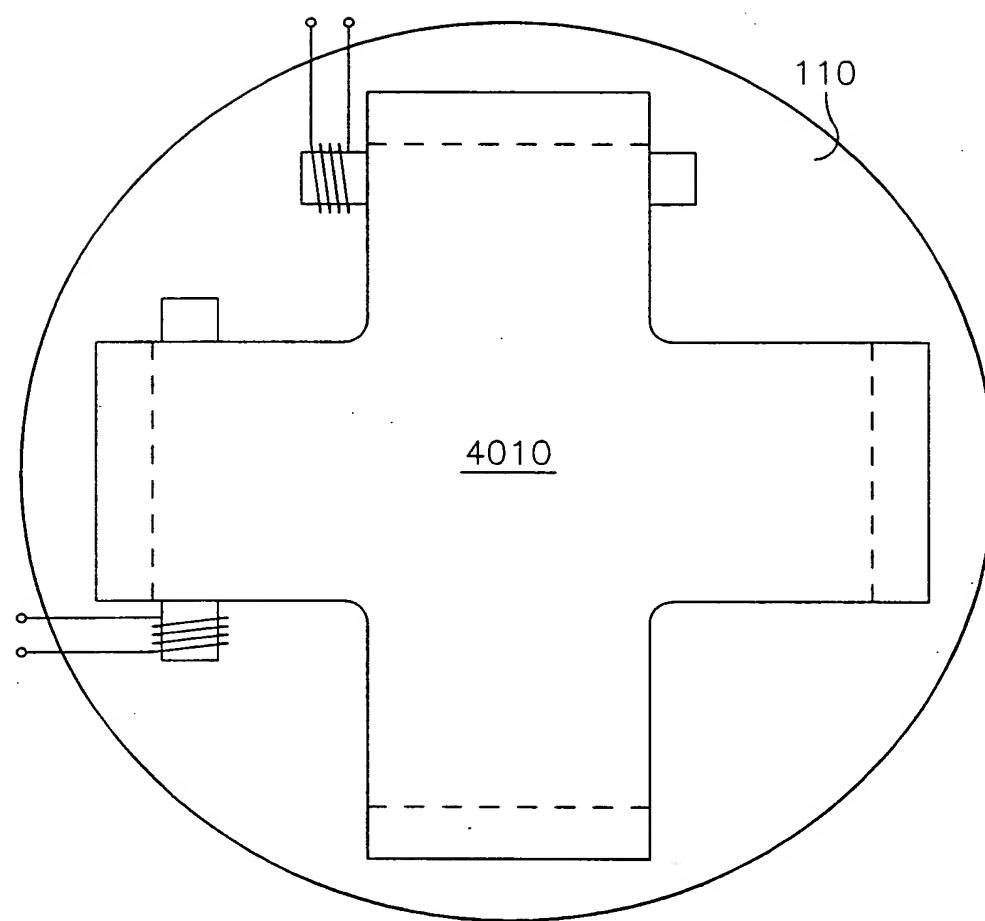


FIG. 40

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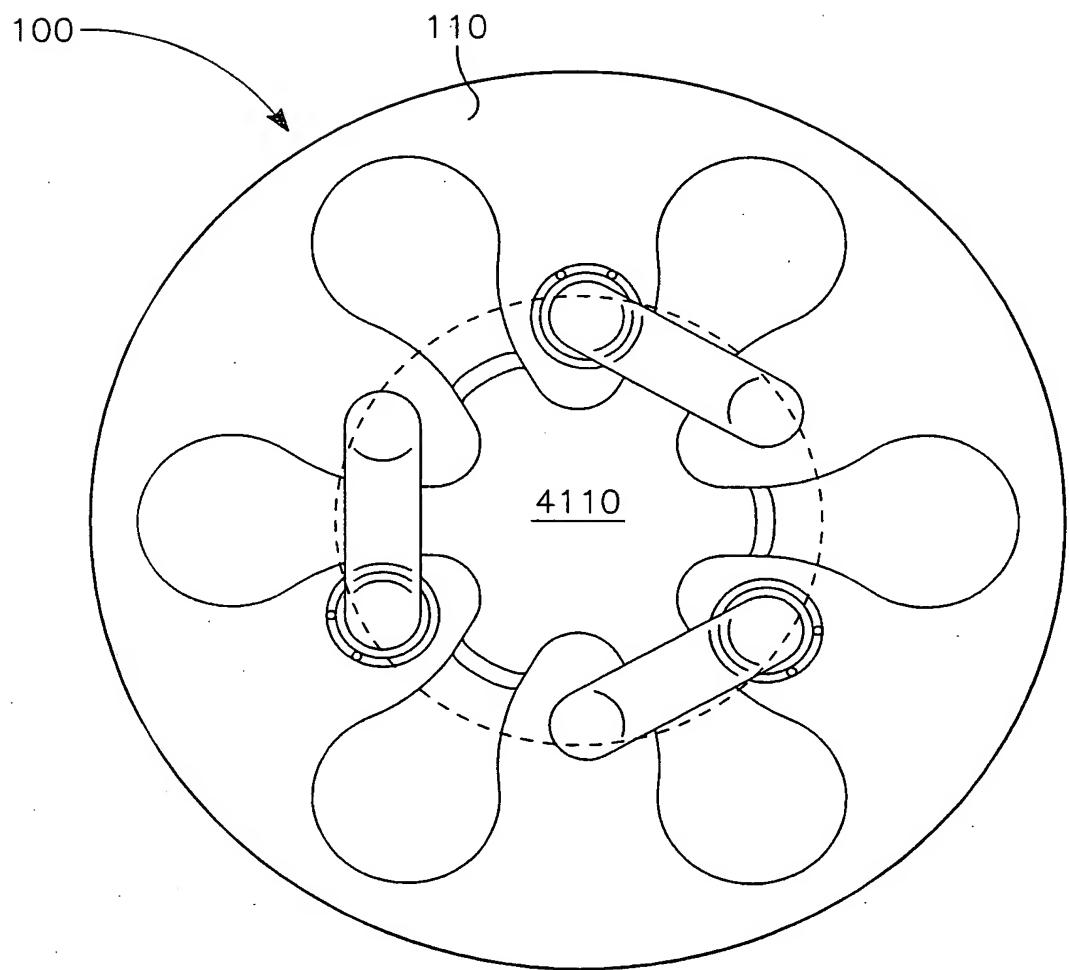


FIG. 41

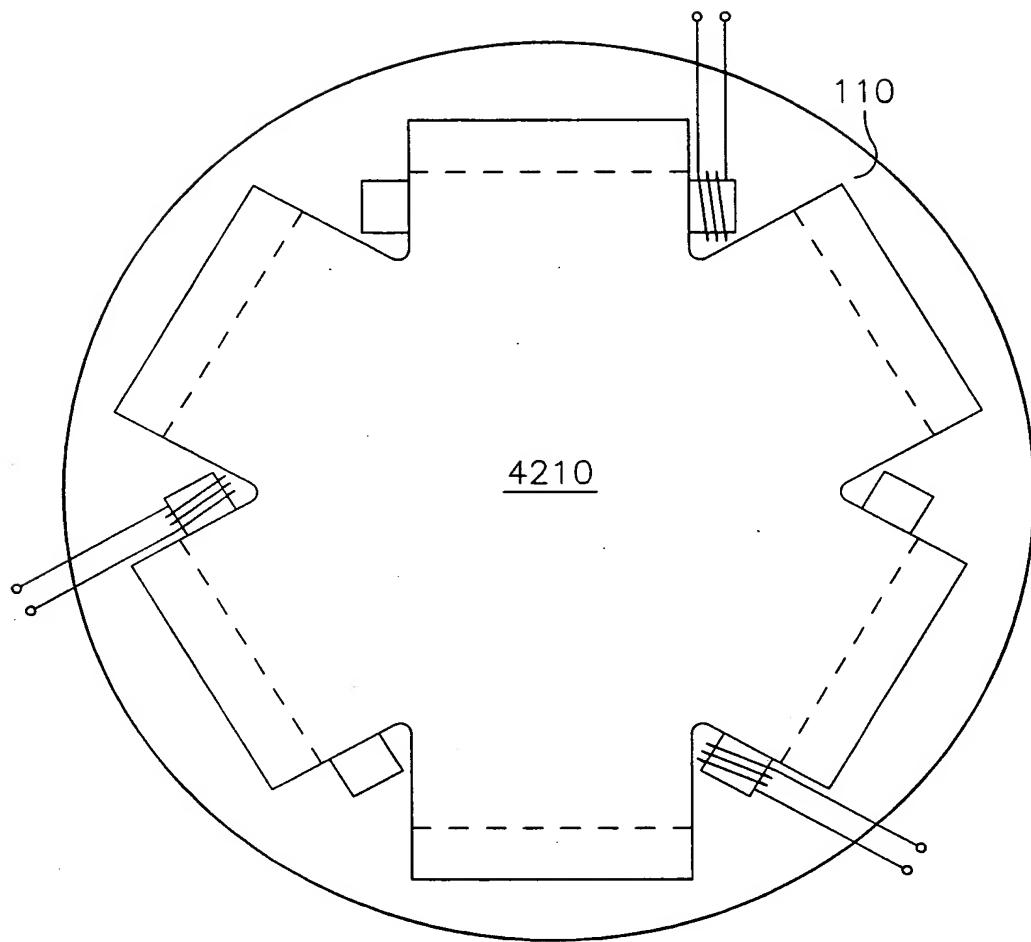


FIG. 42

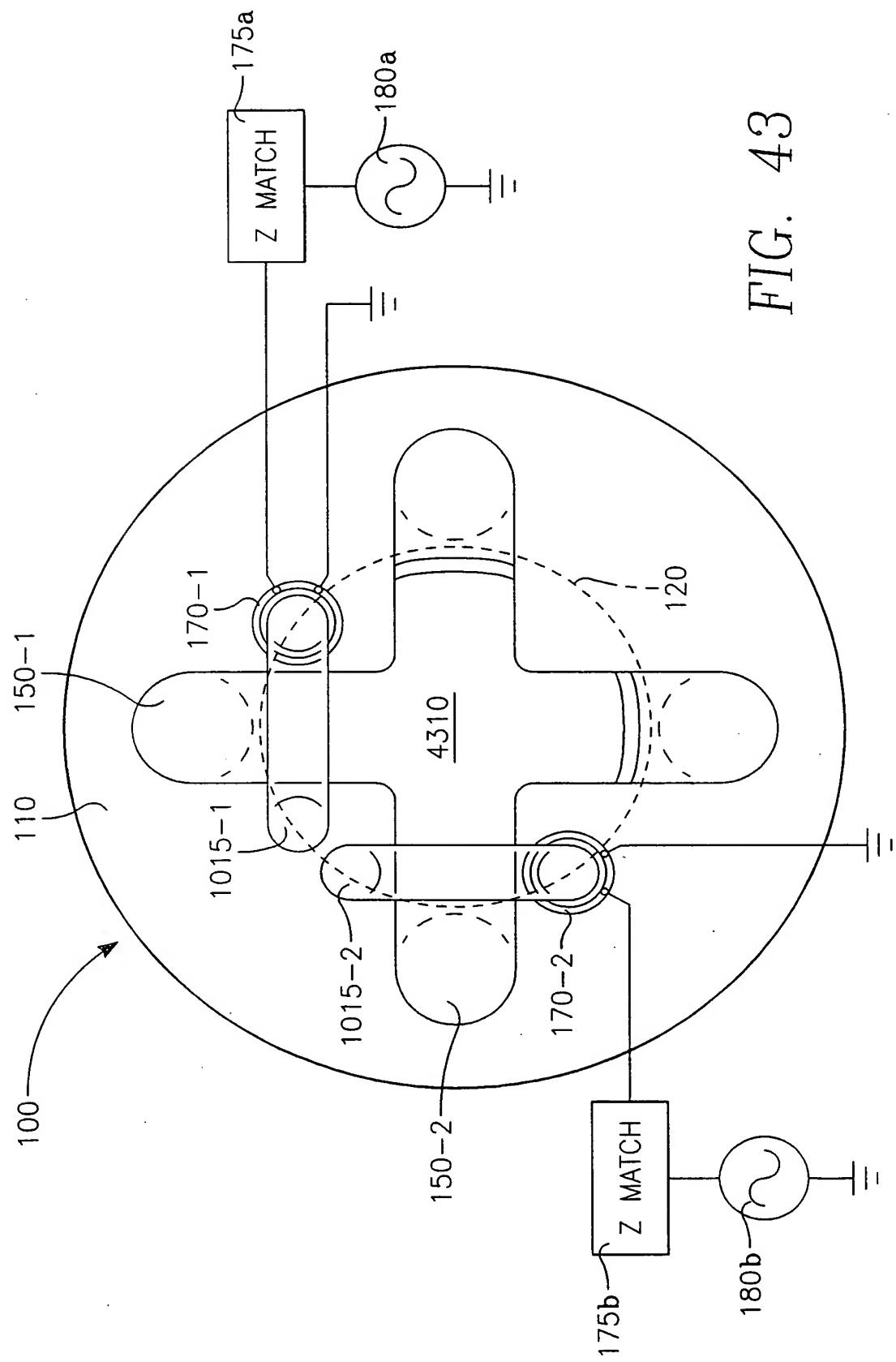


FIG. 43

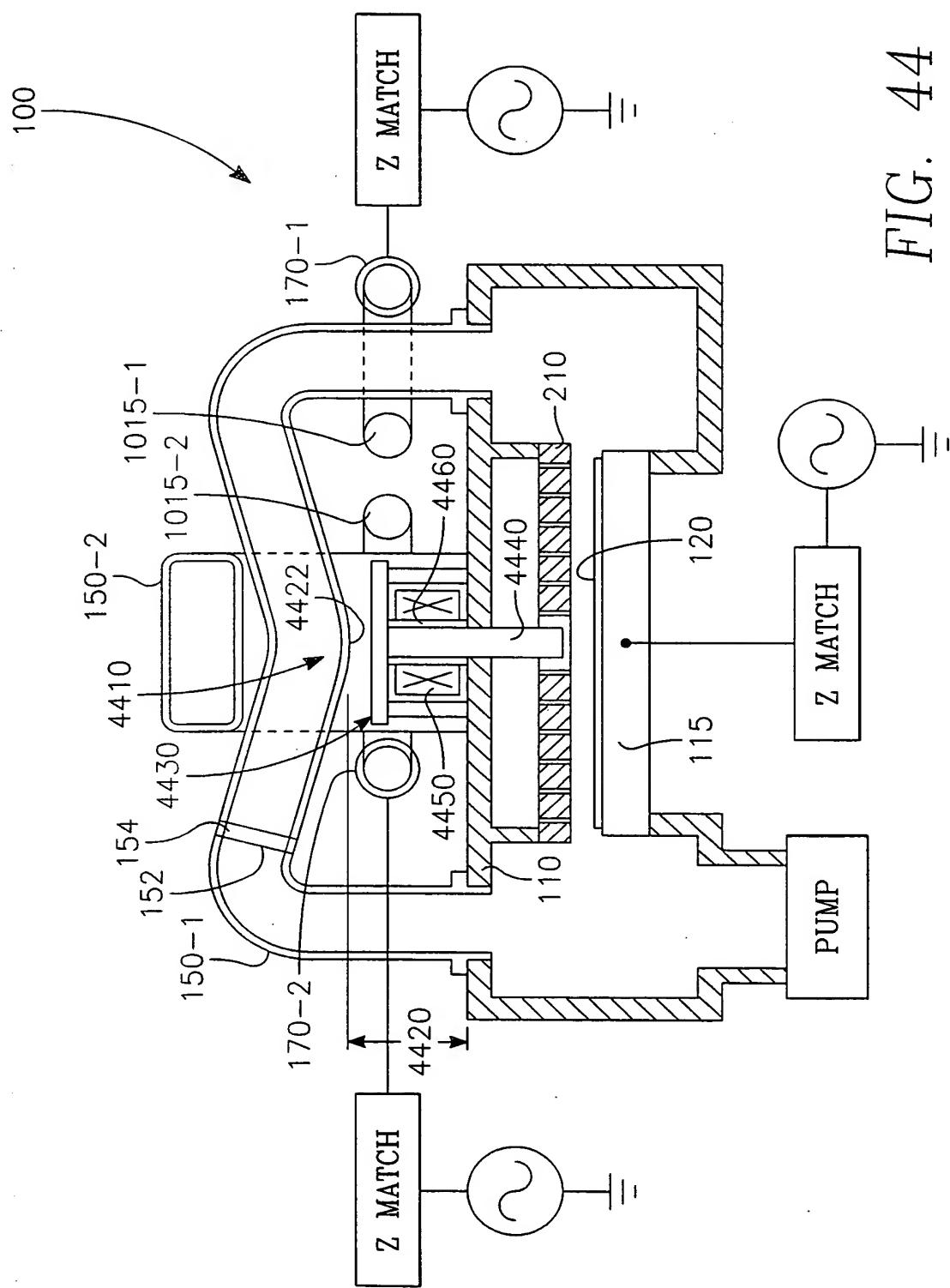


FIG. 44

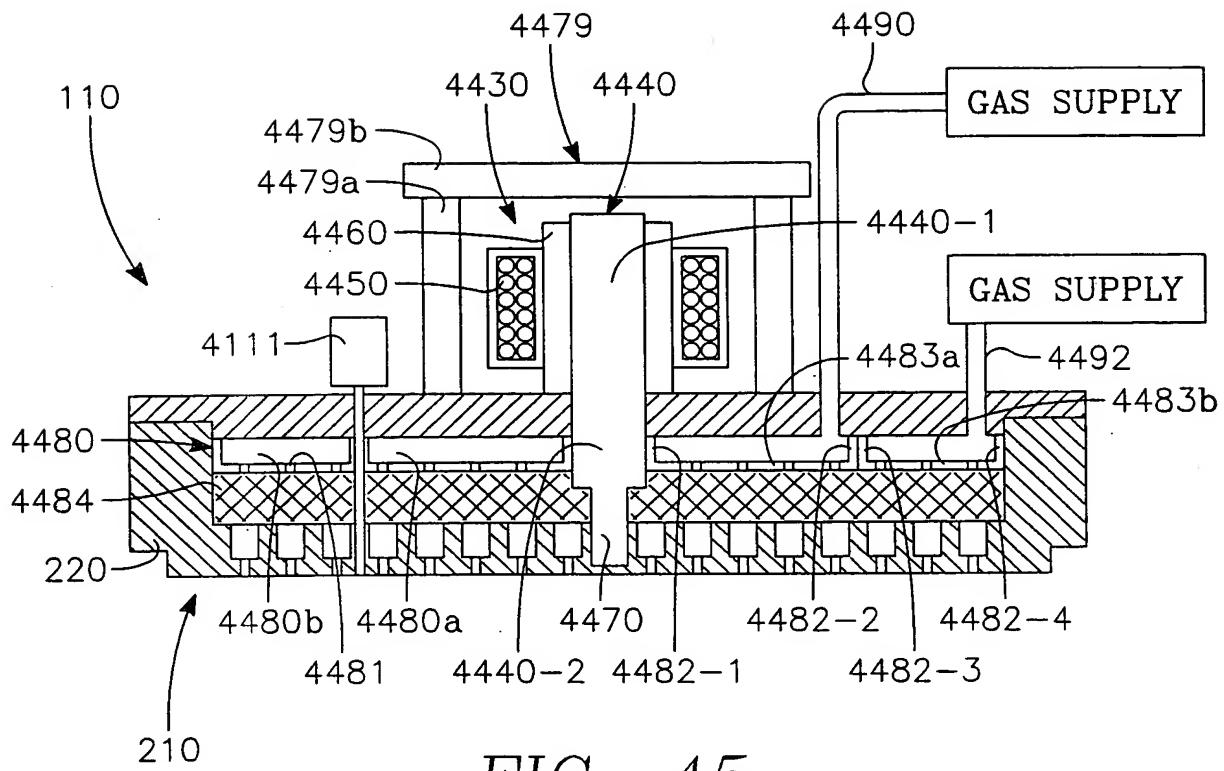


FIG. 45

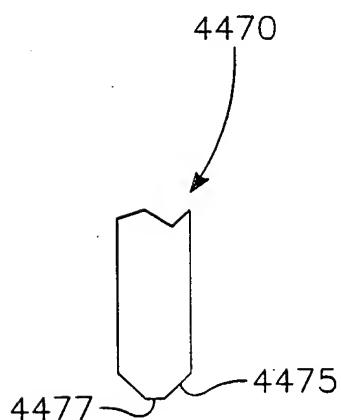


FIG. 46

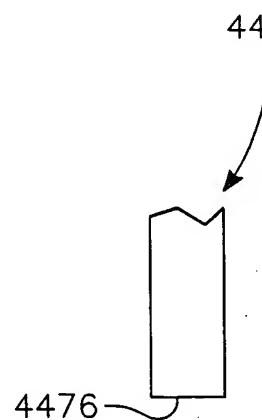


FIG. 47

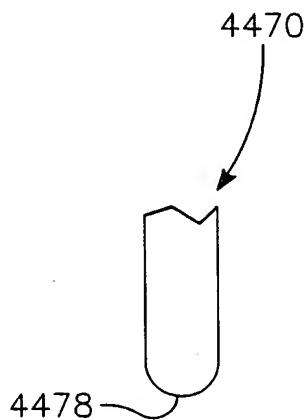
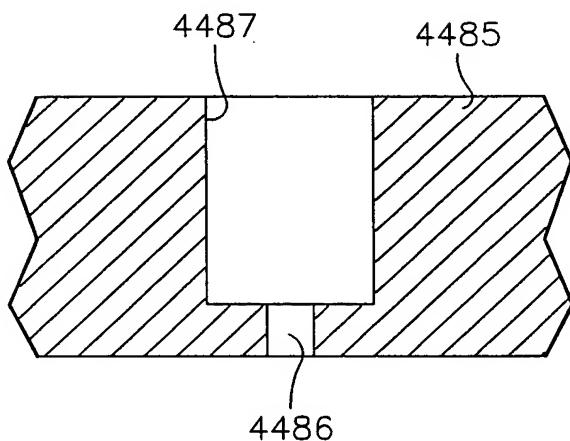
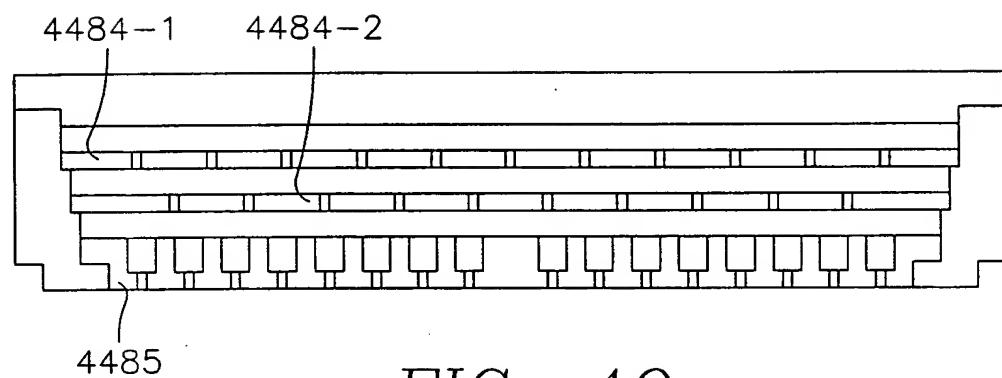


FIG. 48

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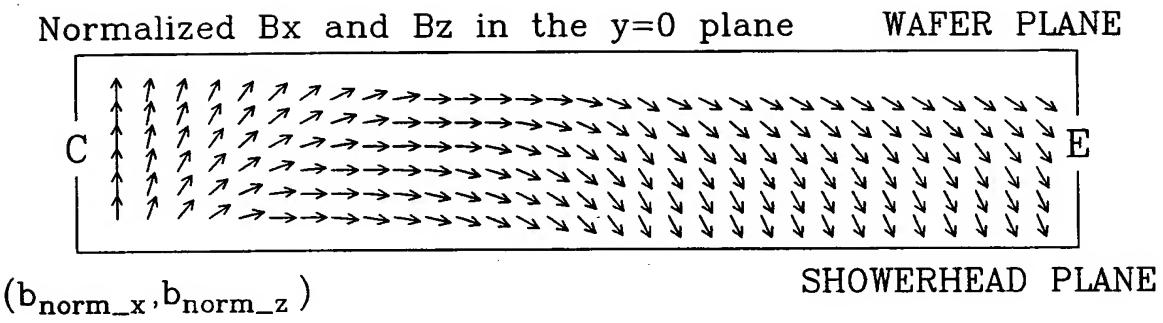


FIG. 51

- B_r measured = 7 gauss at wafer plane, 1 in. off-center (peak)

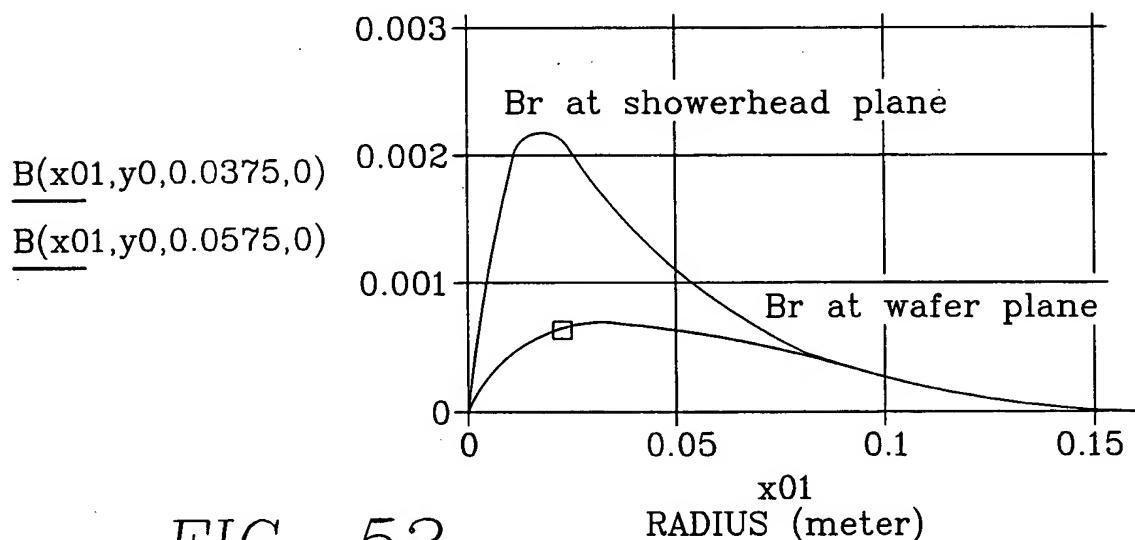


FIG. 52

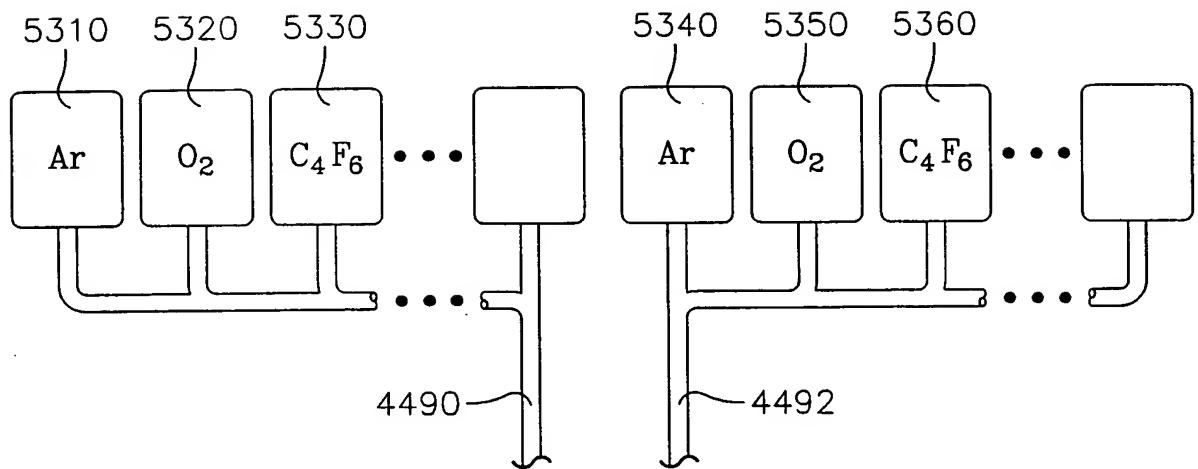


FIG. 53

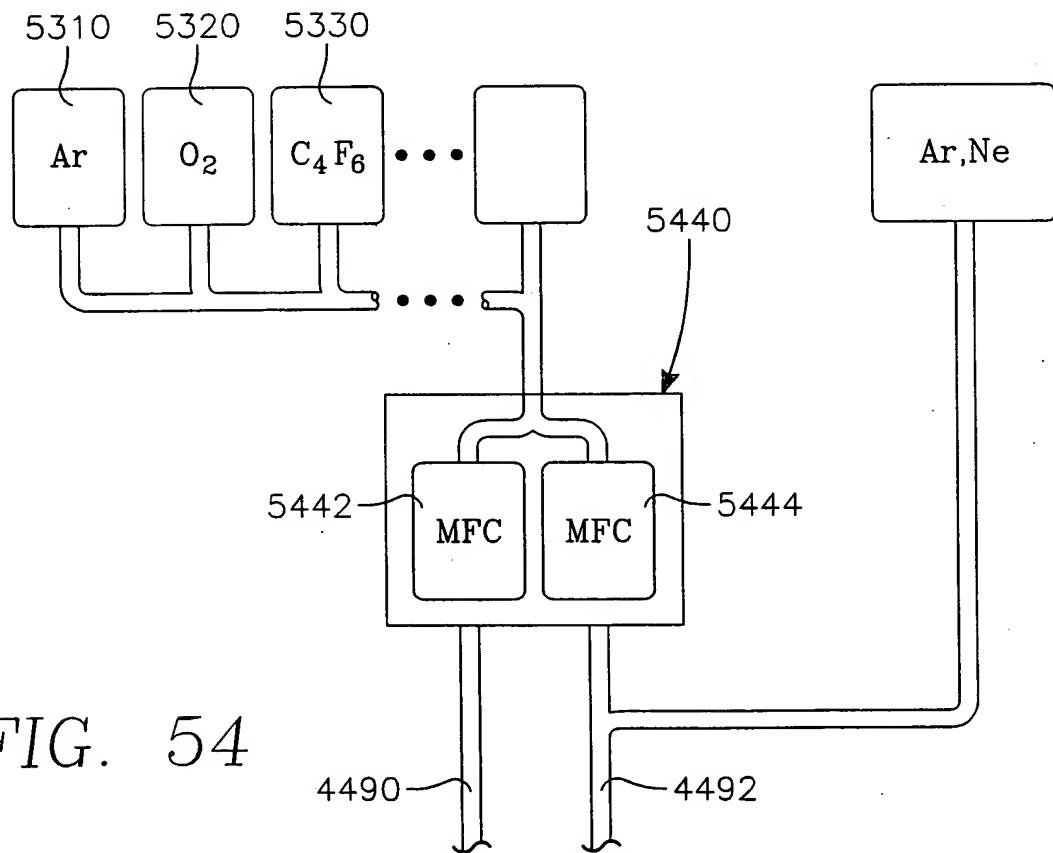


FIG. 54

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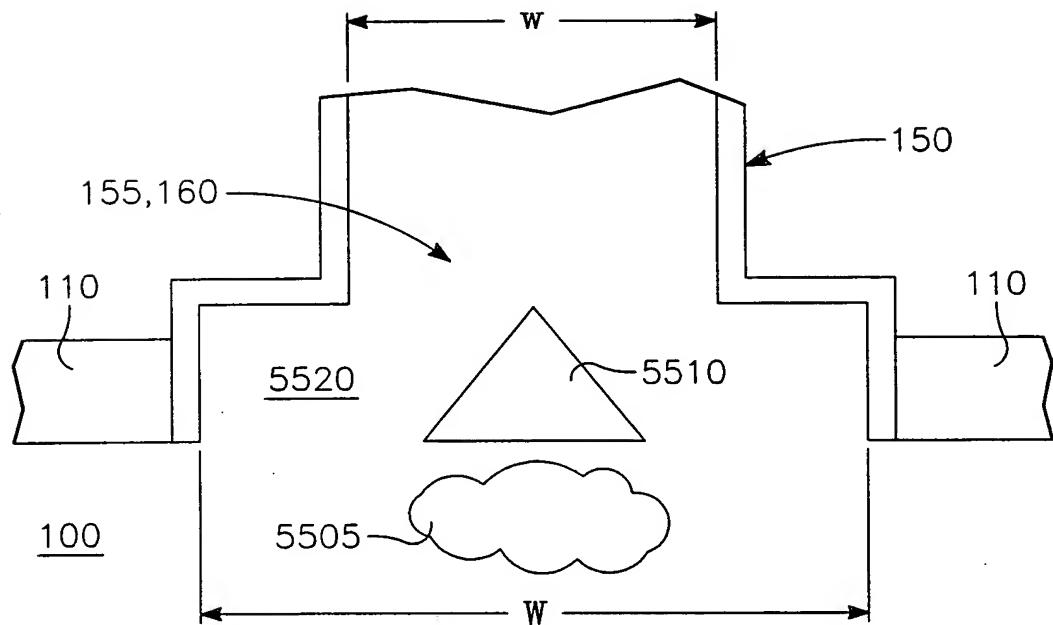


FIG. 55A

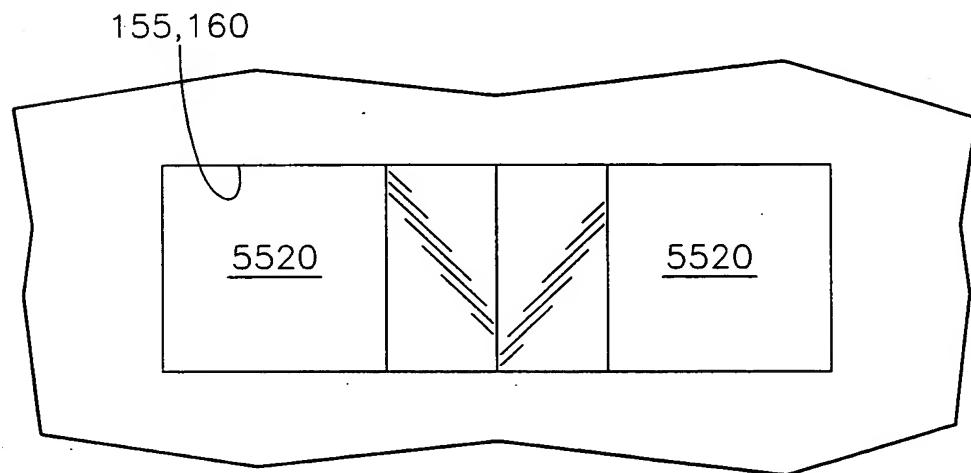


FIG. 55B

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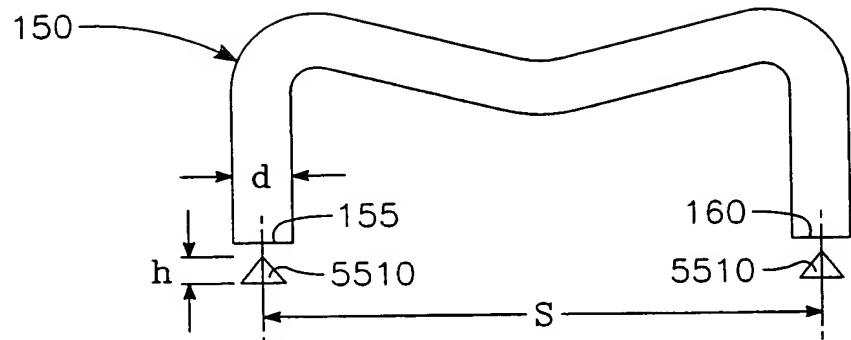


FIG. 56A

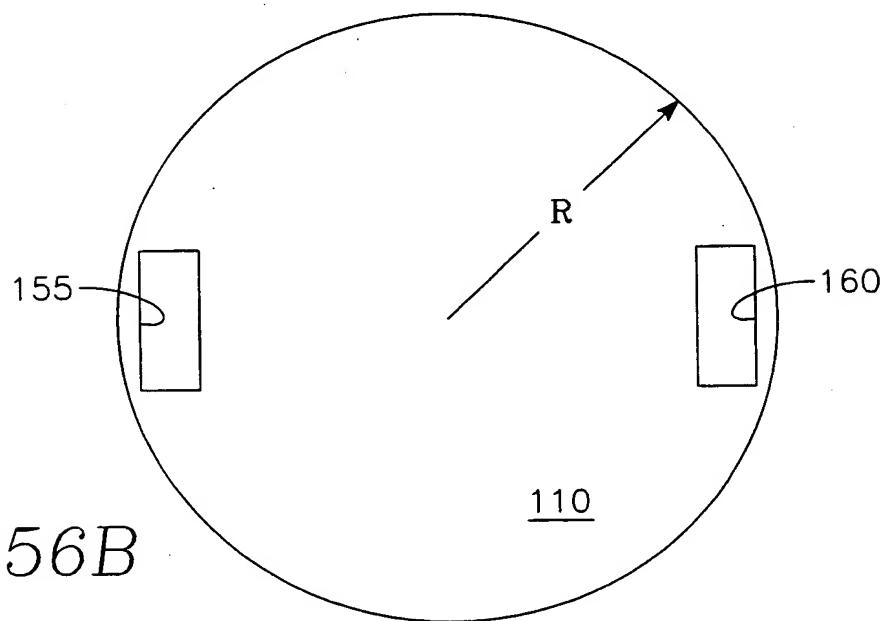


FIG. 56B

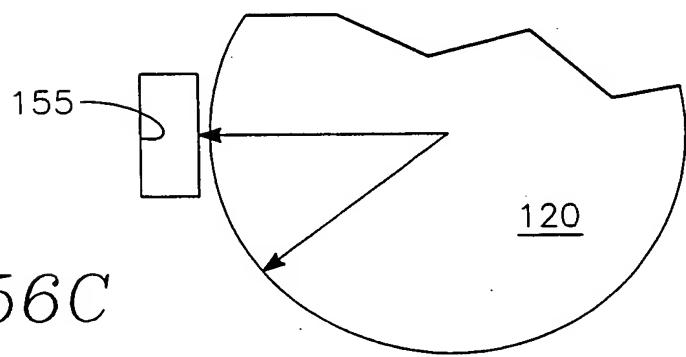


FIG. 56C

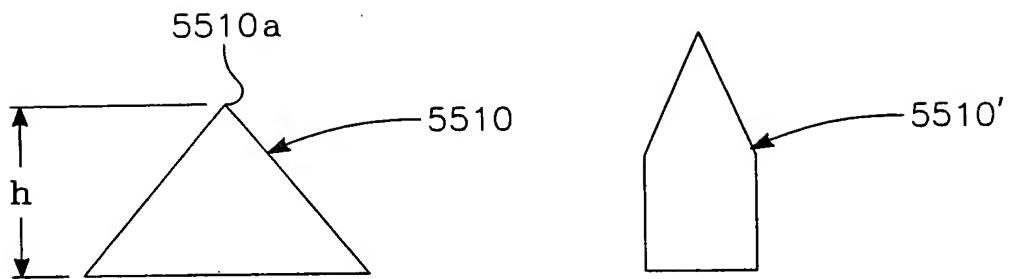


FIG. 57

FIG. 58

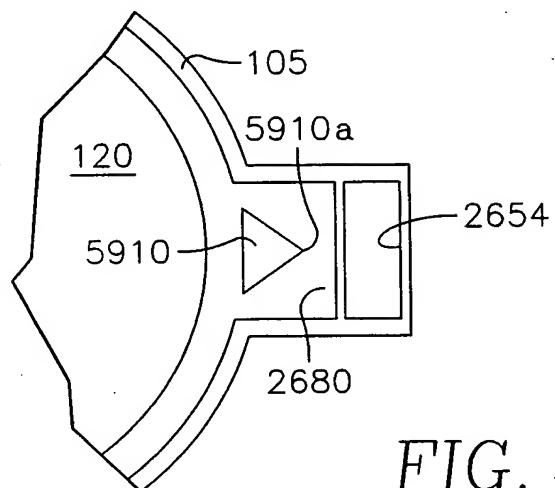


FIG. 59A

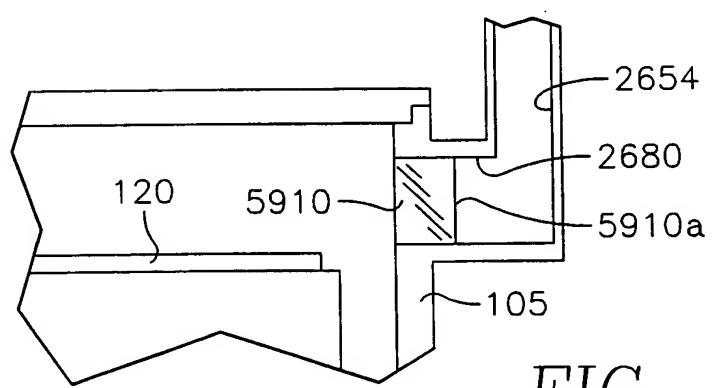


FIG. 59B

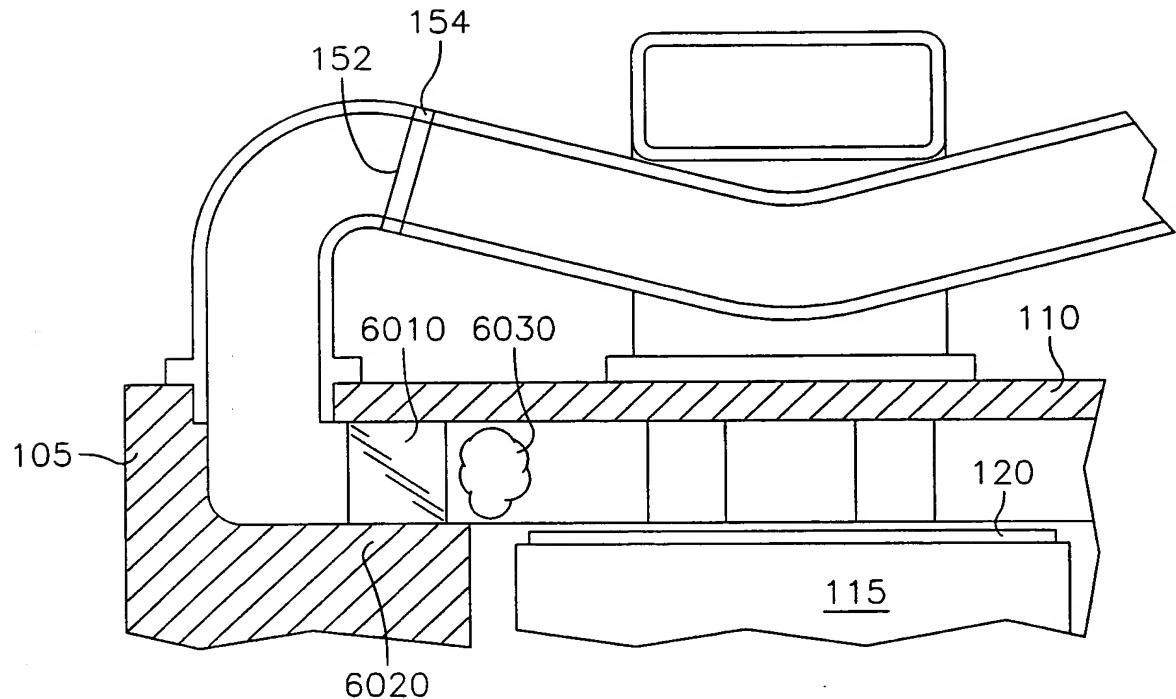


FIG. 60

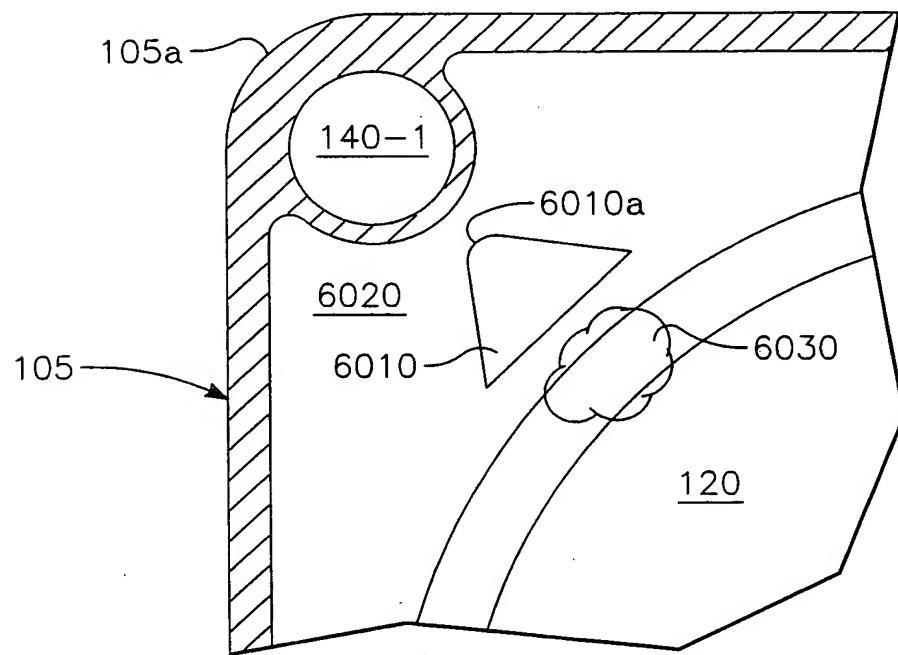


FIG. 61

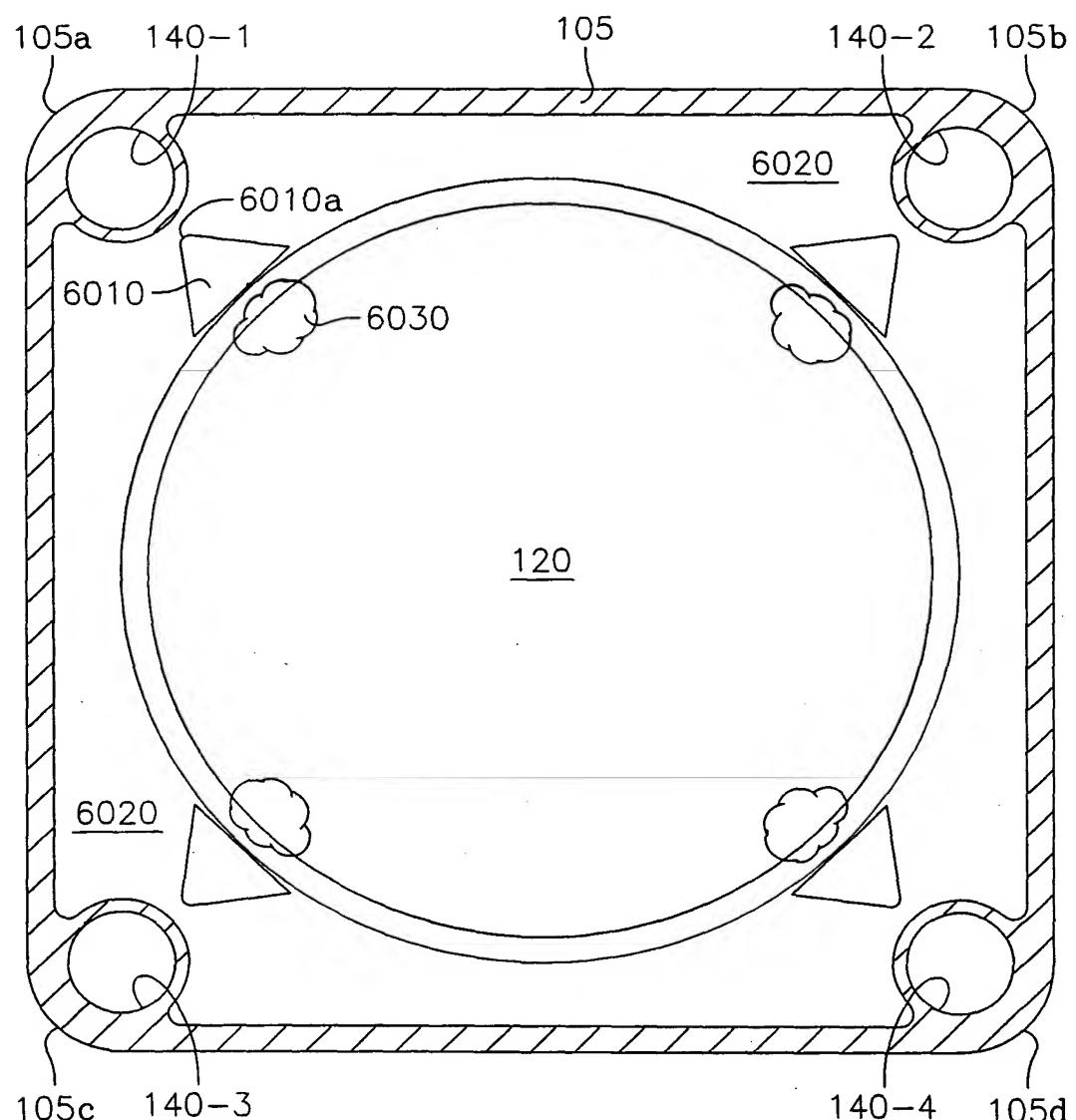


FIG. 62

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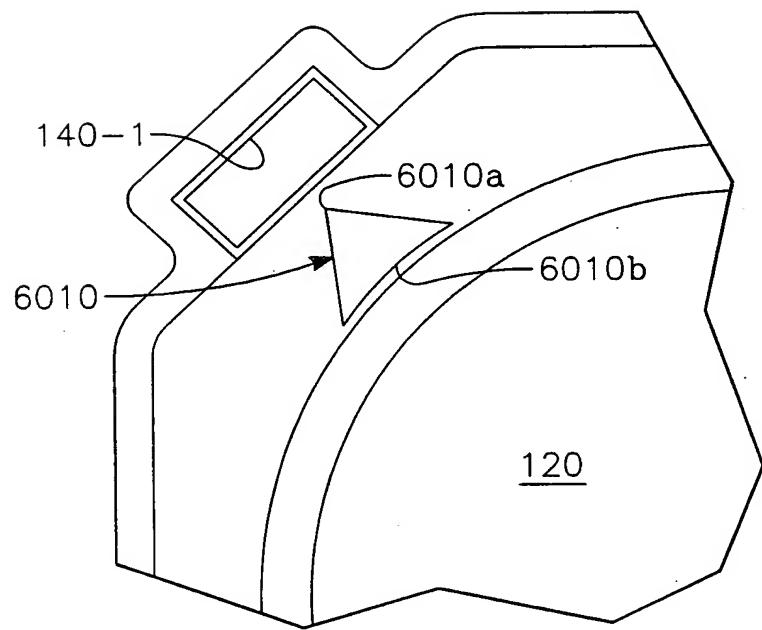


FIG. 63

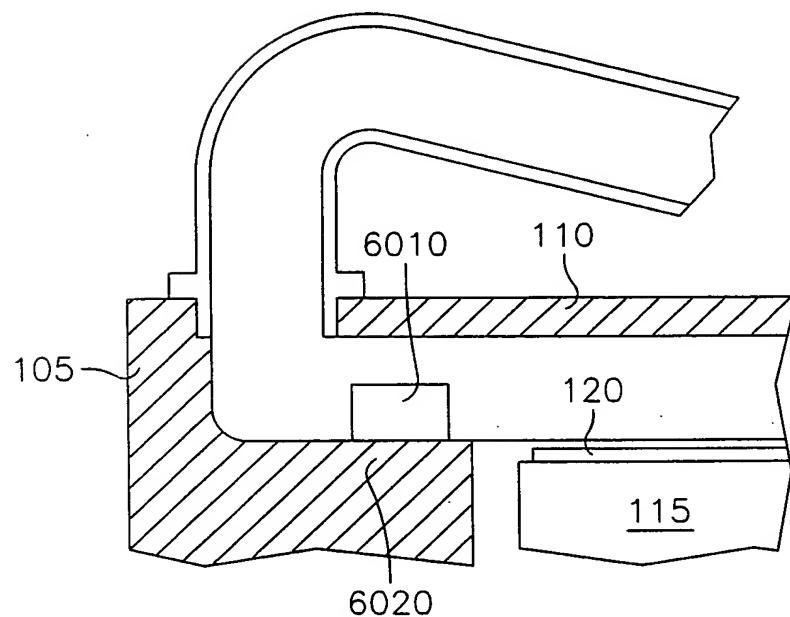


FIG. 64

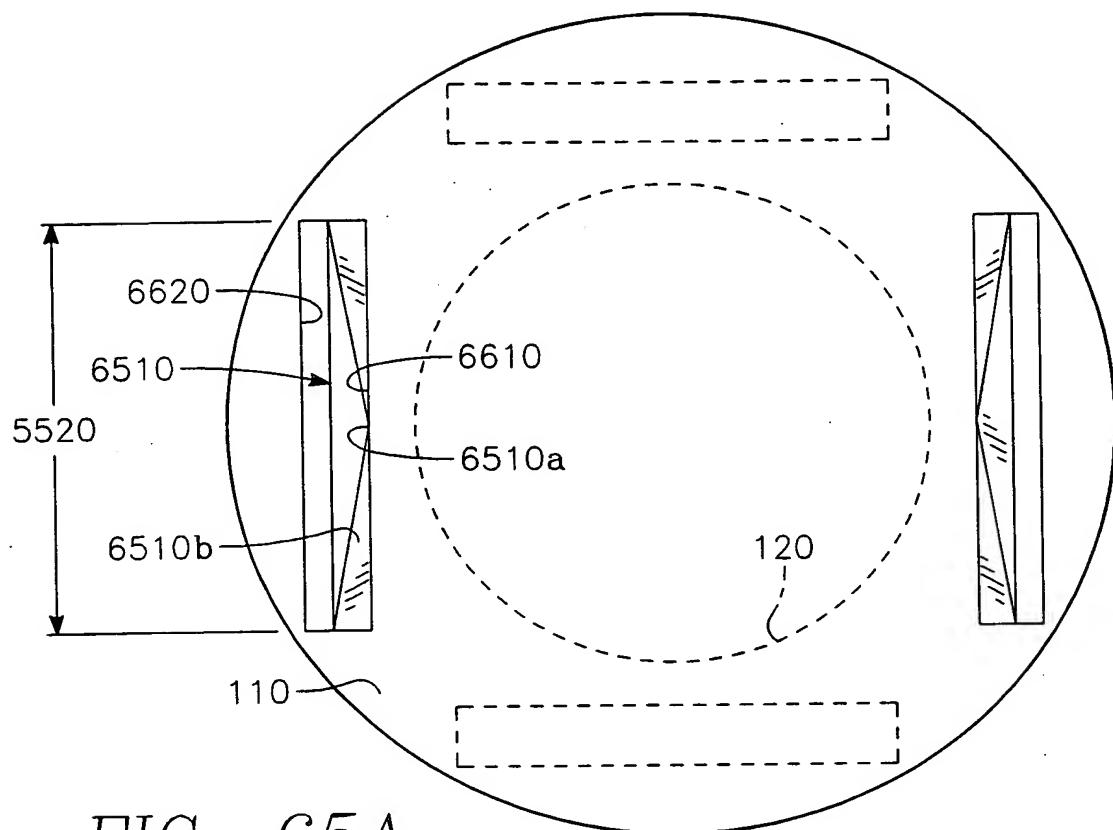


FIG. 65A

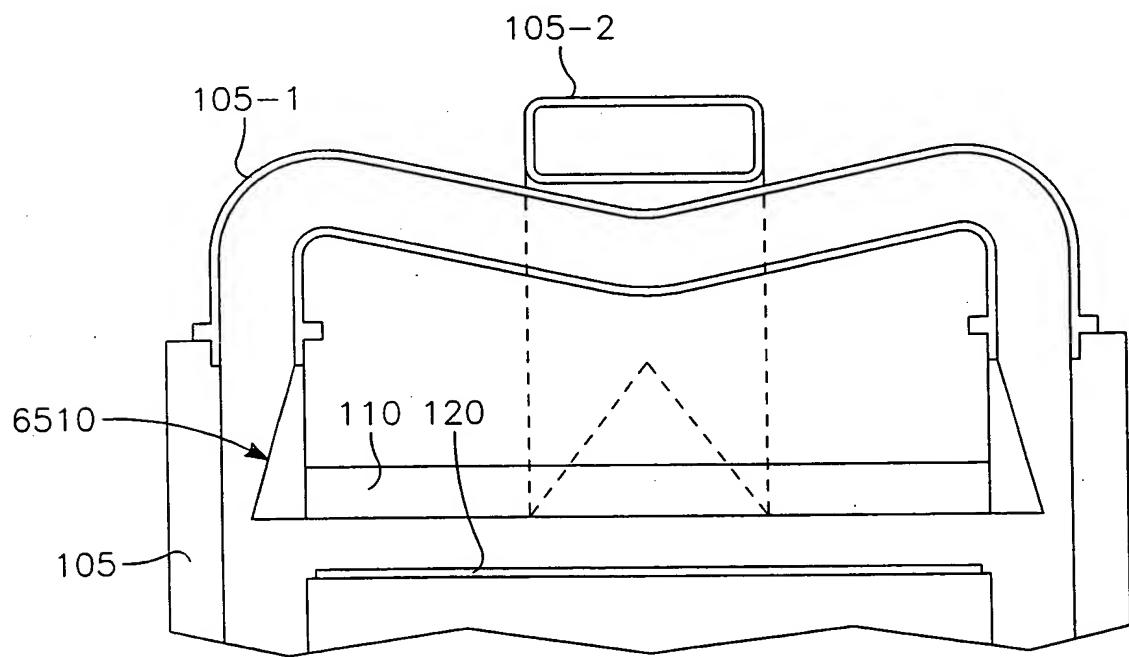


FIG. 65B

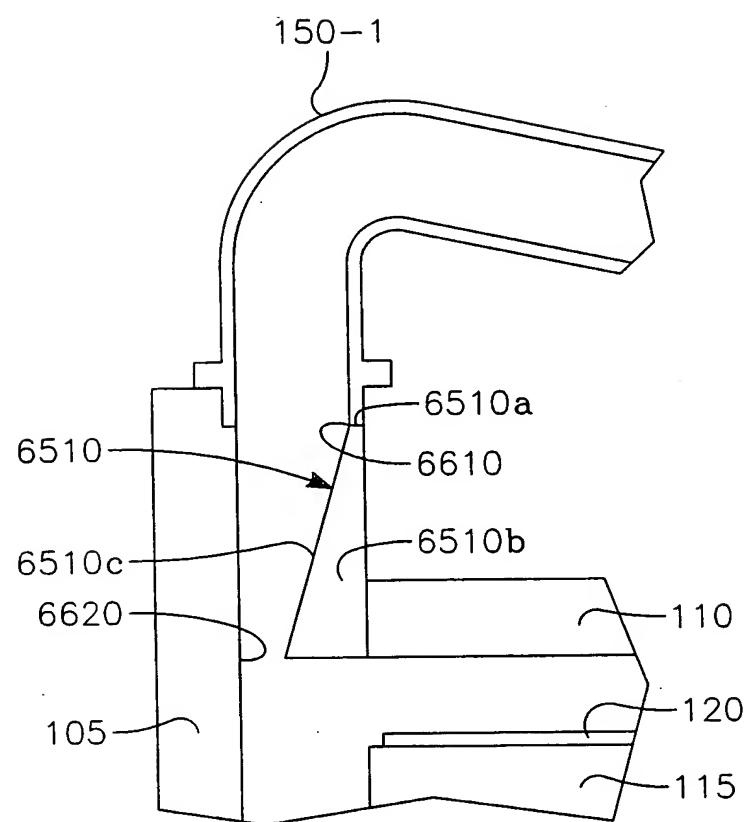


FIG. 66

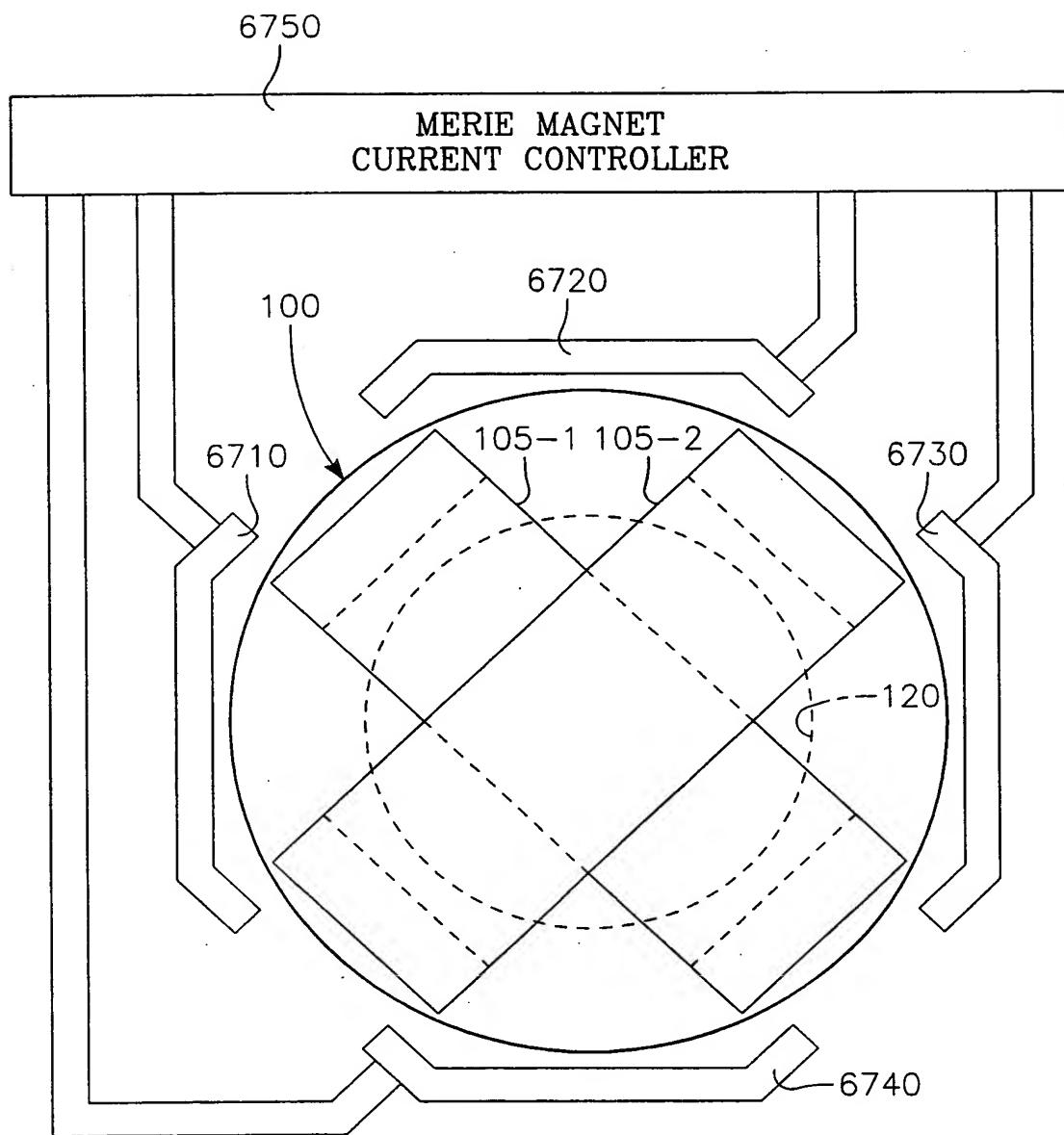
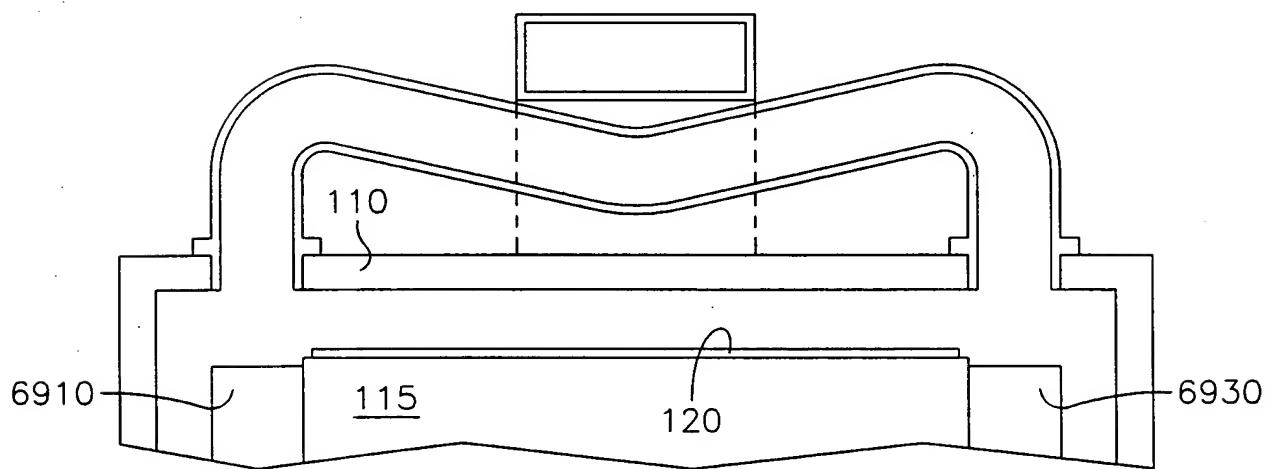
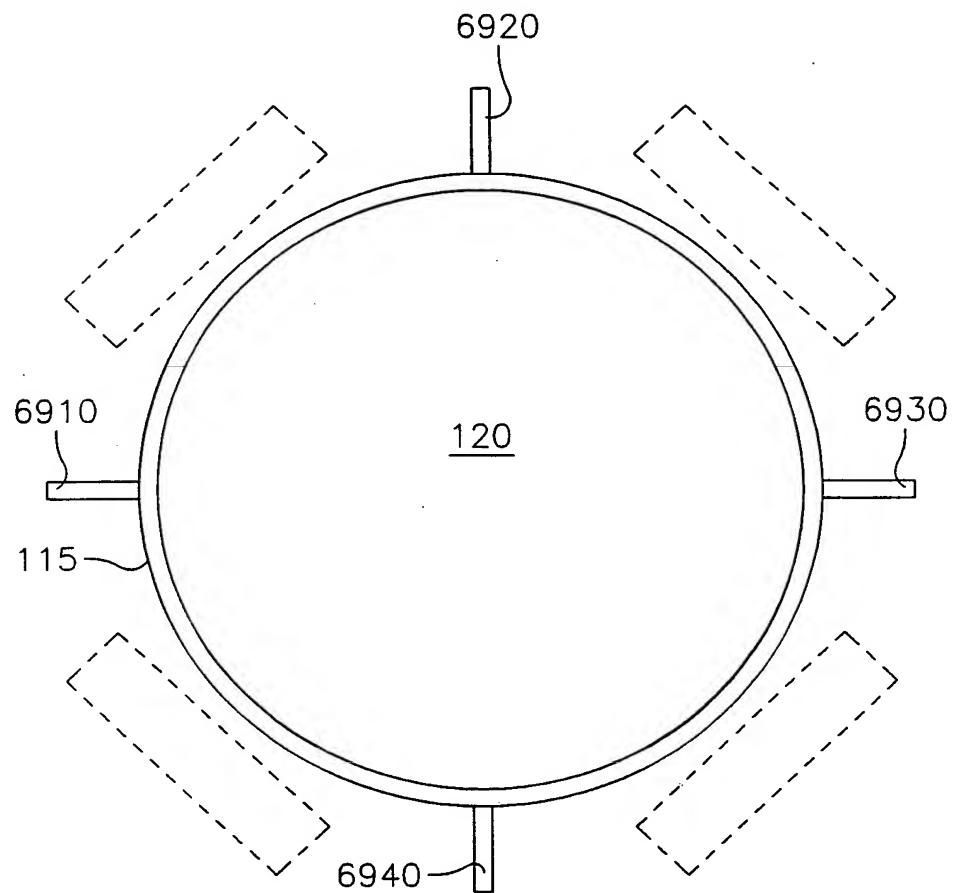
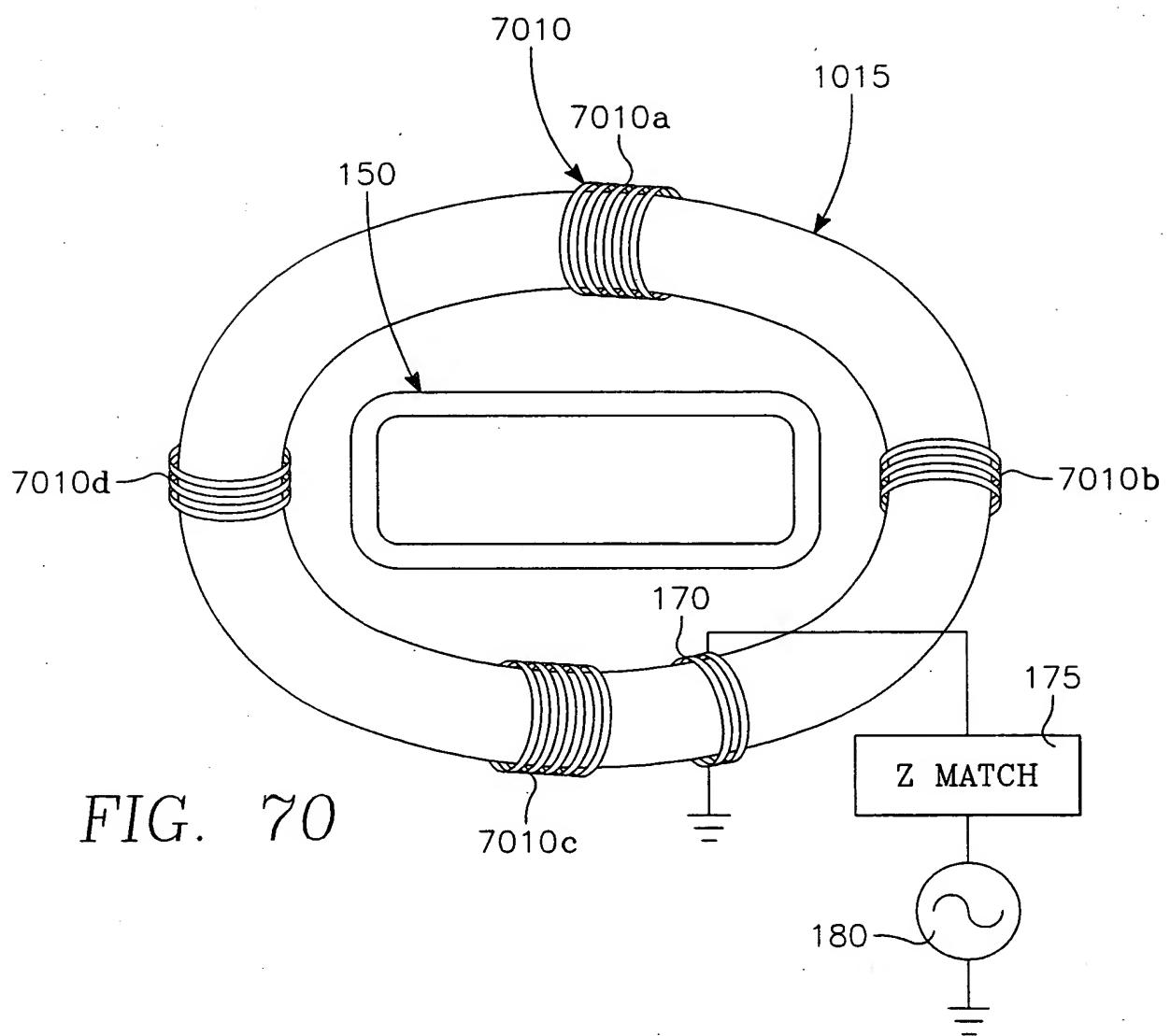
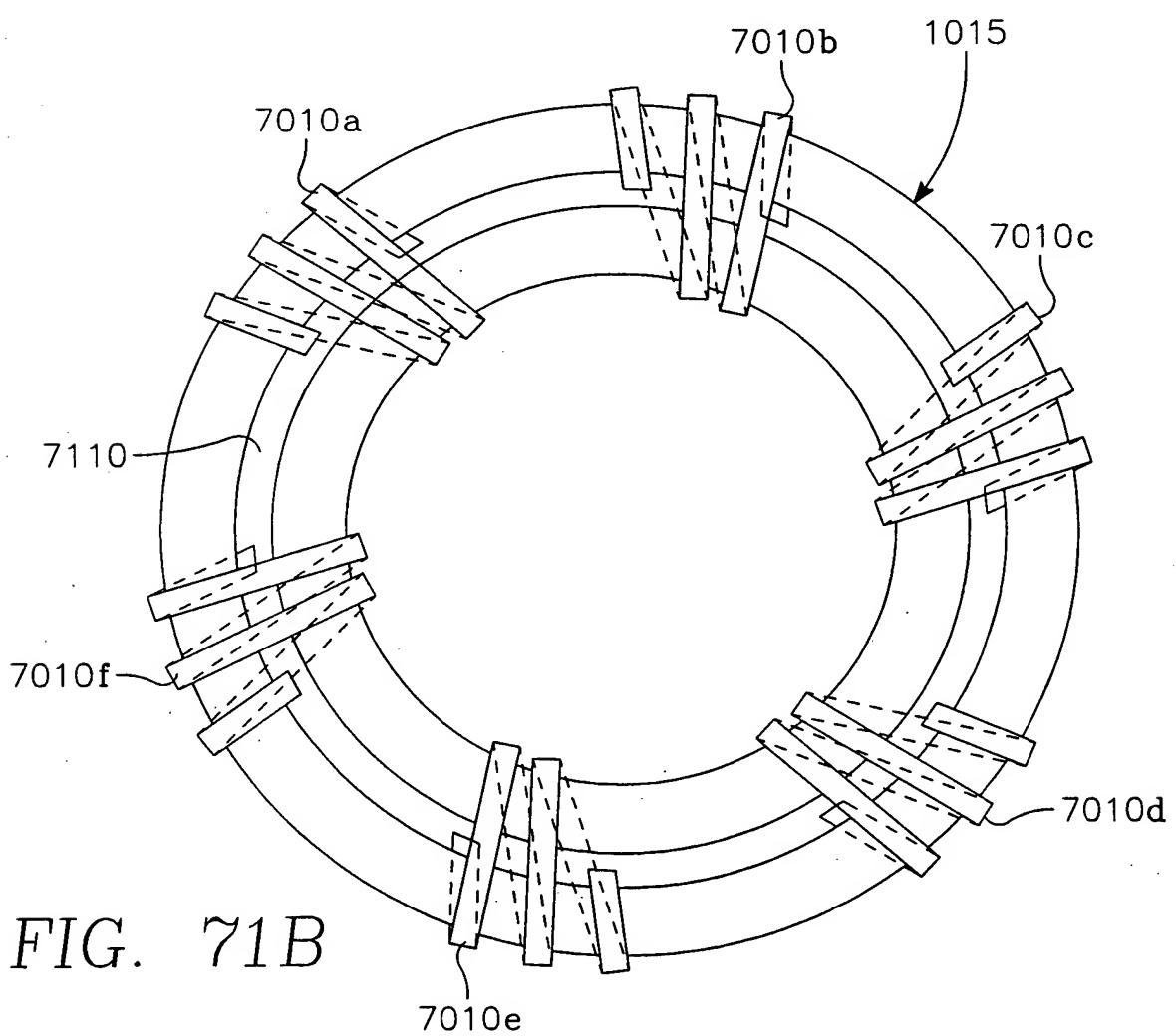
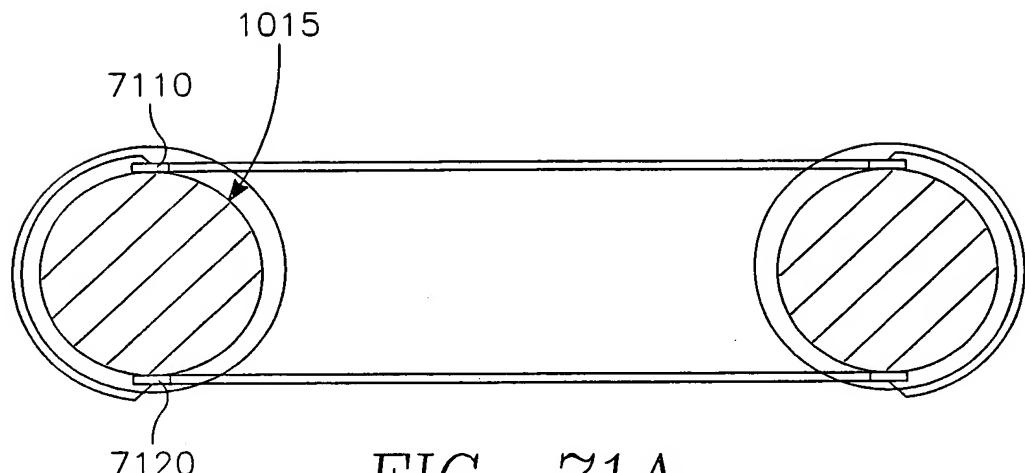


FIG. 67

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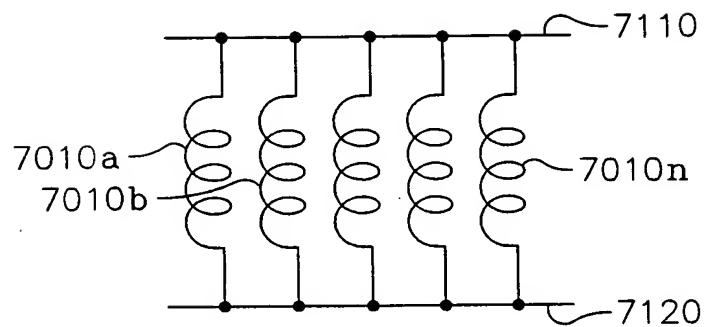


FIG. 72

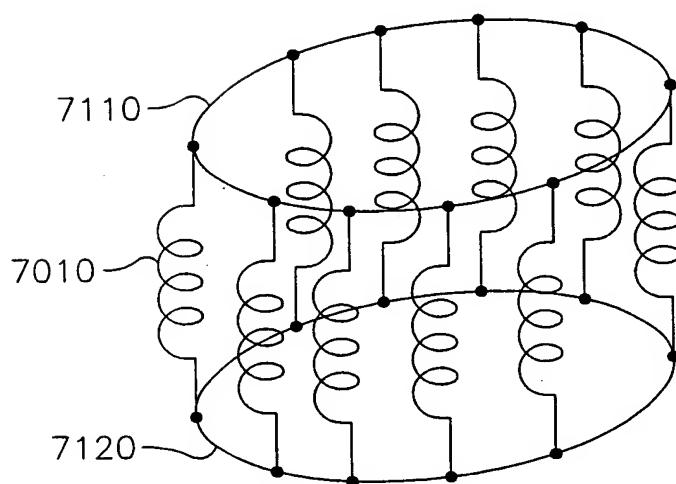


FIG. 73

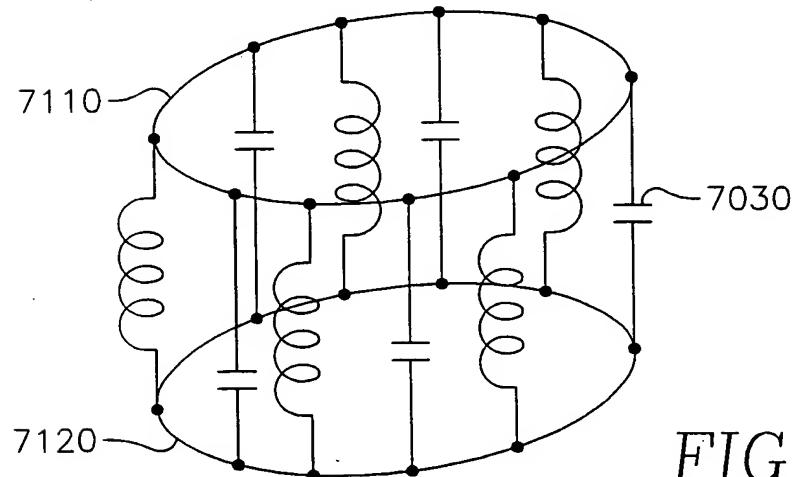


FIG. 74

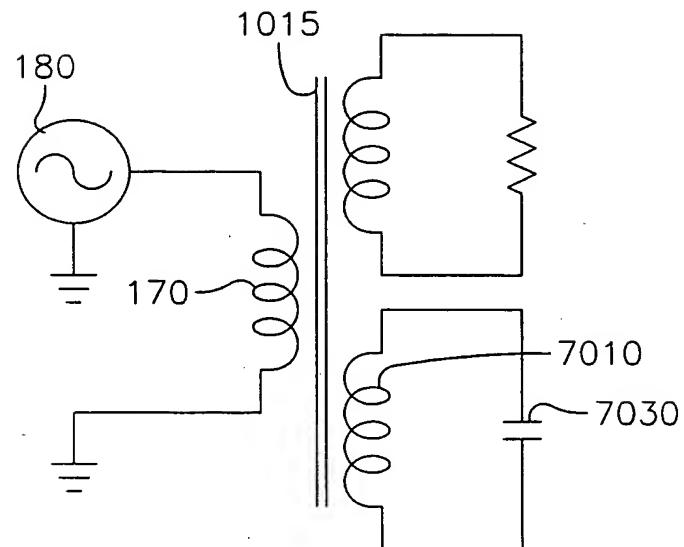


FIG. 75

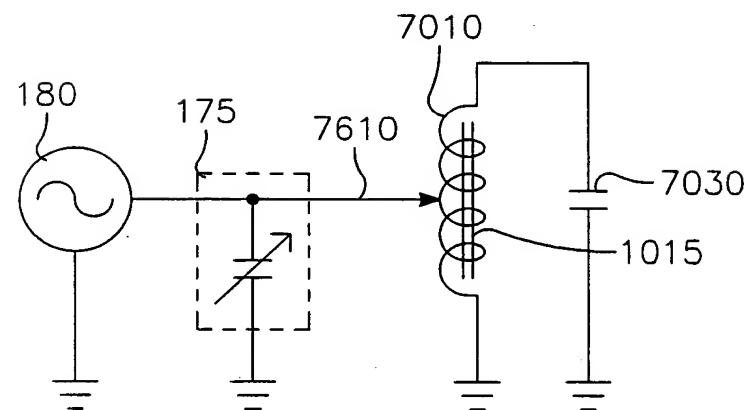
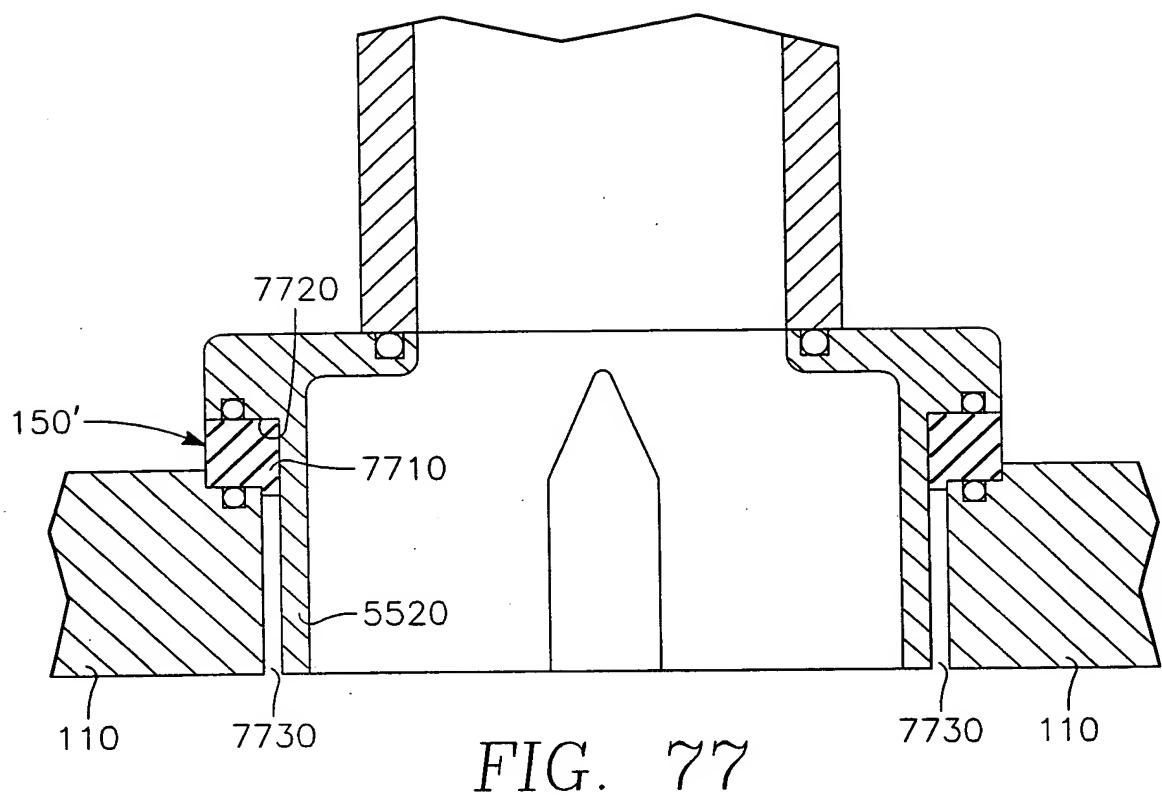


FIG. 76



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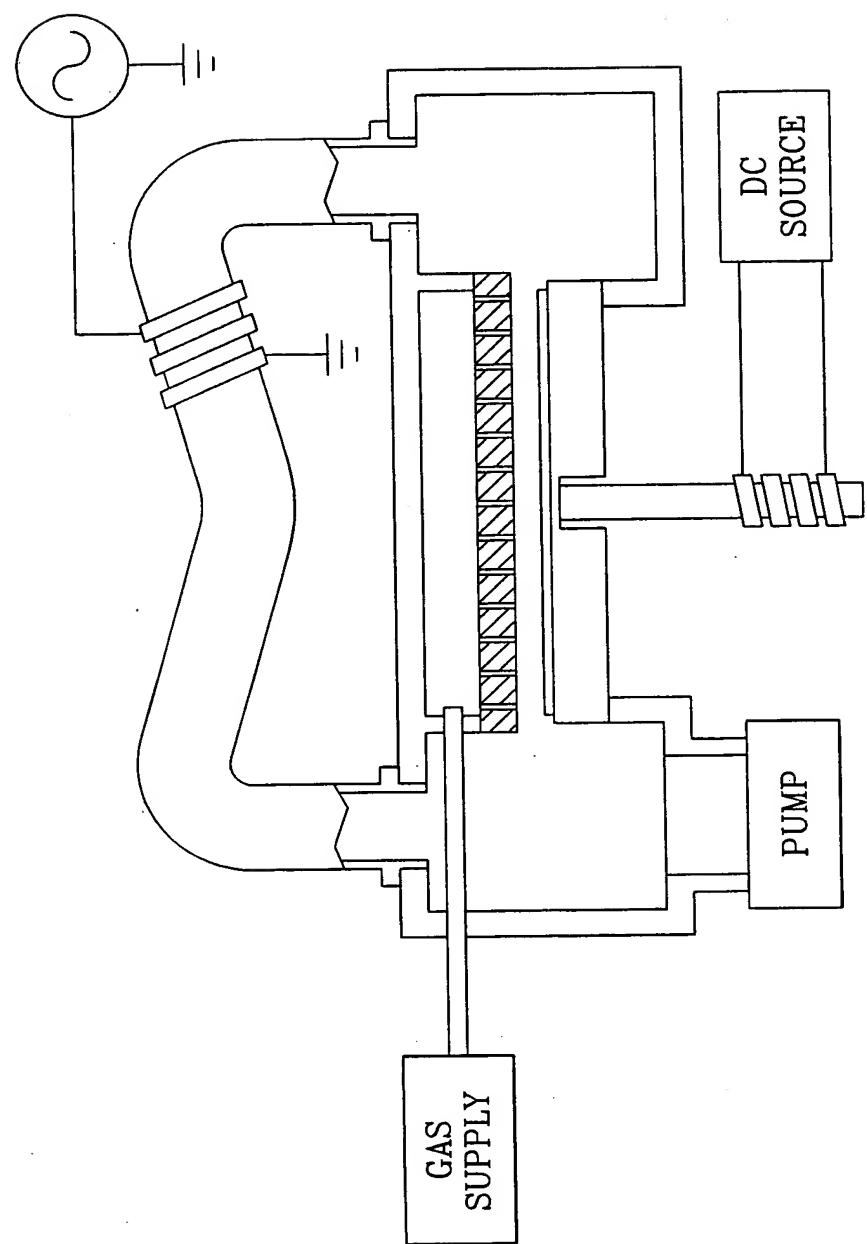


FIG. 78

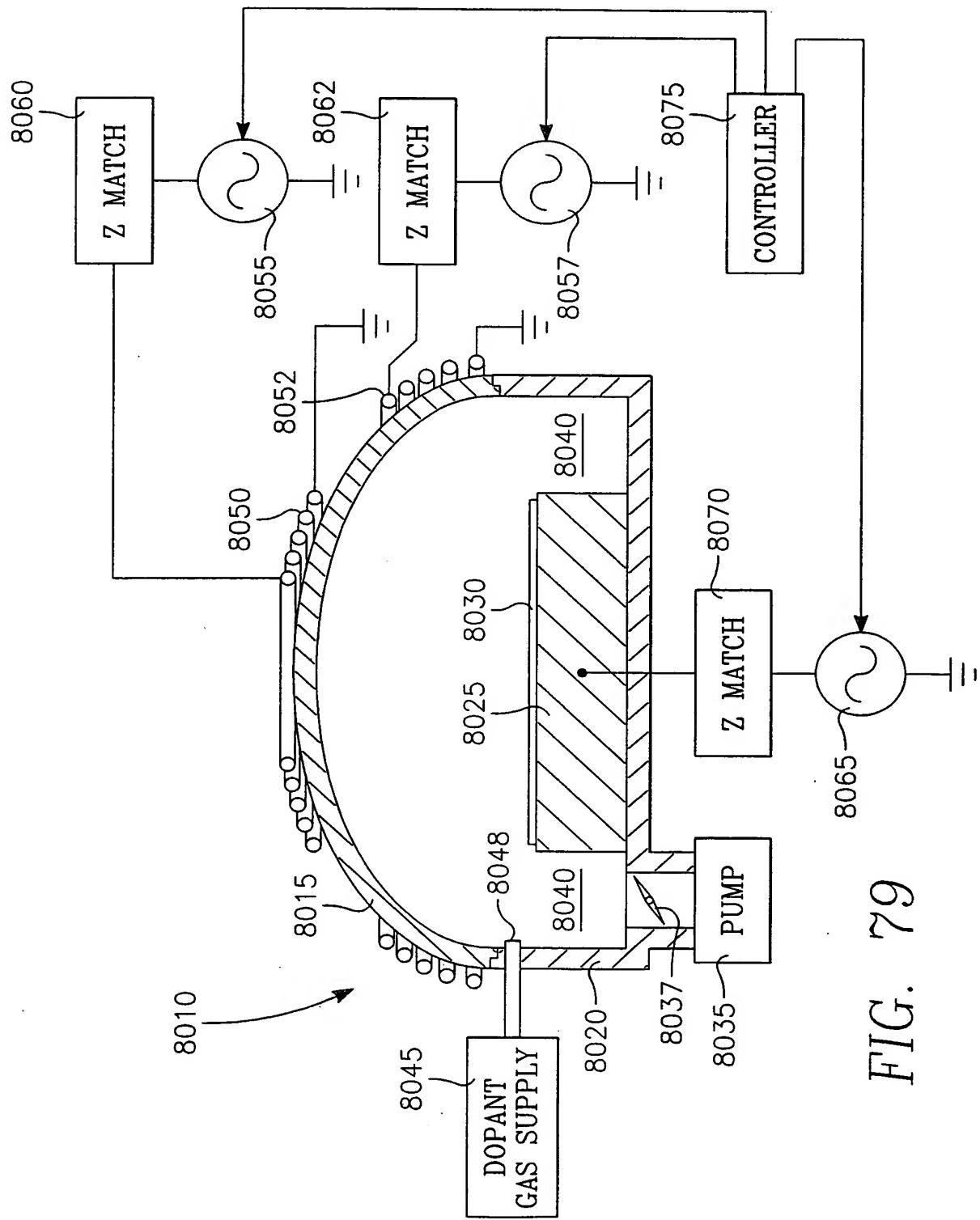


FIG. 79

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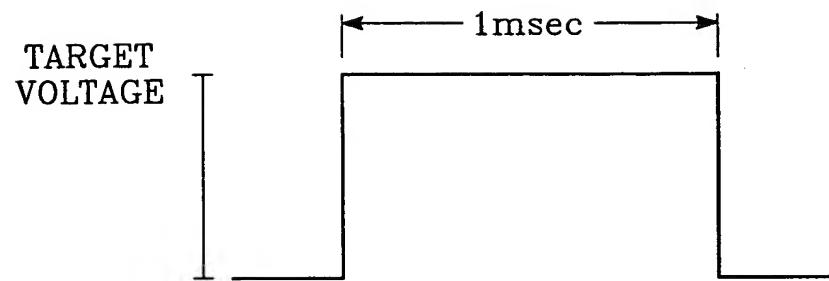


FIG. 80A

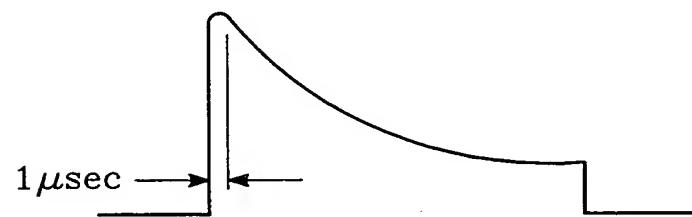


FIG. 80B

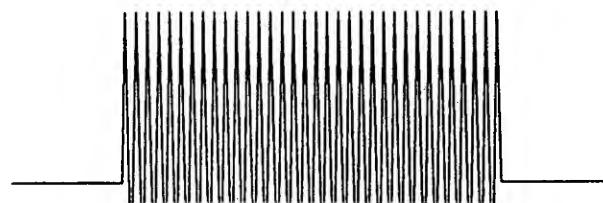
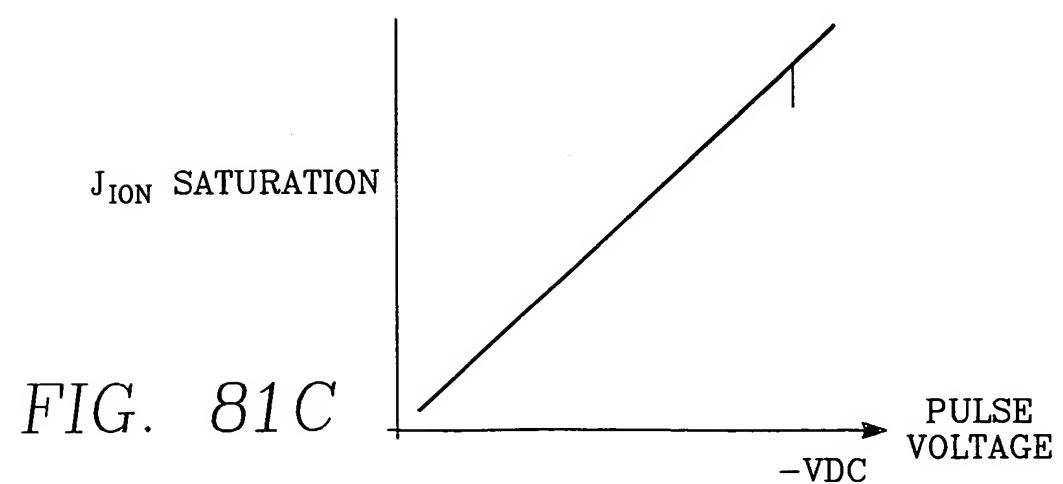
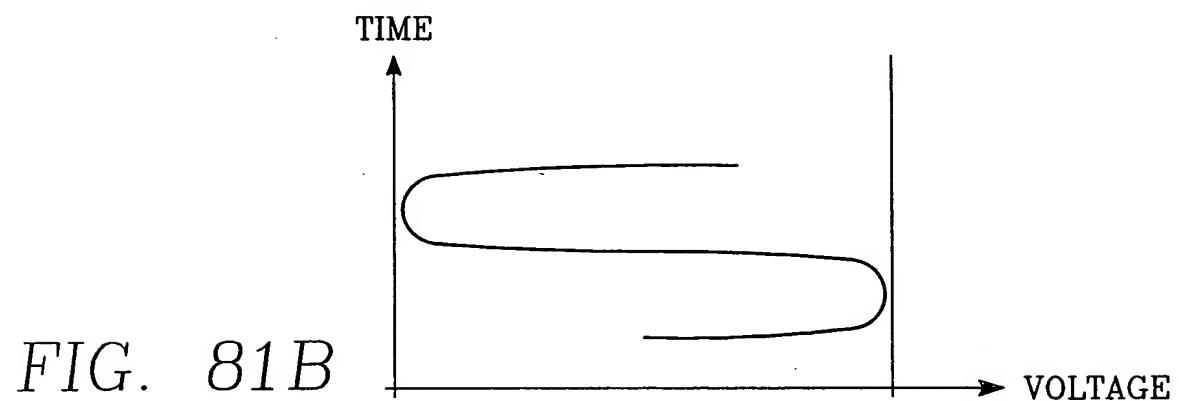
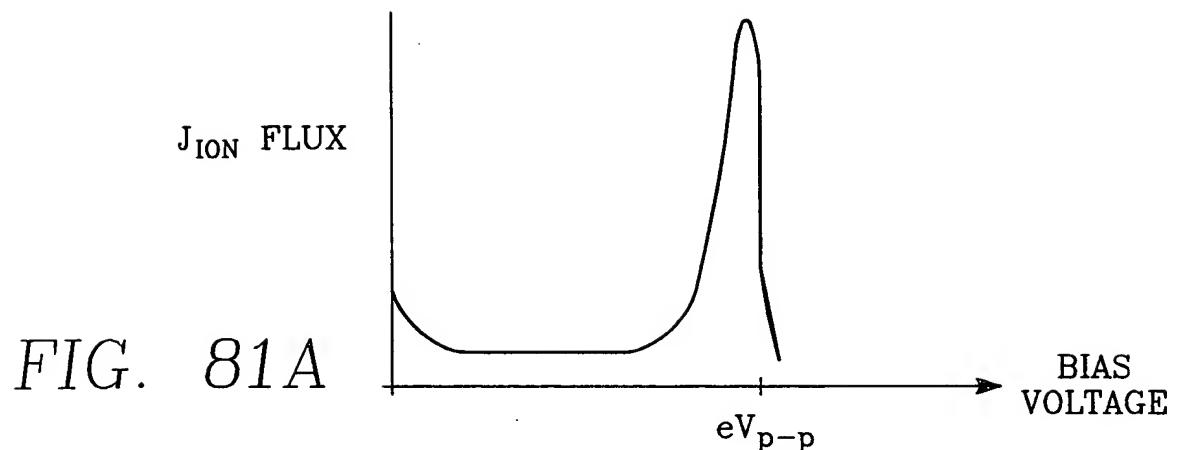


FIG. 80C

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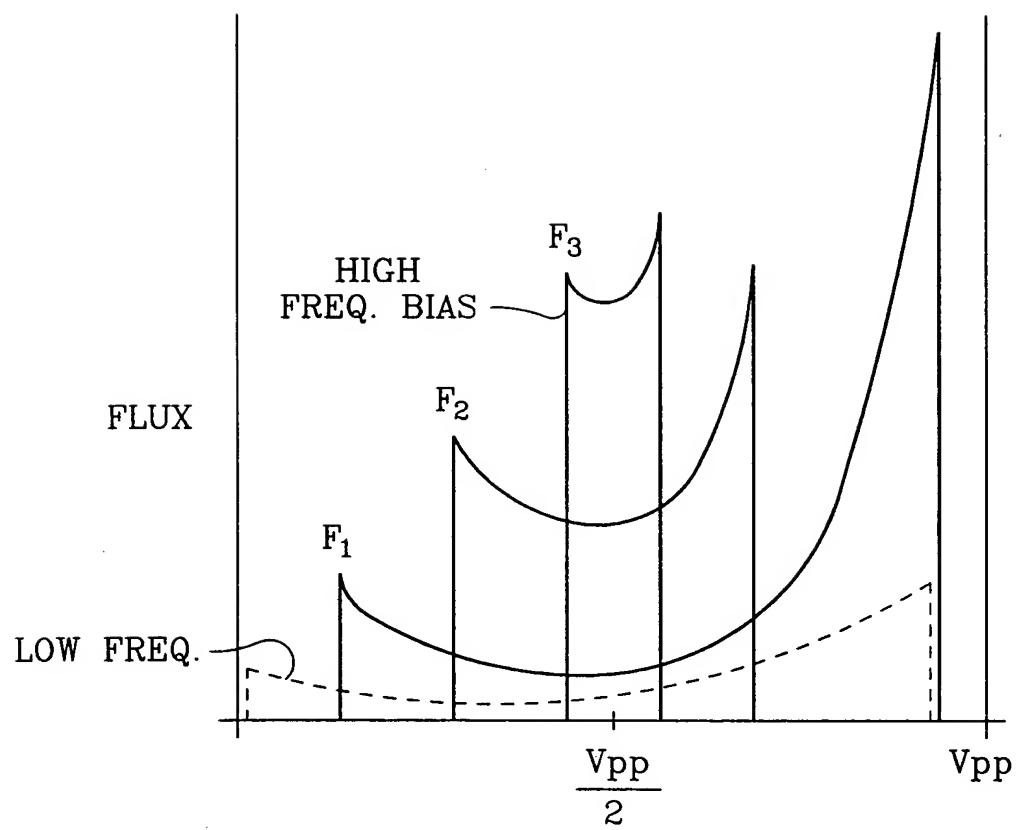


FIG. 81D

FIG. 82A  PUSH PULL

FIG. 82B  PUSH PULL

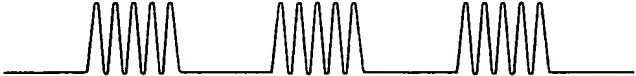
FIG. 82C  IN SYNC

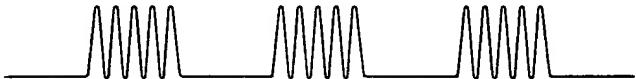
FIG. 82D  IN SYNC

FIG. 82E  SYMMETRIC

FIG. 82F  SYMMETRIC

FIG. 82G  NON-SYMMETRIC

FIG. 82H  NON-SYMMETRIC

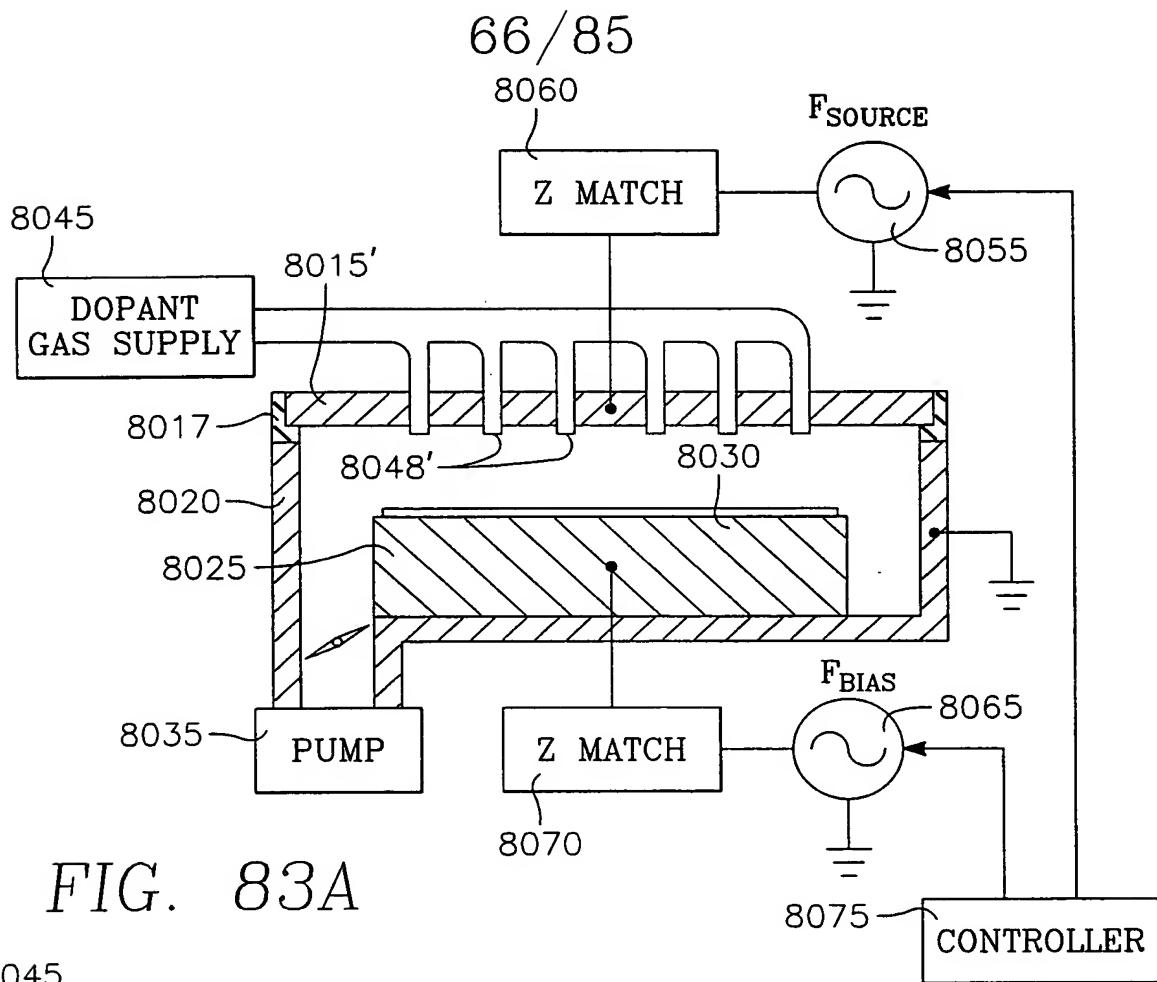


FIG. 83A

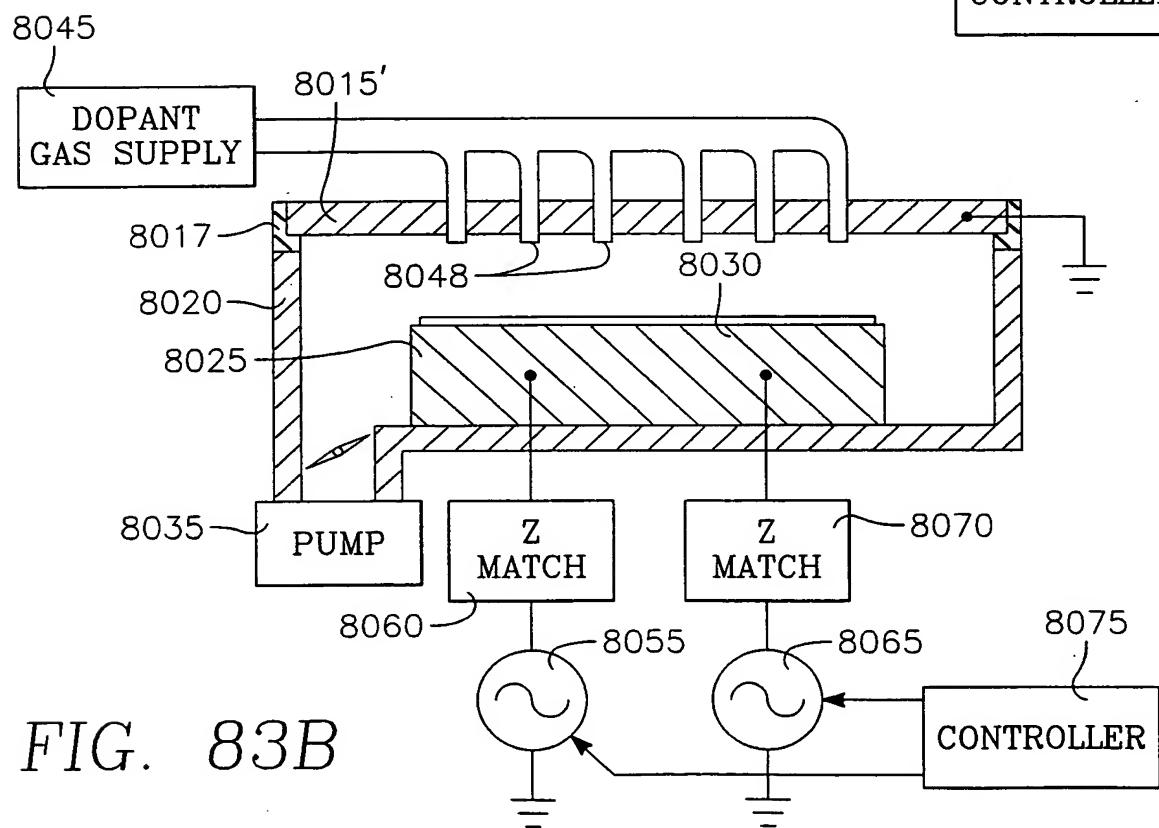


FIG. 83B

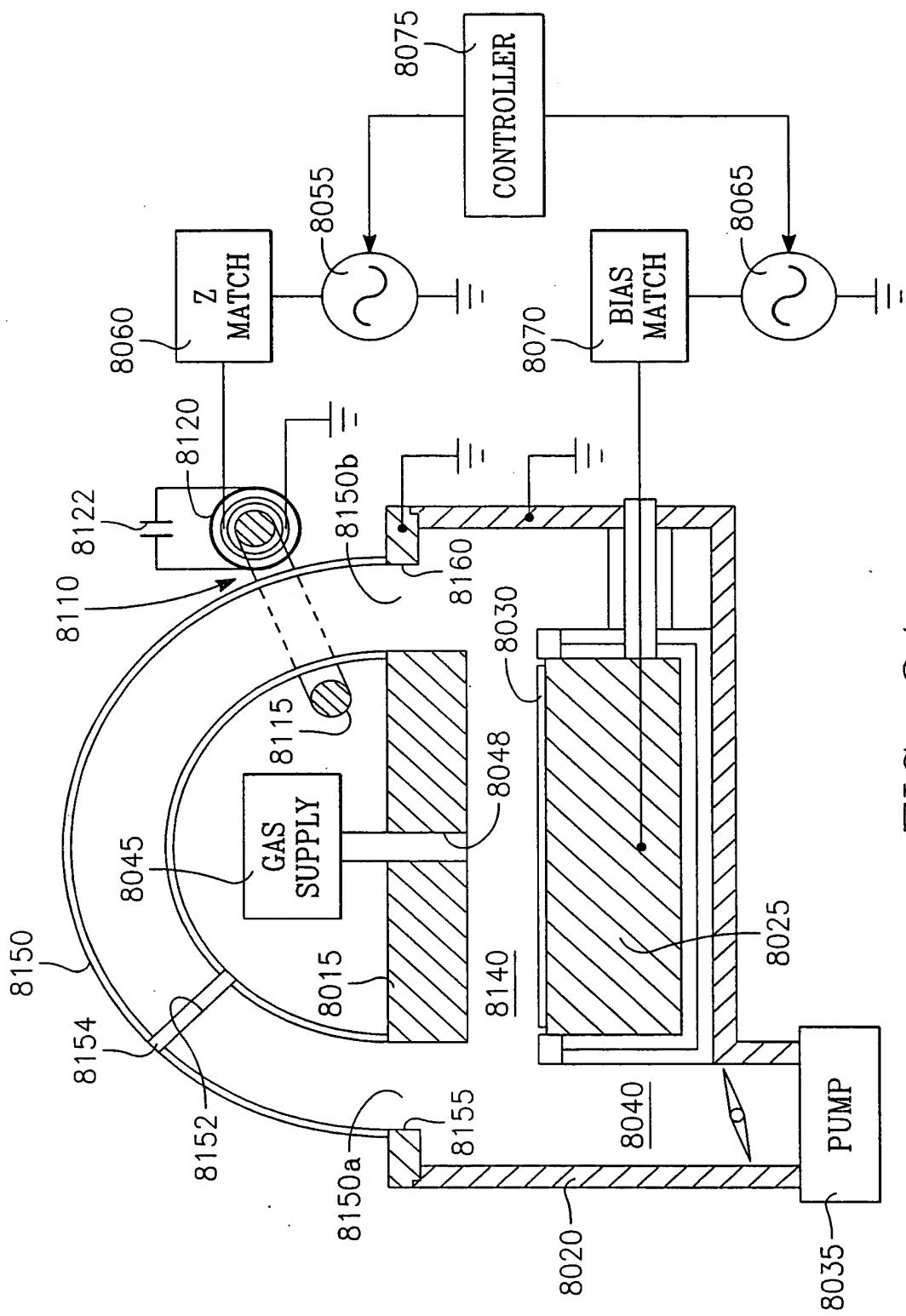


FIG. 84

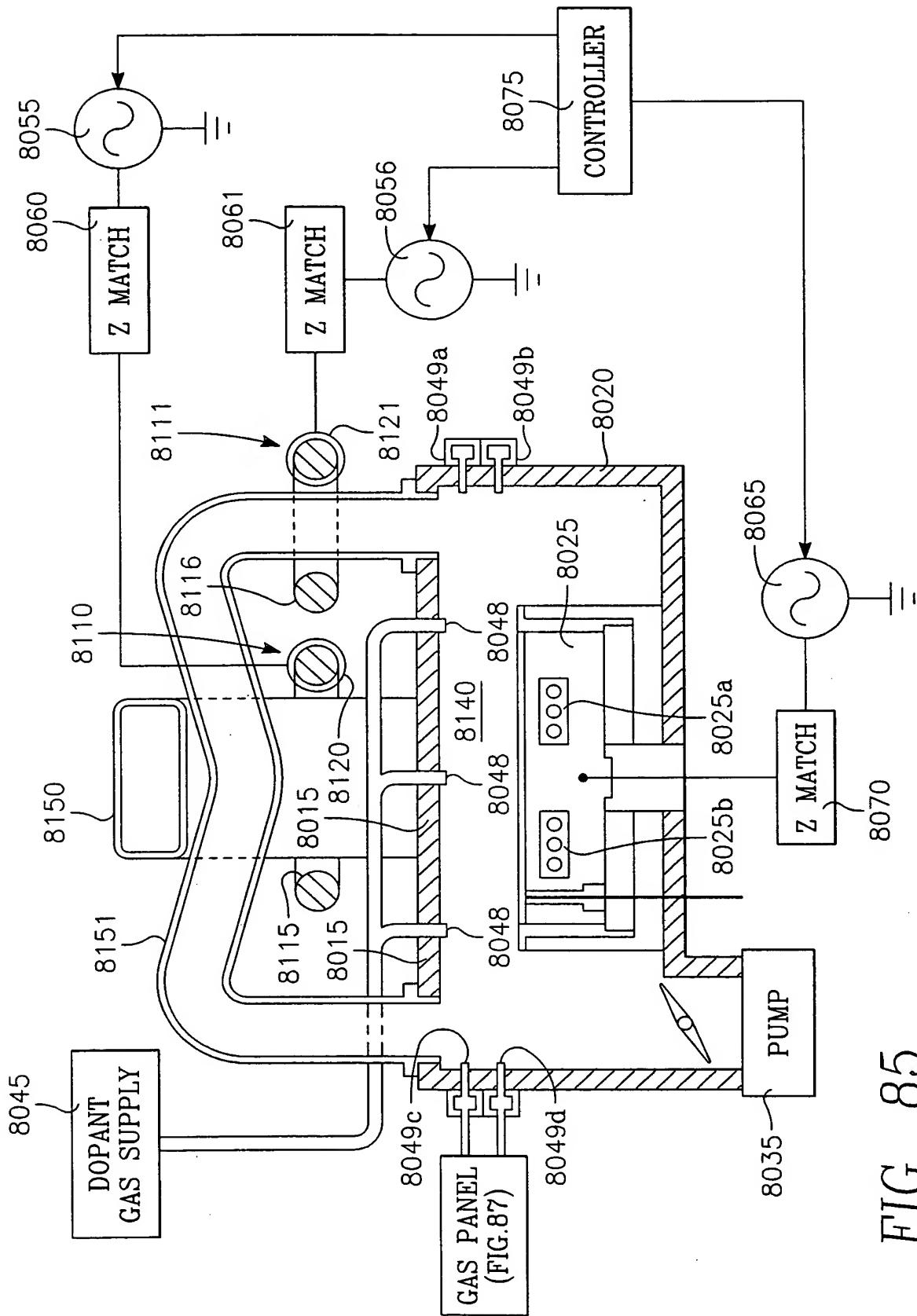


FIG. 85

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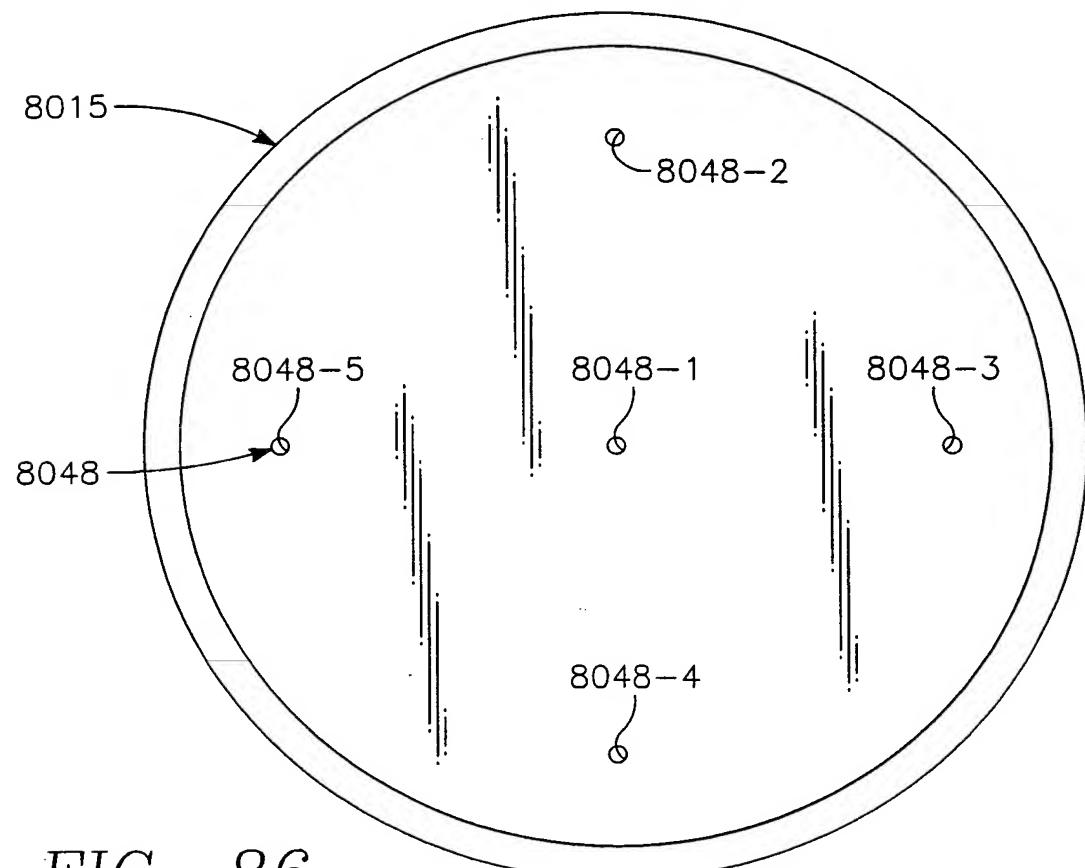


FIG. 86

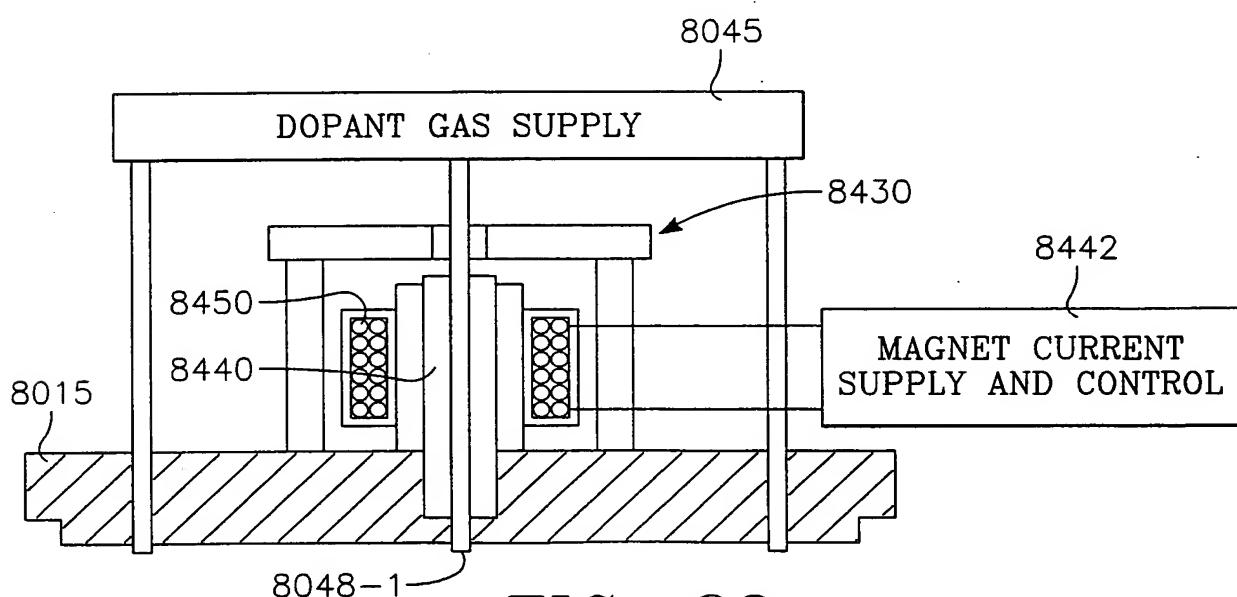


FIG. 88

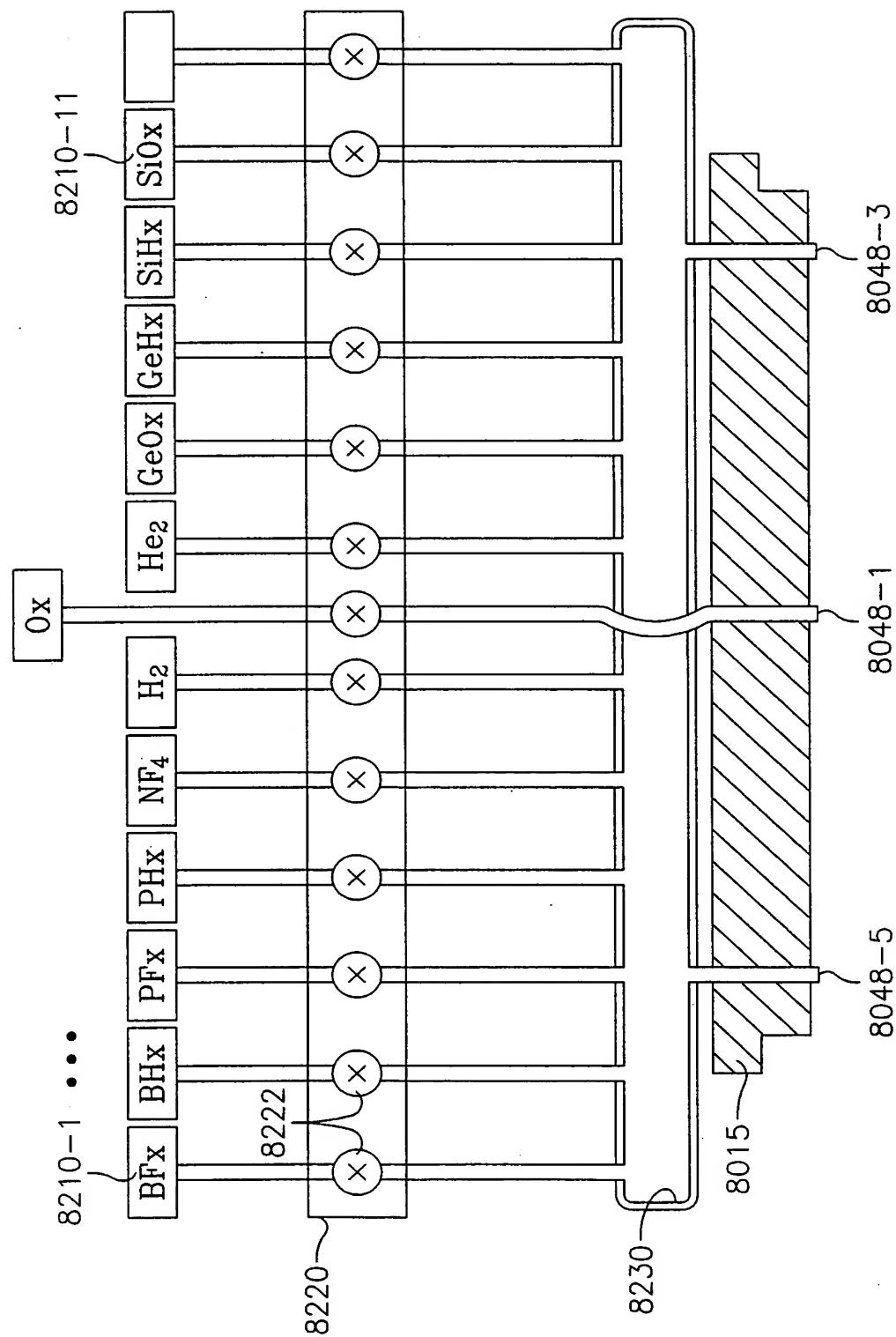


FIG. 87

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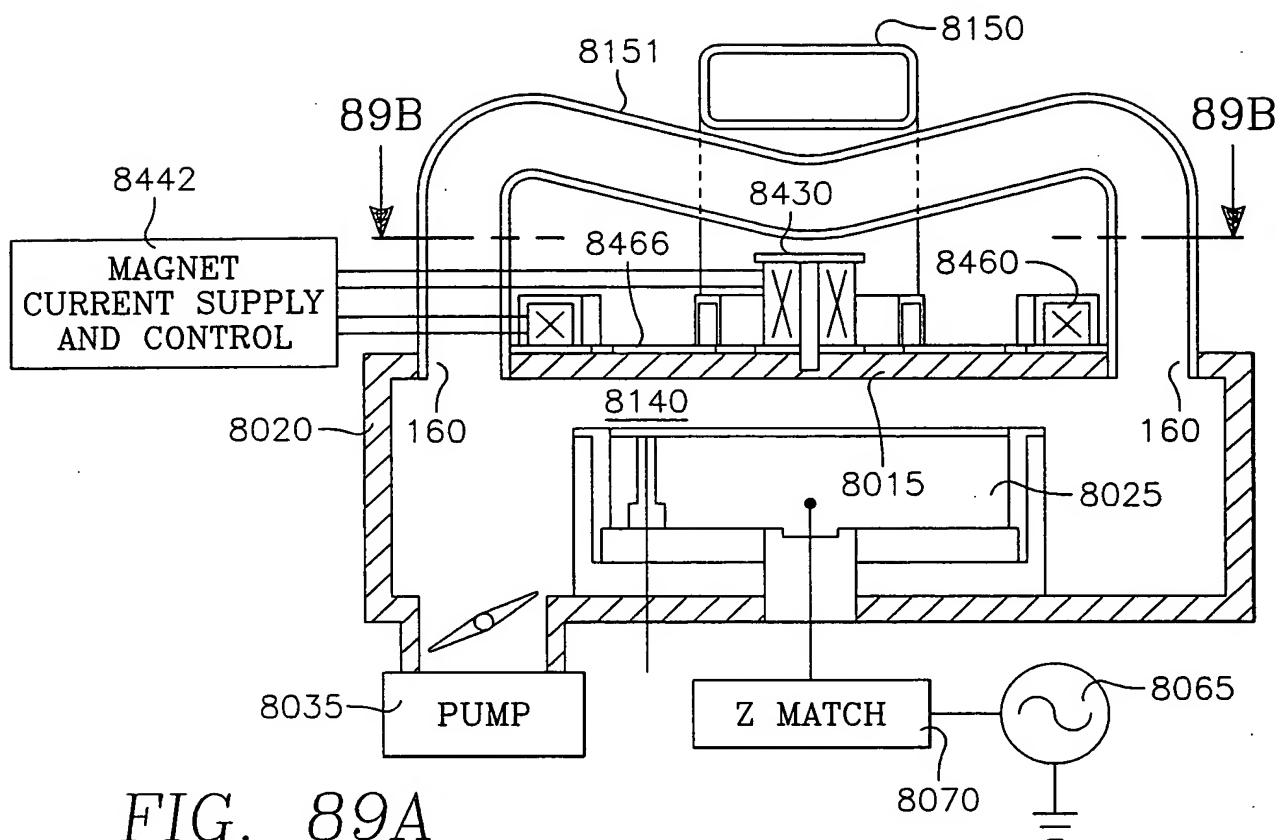


FIG. 89A

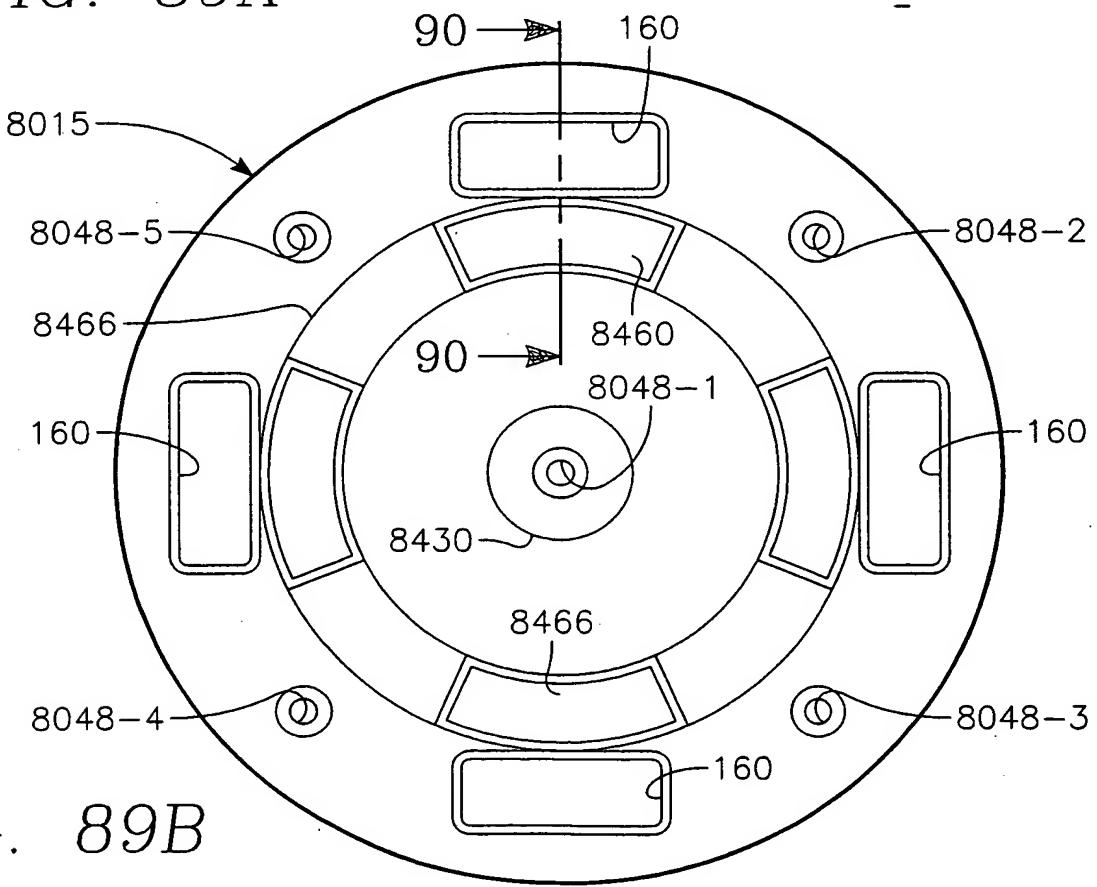


FIG. 89B

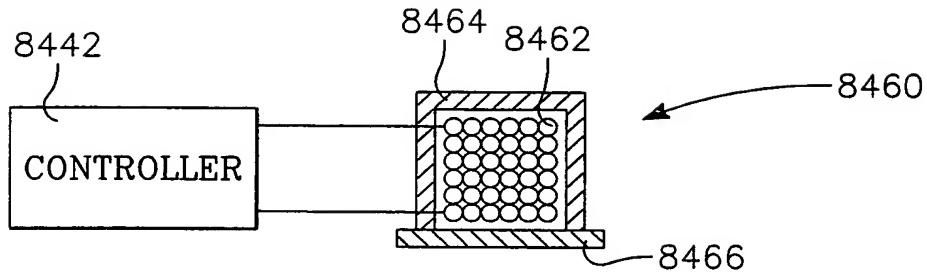


FIG. 90A

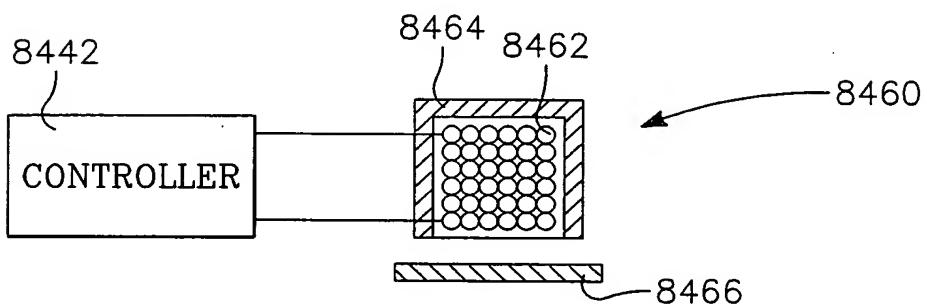


FIG. 90B

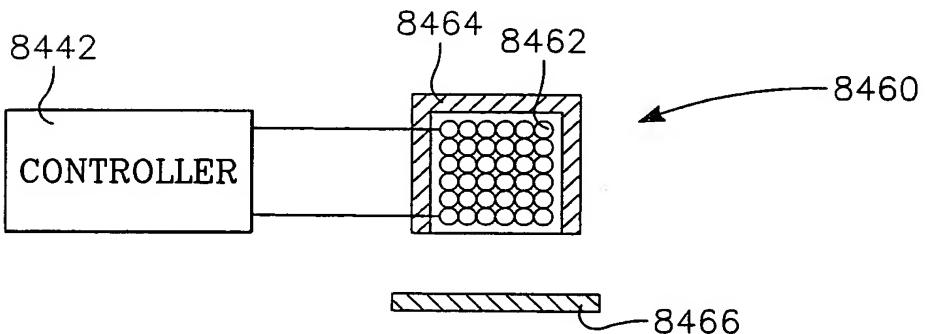


FIG. 90C

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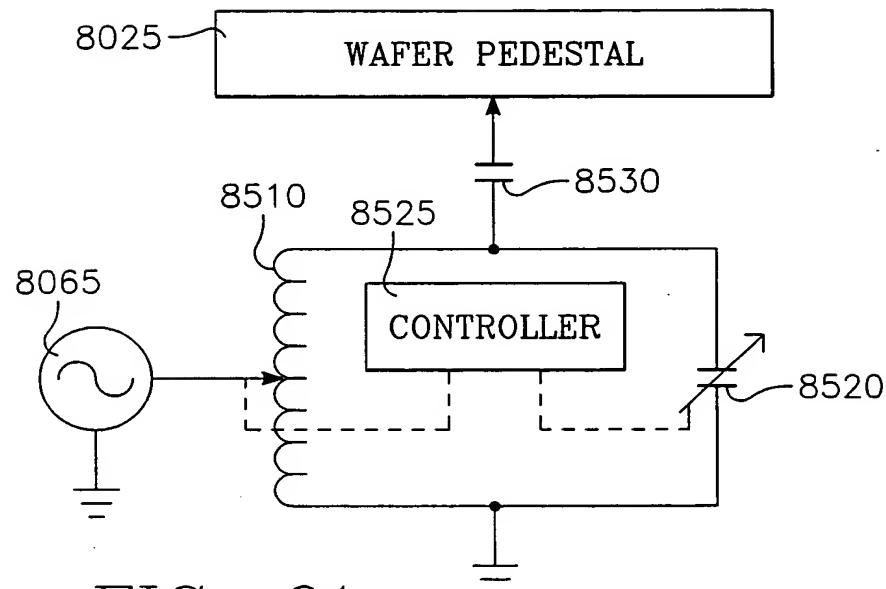


FIG. 91

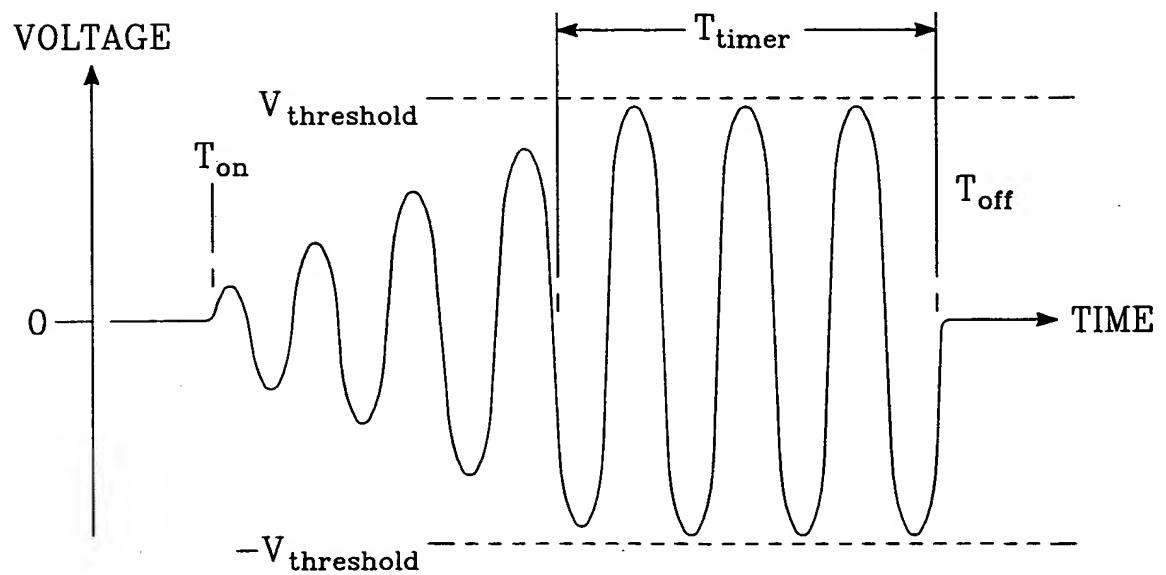


FIG. 92

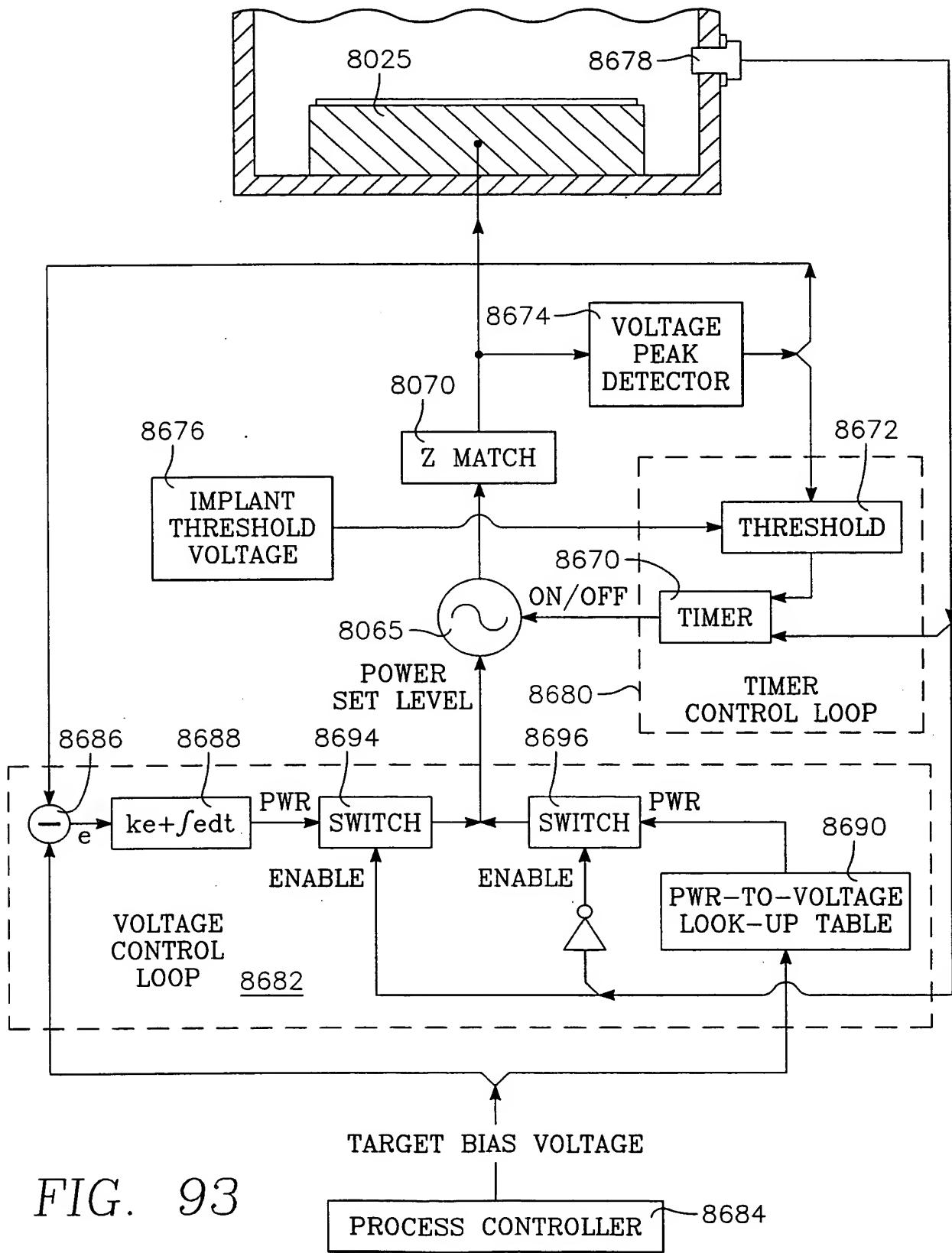


FIG. 93

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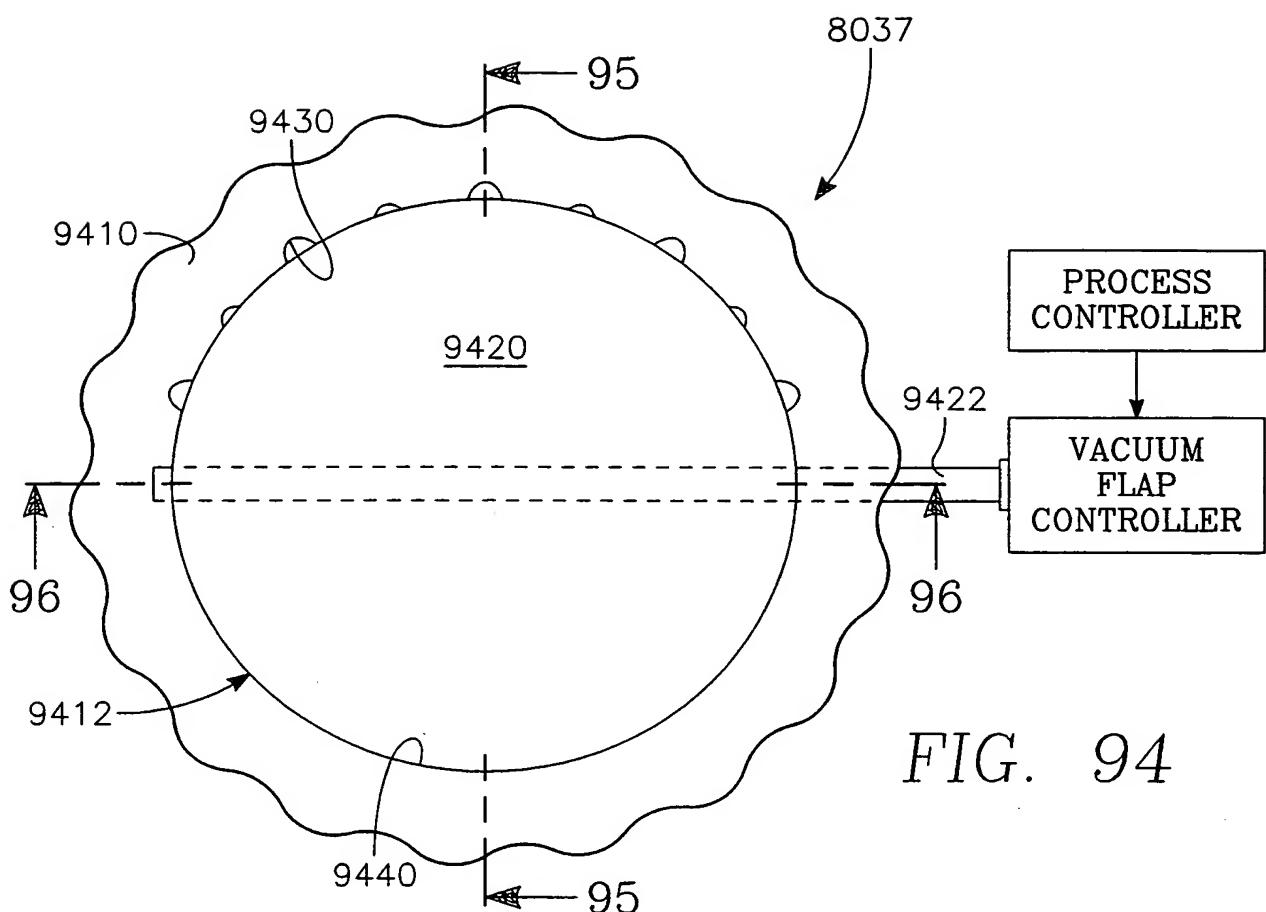


FIG. 94

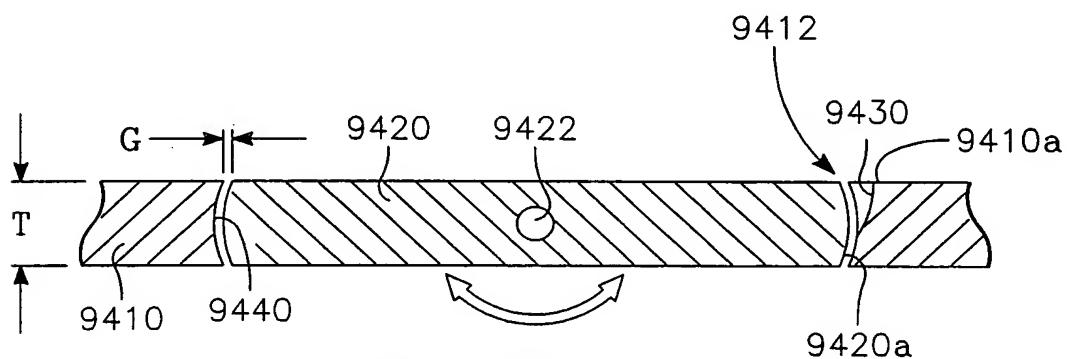


FIG. 95

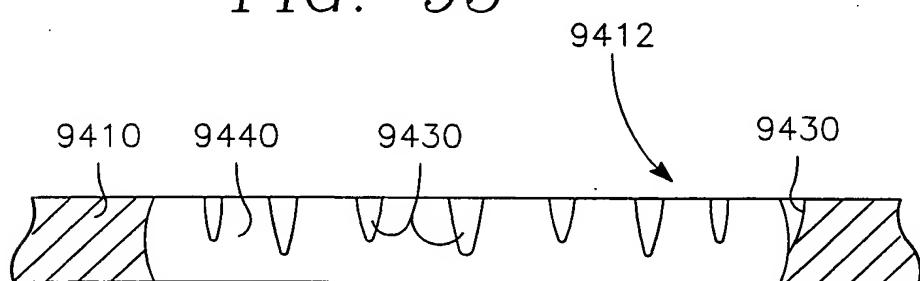


FIG. 96

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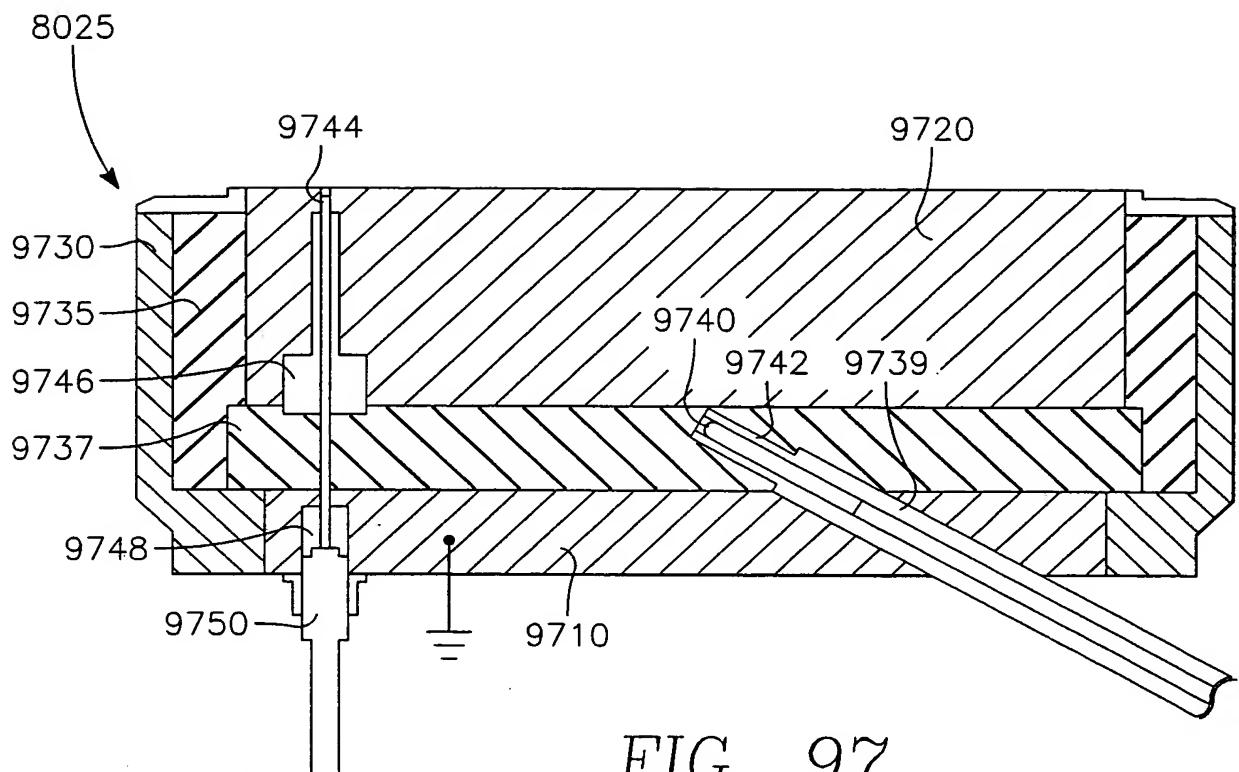


FIG. 97

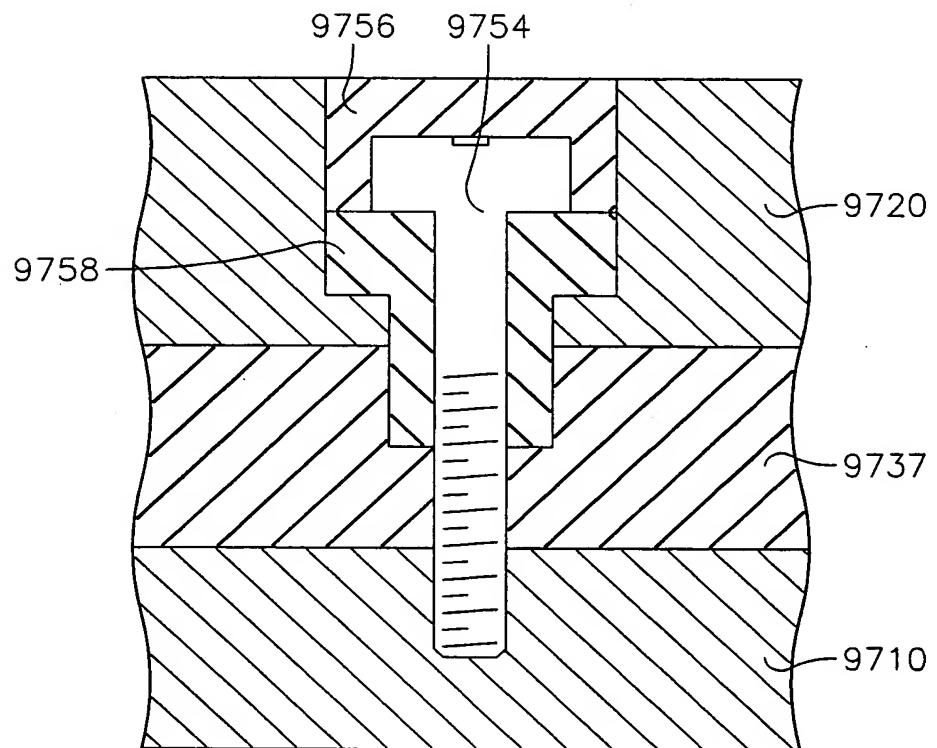


FIG. 98

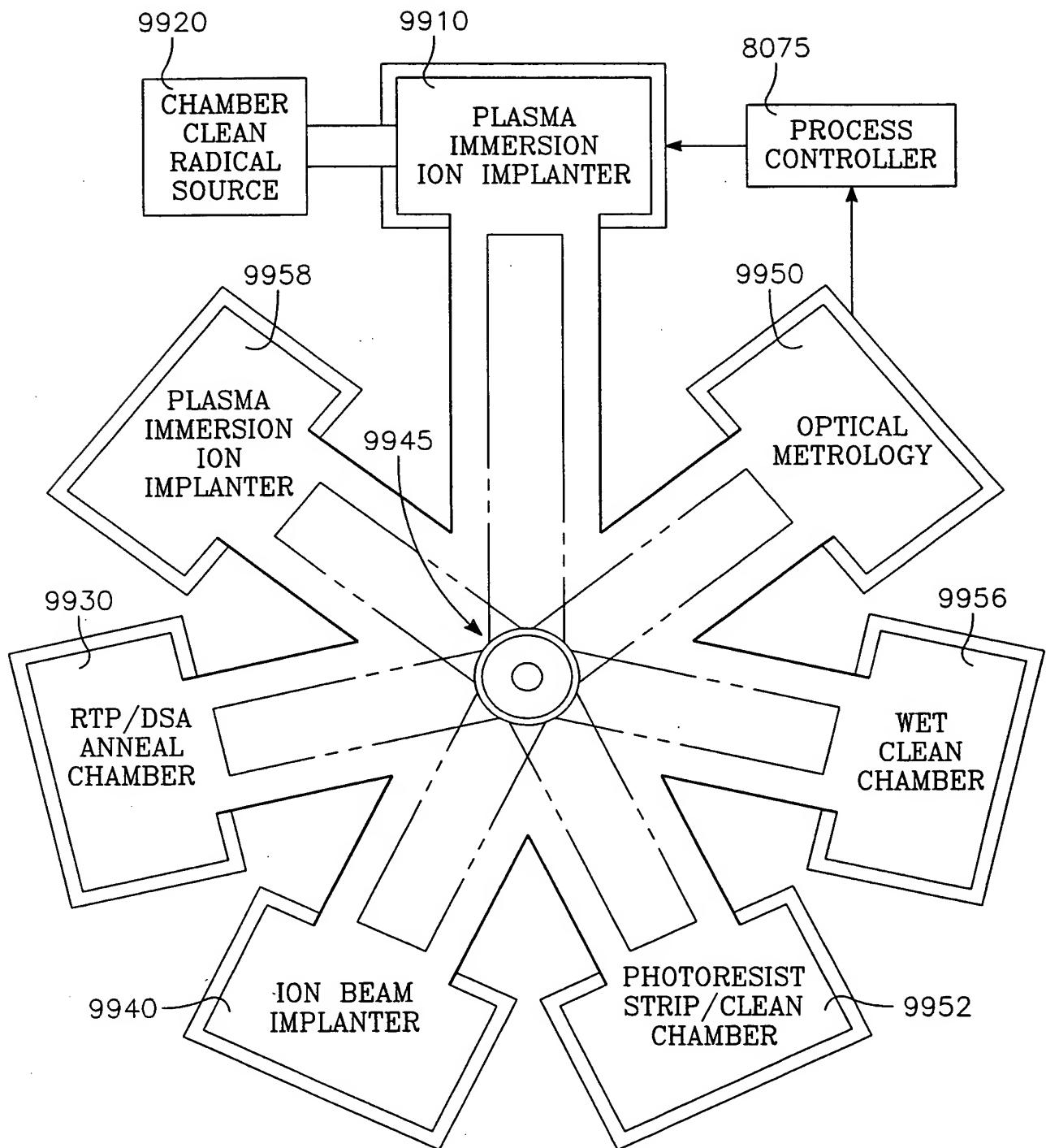


FIG. 99

ELECTRON
DENSITY

η_e

INDUCTIVE
SOURCE

TORROIDAL
SOURCE

FIG. 100

P_{TH} P_{ICP}

POWER

FREE
FLUORINE
DENSITY

ICP

TORROIDAL
SOURCE

FIG. 101

P_{TH} P_{DIS}

POWER

PLASMA
POTENTIAL

$|V_p|$

CAPACITIVE

TORROIDAL
SOURCE

FIG. 102

P_{TH}

POWER

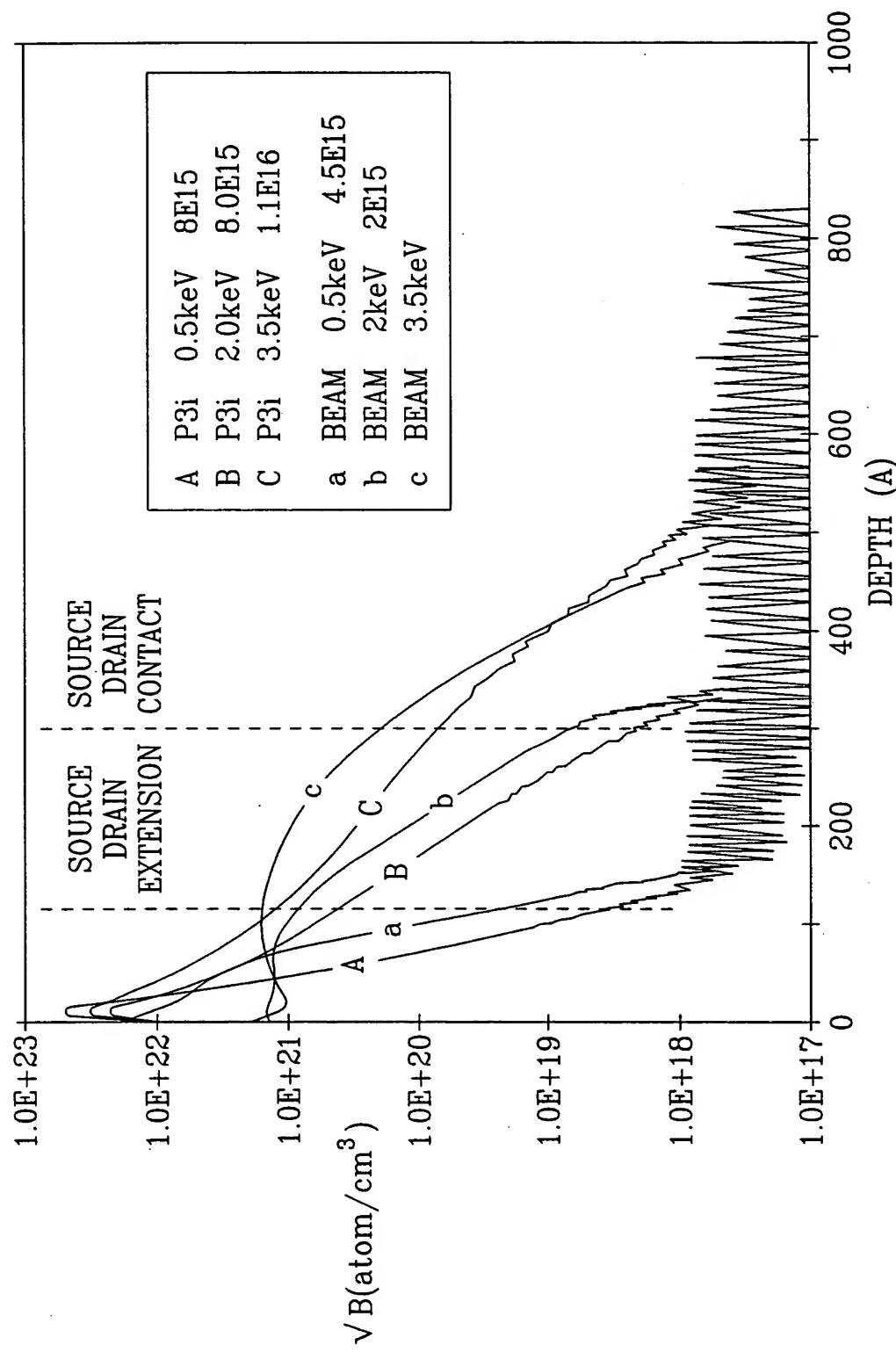


FIG. 103

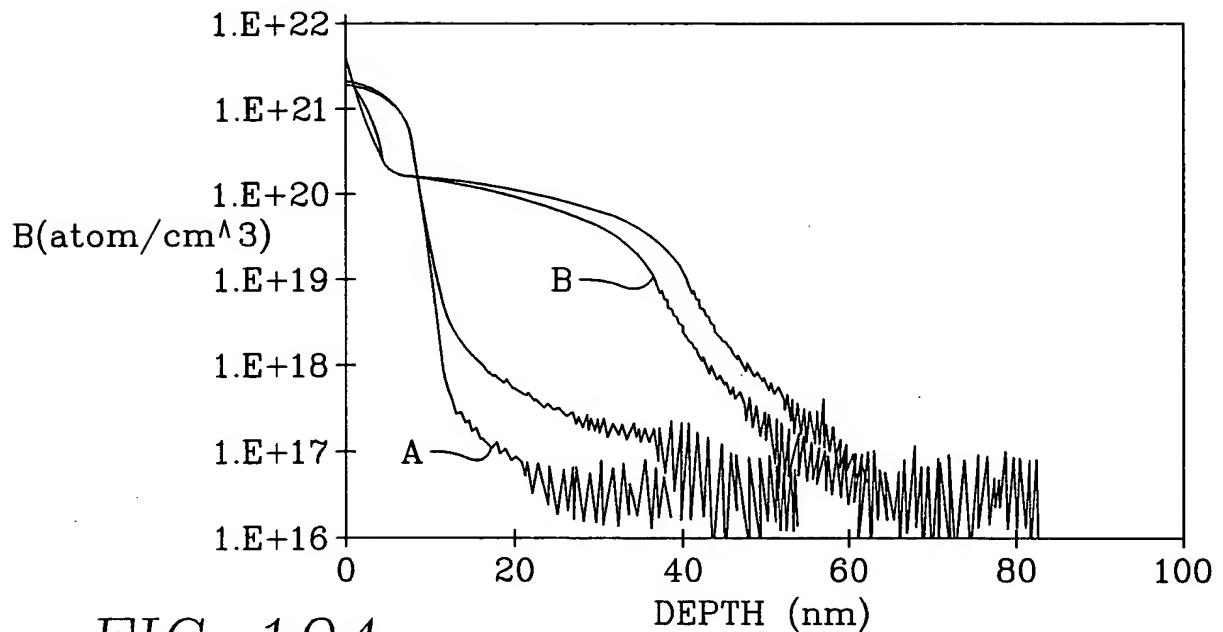


FIG 104

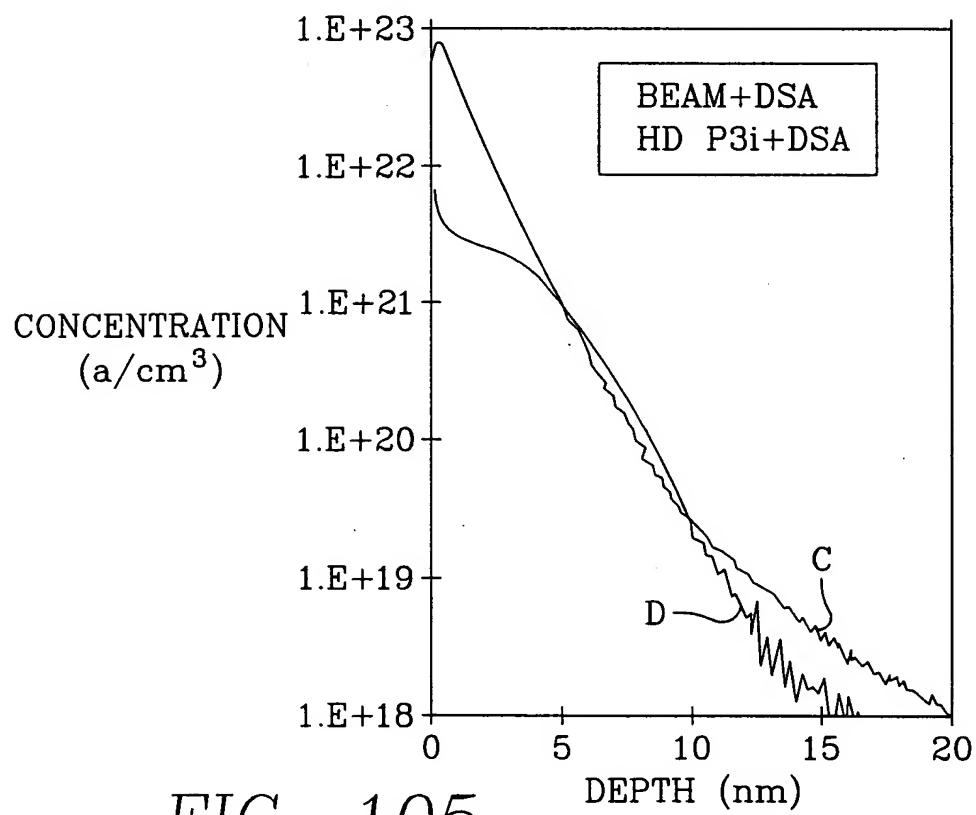


FIG. 105

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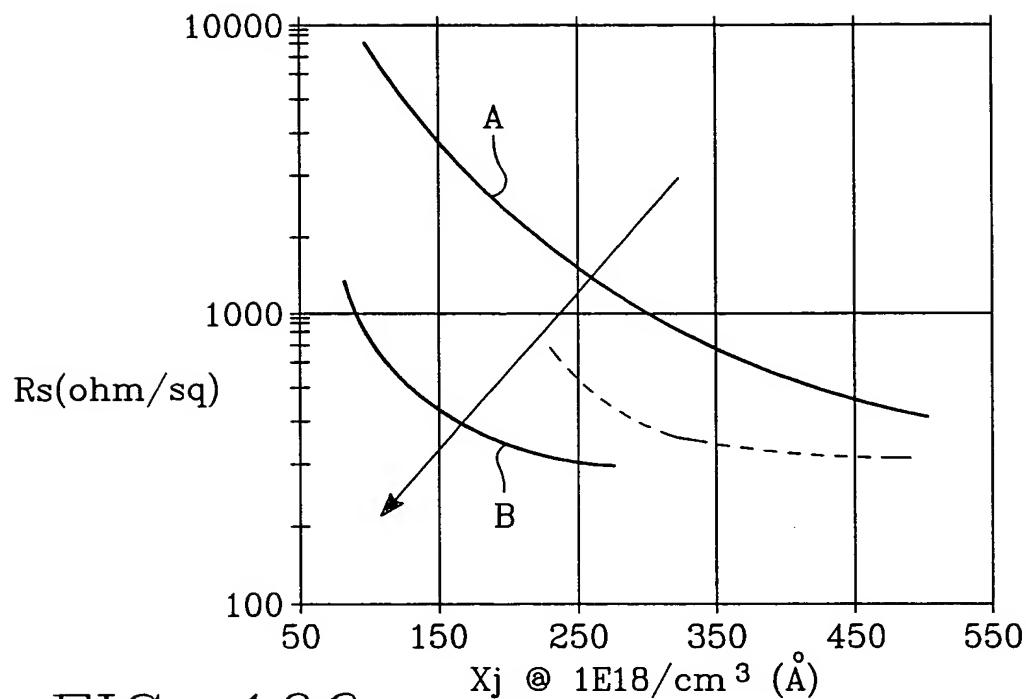


FIG. 106

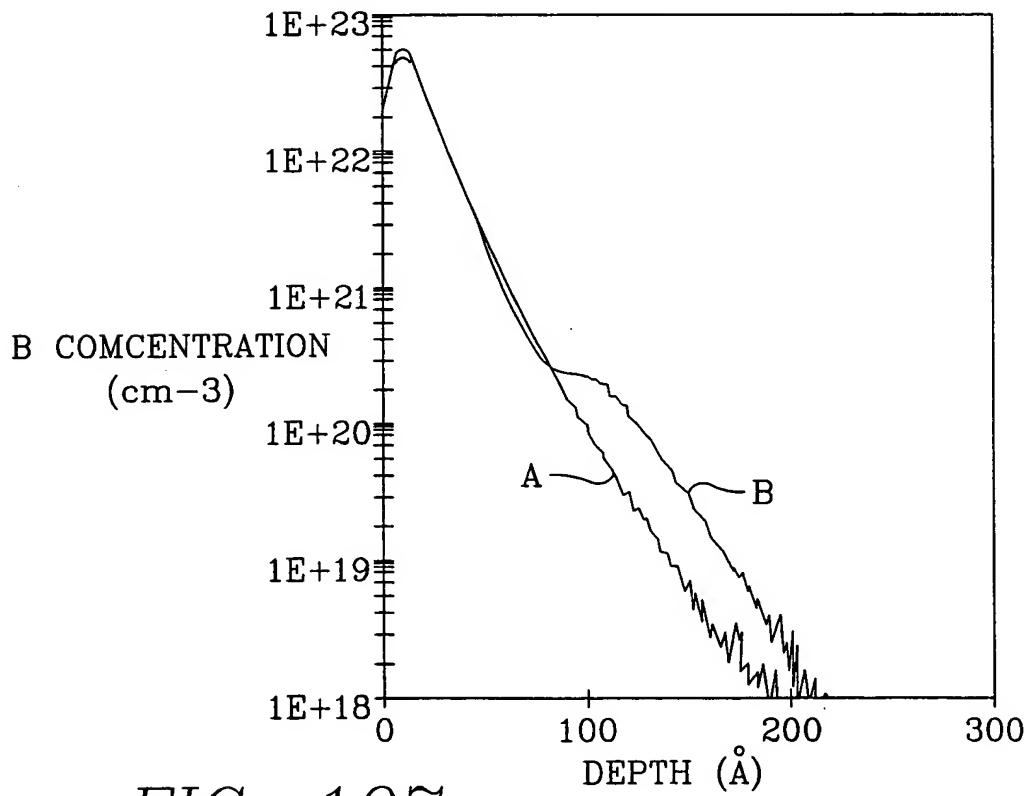


FIG. 107

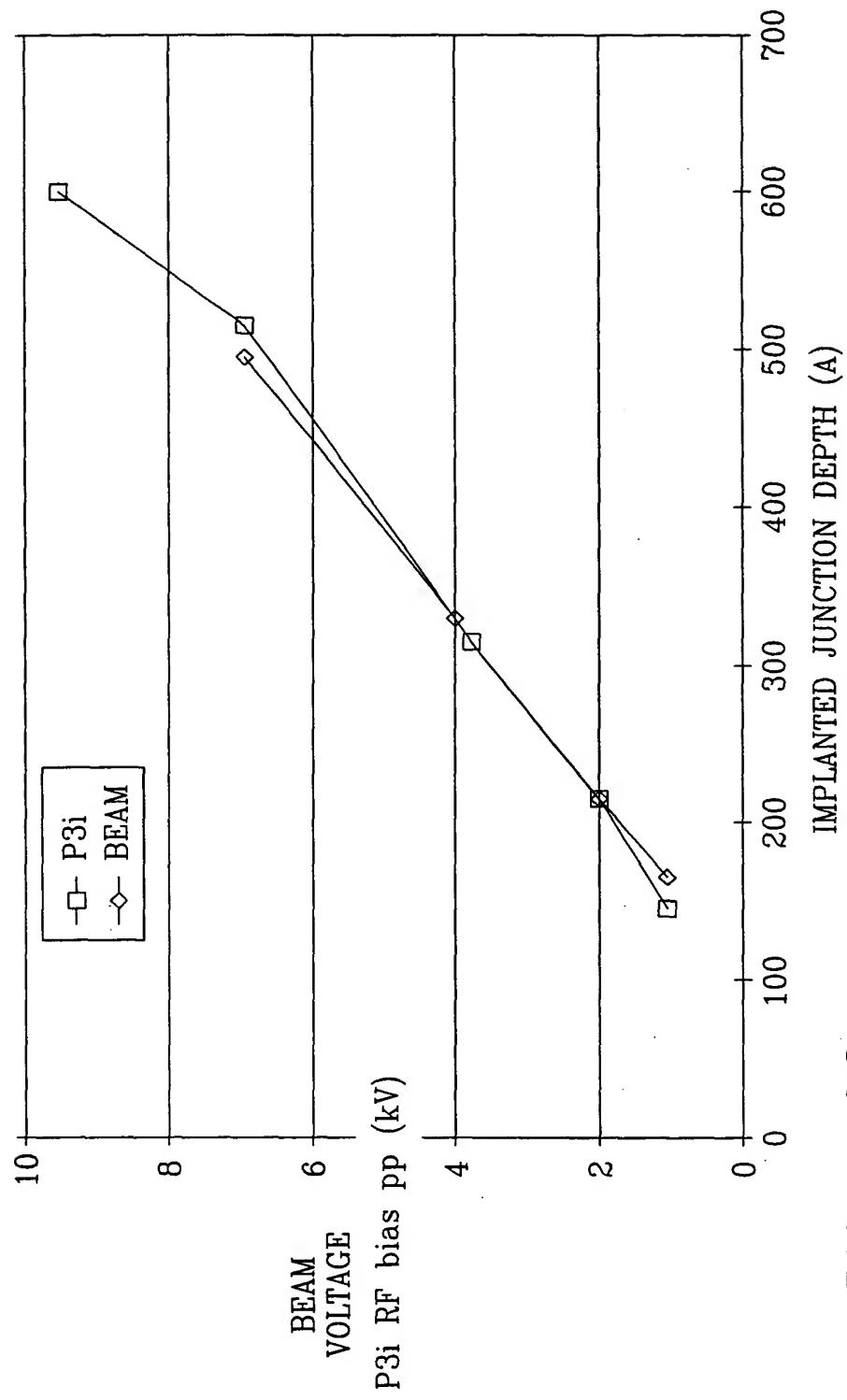


FIG. 108

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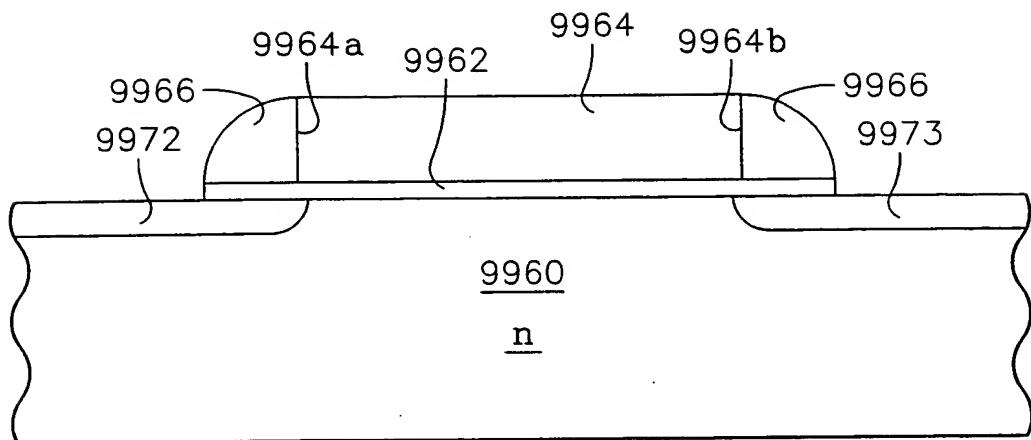
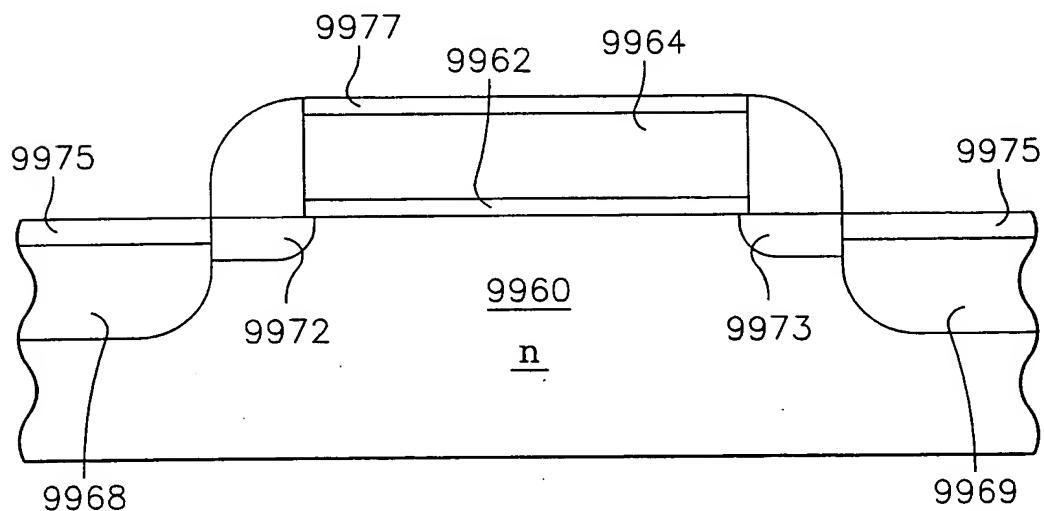


FIG. 109



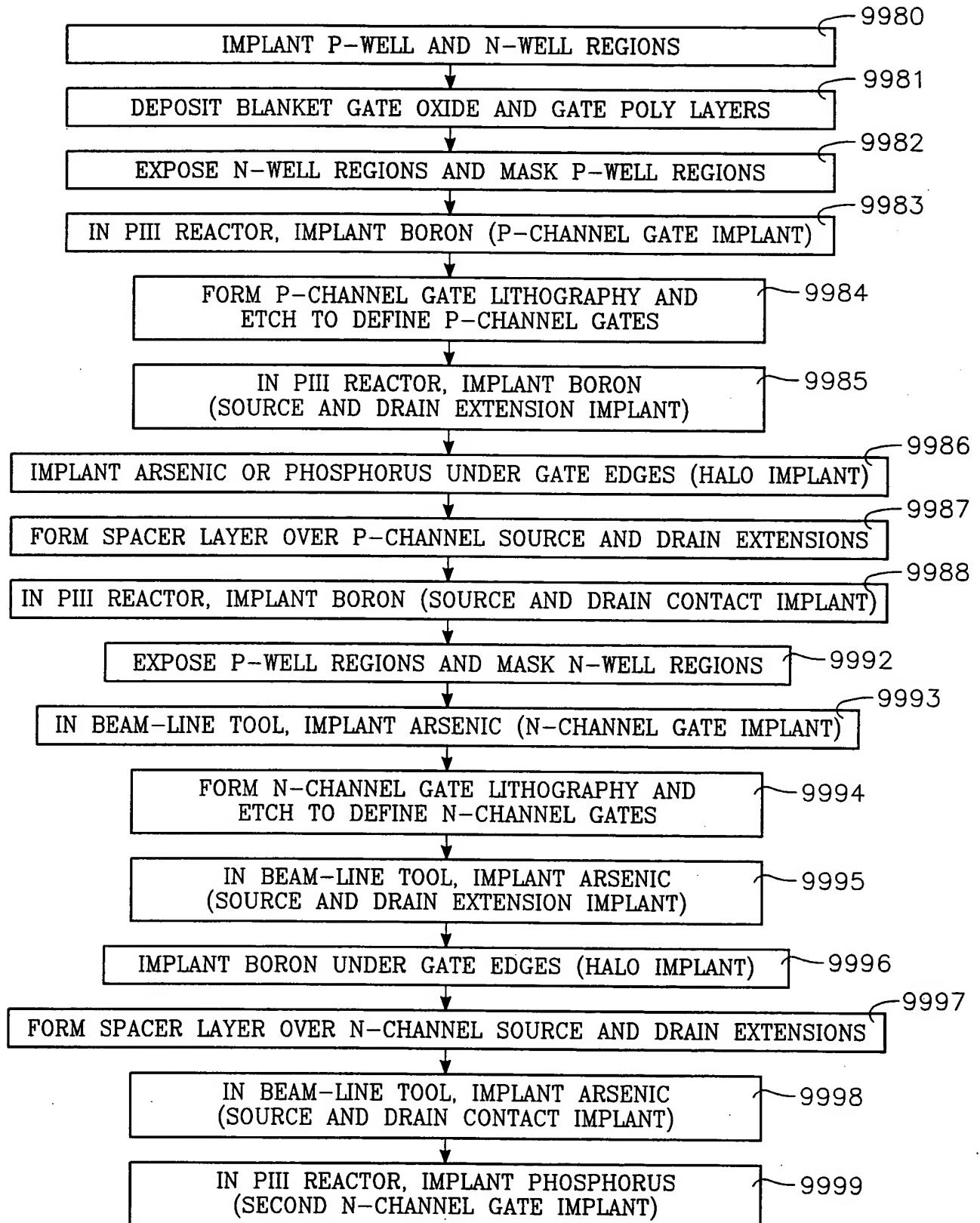


FIG. 111

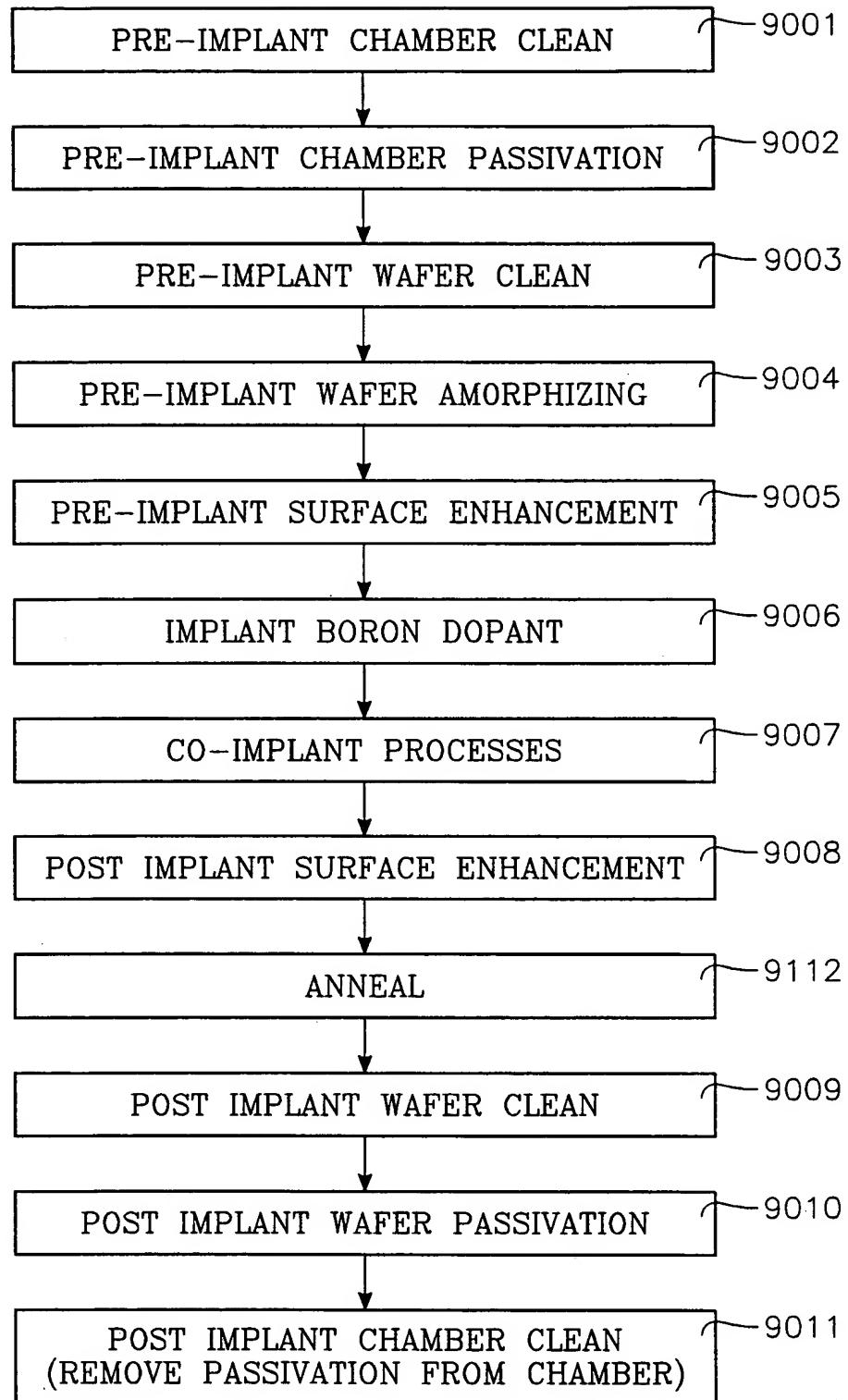


FIG. 112